Conference Program and Exhibitor Listings

Don't miss out on electronic packaging's premier conference!





The 2018 IEEE 68th Electronic Components and Technology Conference

May 29 - June 1, 2018

Sheraton San Diego Hotel & Marina San Diego, California, USA

For more information, visit: www.ectc.net

Program Supported by:







Sponsored by:





WELCOME FROM THE MAYOR OF SAN DIEGO, CALIFORNIA



KEVIN L. FAULCONER

MAYOR



WELCOME TO THE

2018 Electronic Components and Technology Conference

May 29-June 1, 2018

On behalf of the citizens of San Diego, it is my pleasure to welcome you to the 2018 Electronic Components and Technology Conference. We are delighted that you chose to host the Electronic Components and Technology Conference in our beautiful city. This conference is a wonderful opportunity for the best in packaging, components and microelectronic systems science, technology and education to come together and help one another exchange ideas and develop professionally. I am certain you will find San Diego to be a perfect location for your conference and I invite you to explore America's Finest City during your stay here.

Please accept my warmest wishes for an enjoyable event in San Diego.

Best personal regards,

Kevin L. Faulconer

Mayor

WELCOME TO SAN DIEGO FROM THE 68th ECTC GENERAL CHAIR AND PROGRAM CHAIR

On behalf of the Program Committee and Executive Committee, it is our pleasure to welcome you to IEEE's 68th Electronic Components and Technology Conference (ECTC), held at the beautiful Sheraton San Diego Hotel & Marina, San Diego, Calif., USA from May 29 - June 1, 2018. This premier international annual conference, sponsored by the IEEE Electronics Packaging Society (EPS), brings together key stakeholders of the global microelectronic packaging industry, such as semiconductor companies, foundry and OSAT service providers, equipment manufacturers, material suppliers, research institutions and universities, all under one roof. More than 1,400 people have attended ECTC in each of the last three years.

At the 68th ECTC, more than 370 technical papers are scheduled to be presented in 36 oral sessions and five interactive presentation sessions, including one interactive presentation session featuring papers exclusively by student authors. The oral sessions will feature selected papers on key topics such as fan-out packaging, wafer-level packaging, flip-chip packaging, 3D/TSV technologies, design for RF performance and signal/power integrity, thermal and mechanical modeling, optoelectronics packaging, materials, and reliability. Interactive presentation sessions will showcase papers in a format that encourages more in-depth discussion and interaction with authors about their work. Authors from over 20 countries are expected to present their work at the 68th ECTC, covering ongoing technology development within established disciplines or emerging topics of interest for our industry such as additive manufacturing, heterogeneous integration, and flexible and wearable electronics.

ECTC will also feature eight special sessions with invited industry experts covering several important and emerging topic areas. On Tuesday, May 29 at 10 a.m., W. Hong Yeo and C. S. Premachandran will chair an Emerging Technologies special session covering recent advancements and applications using soft materials. On that same day at 2 p.m., Florian Herrault will chair a session focused on emerging device assembly methods and applications. Tuesday evening sessions start at 7:00 p.m. with a Young Professionals networking panel chaired by Yan Liu. This year's ECTC Panel Session begins at 7:45 p.m. and will be chaired by IEEE EPS President Avi Bar-Cohen and Chris Bailey, where the topic will be IC/Package Co-Design for Heterogeneous Systems.

Boon Chye Ooi, Senior Vice President of Global Operations at Broadcom Inc., will be giving the invited keynote talk on "Packaging Advancement to Enable Artificial Intelligence, Autonomous Cars and Wearables in the Near Future: Cost and Implications to Supply Chains" at the ECTC Luncheon on Wednesday, May 30. This conference also features a Women's Panel and Reception jointly organized by ECTC and ITherm on Wednesday, May 30 at 6:30 p.m. This year, panelists from around the globe will share their perspectives on efforts to enhance the participation of women in engineering, and the panel will be chaired by Cristina Amon and Tanja Braun. On that same day at 7:30 p.m., Kemal Aygun will chair the ECTC Plenary Session titled "Artificial Intelligence and Its Impact on System Design." In this plenary session, experts will address the requirements and challenges for future AI hardware and share their views on how AI will impact system design and manufacturing. On Thursday, May 3 I at 8 p.m., the IEEE EPS Seminar "High-Density Packaging Technologies in the Era of Big Data" will be moderated by Yasumitsu Orii and Sheigenori Aoki from the High-Density Substrates & Boards Technical Committee of the IEEE EPS Society.

Supplementing the technical program, ECTC also offers Professional Development Courses (PDCs) and Technology Corner exhibits. Co-located with the IEEE ITherm Conference this year, the 68th ECTC will offer 18 PDCs, organized by the PDC Committee chaired by Kitty Pearsall and Jeffrey Suhling. The PDCs will take place on Tuesday, May 29, and are taught by distinguished experts in their respective fields. The Technology Corner will showcase the latest technologies and products offered by leading companies in the electronic components, materials, packaging and services fields. More than 100 Technology Corner exhibits will be open Wednesday and Thursday starting at 9 a.m. ECTC also offers attendees numerous opportunities for networking and discussion with colleagues during coffee breaks, daily luncheons, and nightly receptions.

Whether you are an engineer, a scientist, a manager, a student, or an executive, ECTC offers something unique for everyone in the microelectronics packaging and components industry. We would like to take this opportunity to thank all our sponsors, exhibitors, authors, speakers, PDC instructors, session chairs, and program committee members, as well as all the volunteers who have helped make the 68th ECTC another resounding success. Once again, thank you for being a part of the 68th ECTC.



Sam Karikalan General Chair Broadcom Inc.



Chris BowerProgram Chair
X-Celeprint, Inc.

WELCOME FROM ECTC SPONSORING ORGANIZATION



On behalf of the IEEE Electronics Packaging Society, it is my great pleasure and privilege to welcome you to the 68th ECTC.

This conference and the electronic packaging community we serve have grown enormously in size and in impact since the inaugural ECTC held 67 years ago. We

expect this year's attendance to reach 1,400 at ECTC, with another 2,500 participating in our other sponsored and co-sponsored conferences and workshops.

I would like to take this opportunity to thank all of you for attending ECTC and our volunteers on the ECTC Executive and Program Committees, members of the Board of Governors, volunteers from the EPS Society, and the ECTC and EPS staff for their commitment and dedication to making the 68th ECTC and its associated

activities the premier annual event of the electronic packaging community. We are fortunate to have so many of you actively engaged in this conference, and we are indebted to the large, skilled and enthusiastic team that keeps finding new ways to enhance this flagship conference.

In this first year of my presidency, I am excited about the impact of these technical events and networking activities on the EPS Society, our industry, and our members. It is profoundly gratifying to know that together we are developing the packaging technology for future product generations and driving innovation in the microelectronic industry!

Avram Bar-Cohen

EPS President 2018-2019

loran Bar- Cole

CONFERENCE POLICIES AND GUIDELINES

Badges

Conference attendees MUST wear the official conference badge to be admitted to all training courses, sessions, meals, Technology Corner exhibits and all conference sponsored social functions.

Medical Services

For emergency medical services, locate any hotel phone, whether in your room or elsewhere in the hotel, and follow its directions for emergencies. Hotel "house" phones have been placed throughout the hotel and conference area for your convenience. If no phone can be located, please locate the nearest hotel staff or ECTC staff for assistance with your emergency. The closest available hotel staff person may be at the front desk.

Personal Property

The hotel's safety deposit box is available for storing your valuables; particularly cash and jewelry. If there is a mini-safe in your room, you should consider using it.

Smoking Policy

Smoking is NOT permitted in the hotel. Please follow hotel policies and signs regarding this. Smoking is also NOT permitted at any ECTC activities including, but not limited to, functions, events, sessions, and / or seminars. Thank you for your consideration and cooperation.

Recording presentations via photos or video is prohibited.

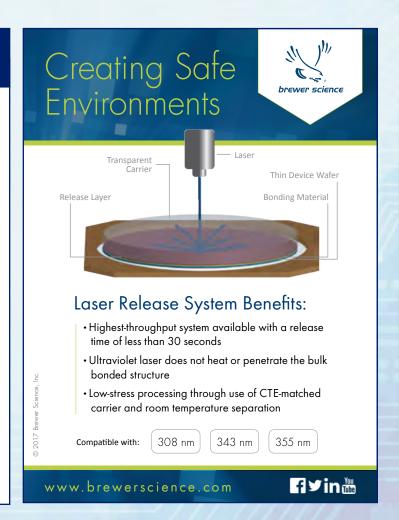


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Session 3: 3D Design, Assembly and Additive Manufacturing
Session 4: Automotive and Harsh Environment Reliability
Session 5: Antenna-in-Package for RF and mm-Wave Systems
Session 6: Warpage and Moisture Characterization
Session 7: Low-Temperature Metallic Interconnection Technologies
Session 8: Fan-Out Packaging-Applications and Architectures
Session 9: Flip-Chip Manufacturing Challenges
Session 10: Innovative Design, Modeling and Predictions for Reliability I
Session 11: Emerging Packaging Technologies for 5G and
Advanced Computing
Session 12: Sintering Pastes, Transient Liquid Phase and Direct Bonding 1
Session 13: Fan-Out and Interposer Interconnections
Session 14: Advanced Substrates and Flip Chip Applications
Session 15: Warpage Control in Assembly Processes
Session 16: Advances in Interconnect Reliability and Techniques
Session 17: Technology Advances in Nano, Biochemical,
Thermal and Flexible Applications
Session 18: Silicon Photonics
Session 19: Interconnect Reliability
Session 20: MEMS, Sensor, IoT and Flex
Session 21: Materials and Process Trends for Fan-Out
Wafer-Level Packaging
Session 22: Thermal Mechanical Modeling and Characterization
Session 23: RF and THz Module Components
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Session 27: Automotive and Power Electronics
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Session 29: Modeling of Power Electronics
Session 30: Emerging Materials and Technologies
Session 31: Advanced Wirebond and Interconnect Technologies
Session 32: Heterogeneous Integration
Session 33: Next-Generation Materials and Processes for
Through Vias and 3D Interconnects
Session 34: Fan-Out Wafer-Level Package Reliability
Session 35: Multiphysics and Solder Joint Reliability
Session 36: Power Delivery Solutions for Components and Systems
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Technology Corner Booth Layout
Technology Corner Exhibits
ECTC Executive Committee
ECTC Program Committee
69th ECTC Call for Papers
Conference Sponsors
Media Sponsors
Hotel Layout
69th ECTC Dates and Location
Conference at a Glance

Conference organizers reserve the right to cancel or change this program without prior notice.



ECTC Luncheon Keynote Speaker

Wednesday, May 30, 2018 12:00 Noon Grande Ballroom

Packaging Advancement to Enable Artificial Intelligence, Autonomous Cars and Wearables in the Near Future: Cost and Implications to Supply Chains

Boon Chye Ooi Senior Vice President, Global Operations – Broadcom Inc.

Recent advancements in IC Packaging have played a vital role in enabling semiconductor devices to scale new performance heights and penetrate into new application frontiers. Technologies such as 2.5D/3D packaging and fan-out packaging are in the forefront, leading us into the world of artificial intelligence, autonomous cars and wearables. The packaging industry still has to make these technologies cost competitive and multi-sourced for their ubiquitous deployment, while also keeping up with performance challenges on signal integrity, thermal performance and mechanical reliability. Will IDMs, foundries or OSATs keep up with the design challenges and drive down the cost of supply chain? Boon Chye Ooi, Senior Vice President of Global Operations at Broadcom Inc., will discuss such challenges in the immediate future and issue a call to action by the industry stakeholders.

As a Senior Vice President at Broadcom, Boon Chye Ooi leads the Global Operations organization that is responsible for worldwide manufacturing, including foundry and package engineering, outsourcing, procurement and logistics, planning and quality programs. He has held this position since January 2009. From November 2003 until 2008, Mr. Ooi was the Senior Vice President of Worldwide Operations at Xilinx, where he was responsible for all worldwide plant operations, supply chain processes, and inventory controls, as well as contract electronic component manufacturers. Prior to Xilinx, Mr. Ooi had a long career at Intel, where he served in a variety of management positions.

Heterogeneous Integration Roadmap Workshop

Tuesday, May 29, 2018 • 8:00 a.m. - 5:00 p.m. Executive Center I & 4

Our Industry has reinvented itself through multiple disruptive changes in technologies, products, and markets. With migration of logic, memory and applications to the cloud, Al at the edge, the Internet of Things (IoT) to internet of everything (IOE), smart devices everywhere, and autonomous automotives, the pace of innovation is increasing to meet these challenges.

The Heterogeneous Integration Technology Roadmap (HIR) is sponsored by the IEEE EPS Society, the Electron Devices Society (EDS), and Photonics Society together with SEMI and ASME EPPD. It will address the future directions of heterogeneous integration technologies serving system integration for future markets and products, which are so very crucial to our societies' fields of interest and our industries and academic and research communities. Fresh from the highly successful Heterogeneous Integration Roadmap Symposium on February 22nd hosted by the IEEE EPS Santa Clara Valley Chapter at Santa Clara California, the first Heterogeneous Integration Roadmap will be unveiled at the 2018 ECTC Conference.

The 2018 ECTC Conference is pleased to host the upcoming Heterogeneous Integration Roadmap workshop on Tuesday, May 29, in San Diego, Calif. We invite all the ECTC participants to attend this important working session for our profession and for our industry. The workshop is open to all. Registration is not necessary. There is no fee for attendance.

REGISTRATION, RECEPTIONS AND GENERAL INFORMATION

Registration

ECTC registration will be open at the ECTC Registration Desk located in the Sheraton San Diego Hotel & Marina, Marina Tower, Lobby Level, in the Bayview Foyer.

Monday, May 28, 2018 • 3:00 p.m. – 5:00 p.m.

Tuesday, May 29, 2018 • 6:45 a.m. - 8:15 a.m.*

(AM PD Courses & Special Session Only)*

Tuesday, May 29, 2018 • 8:15 a.m. – 5:00 p.m.

(All conference attendees)

Wednesday, May 30, 2018 • 6:45 a.m. – 4:00 p.m.

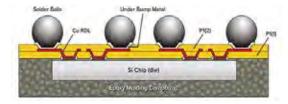
Thursday, May 31, 2018 • 7:30 a.m. – 4:00 p.m.

Friday, June 1, 2018 • 7:30 a.m. - 12:00 Noon

New for 2018 - On Tuesday morning from 6:45 a.m. - 7:15 a.m., ECTC will be providing morning refreshments for those registering early! If you get there after 7:15 a.m., you run the risk that they'll be gone.

*The above schedule for Tuesday will be vigorously enforced to prevent students from being late for their courses. Please make sure to take advantage of the 6:45am start time on Tuesday, May 29 as registration becomes very congested prior to the start of morning Professional Development Courses.

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Door Registration Fees

Door Registration with Proceedings on USB drive	
${\tt IEEE\ Member\ JOINT\ Registration\ (full\ ECTC\ +\ ITHERM\ conference)}$.\$1125
IEEE Member Full Registration	\$835
IEEE Member Speaker / Session Chair	\$730
IEEE Member One Day	\$550
IEEE Member Speaker One Day	\$415
Exhibit Booth Attendant	\$0
Non-Member JOINT Registration (full ECTC + ITHERM conference)	\$1335
Non-Member Full Registration	\$1025
Non-Member Speaker / Session Chair	\$730
Non-Member One Day	\$550
Non-Member Speaker One Day	\$415
Exhibit Booth Attendant	\$0
Student	\$315
Student Speaker	
Exhibits Only	\$25
Tuesday Professional Development Courses	
IEEE Members and Non-Members	
Tuesday AM or PM Course with luncheon	\$500
Tuesday All-Day Courses with luncheon.	. \$710
Tuesday Student All-Day Courses with luncheon	\$130
Extra Luncheon Tickets for Each Day	\$65
Extra Proceedings with Registration	. \$100

Each student registrant will be offered FREE memberships to the IEEE & EPS for the rest of 2018.

PROFESSIONAL DEVELOPMENT
COURSE INSTRUCTORS BREAKFAST
Tuesday, May 29, 2018 • 7:00 a.m. - 8:00 a.m.
Grande Ballroom B

PDC Instructors and Proctors are required to attend a briefing breakfast.

SESSION CHAIRS AND SPEAKERS BREAKFAST Wednesday, May 30 - Friday, June 1, 2018 7:00 a.m. - 8:00 a.m.

Grande Ballroom A

Session Chairs and speakers are requested to attend a complimentary continental breakfast on the morning of their sessions/presentations. At this time, presentations will be transferred to the conference PC, which is loaded with Windows XP and MS Office 2003.

SPEAKER PREP ROOM
Tuesday, May 29 - Friday, June 1, 2018
7:00 a.m. - 5:00 p.m.

Marina 3

Speakers should prepare and review their digital presentations within the allotted times above:

(It is extremely important to assure that your presentation, presentation software and computer work flawlessly with the digital projector provided.)

MISCELLANEOUS INFORMATION

Hotel Concierge

The Hotel Concierge, located in the hotel lobby, can direct you to various types of entertainment or restaurants, or give suggestions for that special night out. The Concierge can help to make your visit and conference experience a memorable one!

Message Center

Please use the hotel switchboard or the ECTC Registration Desk, located in the Marina Tower, Lobby Level, Bayview Foyer to leave and pickup messages.

The hotel phone number is +1 (619) 291-2900.

Press Room

Press Interviews will be scheduled on an as-requested basis. To coordinate an interview with conference leadership or presenting technical experts, please contact ECTC Publicity Chair:

Eric Perfecto
eric.perfecto@globalfoundries.com
+1 (845) 475-1290

LUNCHEONS

Tuesday, May 29, 2018 12:00 Noon (Grande Ballroom)

The Electronic Components and Technology Conference will sponsor a luncheon for all Professional Development Courses attendees, proctors and PDC committee members.

Wednesday, May 30, 2018 12:00 Noon (Grande Ballroom)

The Electronic Components and Technology Conference will sponsor a luncheon for conference attendees. Best and Outstanding Papers will be awarded. The guest speaker will be Boon Chye Ooi, Senior Vice President - Global Operations for Broadcom Inc.

Thursday, May 31, 2018 12:00 Noon (Grande Ballroom)

The IEEE Electronics Packaging Society (EPS) will sponsor a luncheon for conference attendees. The EPS awards will be presented.

Friday, June 1, 2018 12:00 Noon (Grande Ballroom)

The ECTC Program Chair will sponsor a luncheon for conference attendees. You don't want to miss it!

There will be a raffle for attendees.

ECTC Mobile App

ECTC is pleased to announce that a free mobile app is available this year. The app provides schedules for the technical program and PDCs, as well as details on exhibitors, sponsors, and general conference information and venue maps. The app also enables you to set your personal conference schedule so you don't miss important presentations and social functions. Plus, you can rate presentations that ECTC uses to select candidates for best paper awards.

The app is available for iOS and Android devices from the respective app stores by searching "2018 ECTC". Look for additional information in the separate handout included in your ECTC registration packet received at the conference.



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2018 ECTC SESSIONS & SEMINARS - Open to all conference attendees



2018 EMERGING TECHNOLOGIES SPECIAL SESSION

Soft Material-Enabled Electronics for Medicine, Healthcare, and Human-Machine Interfaces

> Tuesday, May 29, 2018 10:00 a.m. – 11:30 a.m. Grande Ballroom C

Chairs: W. Hong Yeo - Georgia Institute of Technology and C. S. Premachandran -GLOBALFOUNDRIES



- I. Michael McAlpine, University of Minnesota
- 2. Todd Coleman , University of California, San Diego
- 3. Aadeel Akhtar, Psyonic
- 4. Rooz Ghaffari, Epicore Biosystems



2018 ECTC/ITHERM WOMEN'S PANEL AND RECEPTION

How to Enhance Women's Participation in Engineering Around the Globe

Wednesday, May 30, 2018 6:30 p.m. – 7:30 p.m. Harbor Island 3

Chairs: Cristina Amon – University of Toronto and Tanja Braun - Fraunhofer Institute for Reliability and Microintegration (IZM)



- Kawthar (Kat) Kasim, Boeing Research and Technology, USA
- 2. Jayathi Murthy, UCLA Dean of Engineering, USA
- 3. Li Ming, R&D Director, Enabling Technologies at ASM Pacific Technology, Hong Kong



2018 ECTC SPECIAL SESSION
Assembly Frontiers – New
Methods and Applications
Tuesday, May 29, 2018
2:00 p.m. – 3:30 p.m.

Grande Ballroom CChair: Florian Herrault – HRL Laboratories, LLC

Speakers:

- i. Jeffrey Demmin, DARPA
- 2. Hugo Pristauz, Besi Switzerland AG
- 3. Matthew Meitl, X-Celeprint
- 4. Doris Tang, PlayNitride
- 5. Val Marinov, Uniqarta



2018 PLENARY SESSION

Artificial Intelligence and Its Impact on System Design Wednesday, May 30, 2018 7:30 p.m. – 9:00 p.m. Harbor Island 1 & 2

Chair: Kemal Aygun – Intel Corporation

Speakers:

- I. Igor Arsovski, GLOBALFOUNDRIES
- 2. Kailash Gopalakrishnan, IBM Corporation
- 3. Andrew Putnam, Microsoft Corporation
- 4. Madhavan Swaminathan, Georgia Institute of Technology
- 5. Dan Oh, Samsung



2018 ECTC PANEL SESSION

I/C Package Co-Design for Heterogeneous Integrated Systems

Tuesday, May 29, 2018 7:45 p.m. – 9:15 p.m. Harbor Island I & 2

Chairs: Avi Bar-Cohen, IEEE EPS President
- Raytheon and Chris Bailey – University of
Greenwich



- Harrison Chang, Advanced Semiconductor Engineering, Inc.
- 2. John Parry, Mentor Graphics
- 3. Yong Liu, ON Semiconductor
- 4. Xuejun Fan, Lamar University
- Madhavan Swaminathan, Georgia Institute of Technology
- 6. Andrew Kahng, University of California, San Diego



2018 IEEE EPS SEMINAR

High Density Packaging Technologies in the Era of Big Data

> Thurday, May 31, 2018 8:00 p.m. – 9:30 p.m. Harbor Island I & 2

Chairs: Yasumitsu Orii - Nagase, Japan and Sheigenori Aoki – Fujitsu



Speakers:

- I. Shunichi Kikuchi, Fujitsu
- 2. Spike Narayan, IBM Research
- 3. Úrmi Ray, JCET StatsChipPac
- 4. Masato Tanaka, Shinko
- 5. Toshihisa Nonaka, Hitachi Chemical



PROFESSIONAL DEVELOPMENT COURSES
TUESDAY, MAY 29, 2018

TUESDAY, MAY 29, 2018			
Morning Courses 8:00 a.m. – 12:00 Noon	Afternoon Courses 1:15 p.m. – 5:15 p.m.		
Seabreeze I. Achieving High Reliability of Lead-Free Solder Joints – Materials Considerations Course Leader: Ning-Cheng Lee – Indium Corporation	Seabreeze 10. Flip Chip Fabrication and Interconnection Course Leaders: Eric Perfecto — GLOBALFOUNDRIES; Shengmin Wen — Synaptics Inc.		
Harbor Island I 2. Introduction to Fan-Out Wafer-Level Packaging Course Leader: Beth Keser – Intel Corporation	Harbor Island I II. Wafer-Level Chip-Scale Packaging Course Leader: Luu Nguyen - Texas Instruments, Inc.		
Harbor Island 2 3. Fundamentals of Glass Technology and Applications for Advanced Semiconductor Packaging Course Leaders: Aric Shorey and Jingshi Wu – Coming Inc.	Harbor Island 2 12. Flexible Hybrid Electronics – Manufacturing and Reliability Course Leader: Pradeep Lall – Auburn University		
Harbor Island 3 4. Future of Device and Systems Packaging in Post Moore's Law Course Leader: Rao Tummala – Georgia Institute of Technology	Harbor Island 3 13. Fan-Out Wafer-Level Packaging and 3D Packaging Course Leader: John Lau – ASM Pacific Technology Ltd.		
Spinnaker 5. Introduction to Mechanics- Based Quality and Reliability Assessment Methodology Course Leaders: Shubhada Sahasrabudhe and Sandeep Sane – Intel Corporation	Spinnaker 14. Polymers for Electronic Packaging Course Leader: Jeffrey Gotro – InnoCentrix, LLC		
Grande Ballroom A 6. Polymers and Nanocomposites for Electronic and Photonic Packaging Course Leaders: C. P. Wong – Georgia Institute of Technology; Daniel Lu – Henkel Corporation	Grande Ballroom A 15. Corrosion in Microelectronic Packages Course Leader: Varughese Mathew – NXP Semiconductors		
Nautilus 1 & 2 7. Fundamentals of RF Design and Fabrication Processes of Fan-Out Wafer/Panel-Level Packages and Interposers Course Leaders: Ivan Ndip and Markus Wöhrmann – Fraunhofer IZM	Nautilus I & 2 I6. Ageing of Polymers and the Influence on Microelectronic Package Reliability Course Leaders: Tanja Braun and Ole Hölck – Fraunhofer IZM		
Nautilus 3 & 4 8. Reliability Mechanics and Modeling for IC Packaging - Theory, Implementation and Practices Course Leaders: Ricky Lee – HKUST and Xuejun Fan – Lamar University	Nautilus 3 & 4 17. Solving Package Failure Mechanisms for Improved Reliability Course Leader: Darvin Edwards – Edwards Enterprises		
Nautilus 5 9. Integrated Thermal Packaging and Reliability of Power Electronics Course Leader: Patrick McCluskey —	Nautilus 5 18. Design and Optimization of Heat Sinks Course Leaders: Marc Hodes – Tufts University; Georgios Karamanis – Transport		



2018 ECTC/ITHERM YOUNG PROFESSIONALS PANEL AND RECEPTION

Tuesday, May 29, 2018 7:00 p.m. – 7:45 p.m. Harbor Island 3

Chair: Yan Liu – Medtronic, Inc.

ECTC and ITherm cordially invite young professionals (including current graduate students) to attend this networking event. The two panelists will talk about career development for young professionals based on their experiences and achievements in the industry and academia. A reception for panelists and attendees will follow.

Speakers:

- I. Steve Bezuk, Qualcomm Technologies, Inc.
- 2. Kathleen Kramer, University of San Diego

Tuesday, May 29, 2018 • 5:00 p.m. - 6:00 p.m. Host: Texas Instruments, Inc.

Executive Center 3

ECTC welcomes our student attendees and student presenters who bring their research results to our audience. The Student Reception is an event where students can get guidance for their job search from industry leaders. In addition to the Student Reception, in the Student Interactive Presentation Session, we provide our audience one-on-one access to students and their research. We encourage you to attend the Student Interactive Presentation Session on Friday in the Nautilus Foyer. This reception is sponsored by Texas Instruments, Inc.

GENERAL CHAIR'S SPEAKERS RECEPTION Tuesday, May 29, 2018 • 6:00 p.m. - 7:00 p.m.

Grande Ballroom B

Invited session chairs and speakers are requested to attend the reception.

TECHNOLOGY CORNER RECEPTION Wednesday, May 30, 2018 • 5:30 p.m. - 6:30 p.m.

Bayview Pavilion

An Exhibitor Sponsored Reception will be held in the Bayview Pavilion. All attendees and guests are invited.

68th ECTC GALA RECEPTION Thursday, May 31, 2018 • 6:30 p.m.

Outisde at the Bayview Lawn; (Rain Back Up – Grande Ballroom)

All badged attendees and guests are invited to attend our Gala Reception outside at the Bayview Lawn.

CONTINUING EDUCATION UNITS

The IEEE Electronics Packaging Society (EPS) has been authorized to offer Continuing Education Units (CEUs) by the International Association for Continuing Education and Training (IACET) for all Professional Development Courses that will be presented at the 68th ECTC. CEUs are recognized by employers for continuing professional development as a formal measure of participation and attendance in "non-credit" self-study courses, tutorials, symposia, and workshops. Complete details, including voluntary enrollment forms, will be available at the conference. All costs associated with ECTC Professional Development Course CEUs will be underwritten by the conference, i.e., there are no additional costs for Professional Development Course attendees to obtain CEU credit.

Phenomena Technologies, LLC.

University of Maryland

2017 ECTC BEST PAPER AWARDS

BEST OF CONFERENCE PAPERS – 2017

The Electronic Components and Technology Conference is proud to announce the "Best of Conference" papers selected from the 67th ECTC proceedings. The authors of the Best Session Paper share a check for US \$2,500, and the authors of the Best Interactive Presentation share a check for US \$1,500. The winning authors also receive a personalized plaque commemorating their achievement.

Best Session Paper

Session 28, Paper 3

High Thermal Conductivity Mold Compounds for Advanced Packaging Applications

Makoto Shibuya & Luu Nguyen — Texas Instruments, Inc.

Best Interactive Presentation Paper

Session 39, Paper 6

Development of Die Attachment Technology for Power IC Module by Introducing Indium into Sintered Nano-silver Joint

C. A. Yang, C. Robert Kao – National Taiwan University; and H. Nishikawa – Osaka University

INTEL BEST STUDENT PAPER – 2017

The winning student receives a personalized plaque and a check for US \$2,500. The following paper was selected based on the Intel Best Student Paper competition conducted at the 67th ECTC:

Session 2, Paper 7

Latency, Bandwidth and Power Benefits of the Super CHIPS Integration Scheme

Siva Chandra Jangam, Saptadeep Pal, Adeel Bajwa, Sudhakar Pamarti, Puneet Gupta, and Subramanian lyer — University of California, Los Angeles

OUTSTANDING PAPERS – 2017

The winning authors for the Conference Outstanding Session Paper and Interactive Presentation selected from the 67th ECTC proceedings receive a personalized plaque commemorating their achievement and will share a check for US \$1,000.

Outstanding Session Paper

Session 18, Paper 4

Warpage Modeling and Characterization of the Viscoelastic Relaxation for Cured Molding Process in Fan-Out Packages

Shu-Shen Yeh, Po-Yao Lin, Kuang-Chun Lee, Jin-Hua Wang, Wen-Yi Lin, Ming-Chih Yew, Po-Chen Lai, Shyue-Ter Leu, and Shin-Puu Jeng — Taiwan Semiconductor Manufacturing Company, Ltd.

Outstanding Interactive Presentation

Session 40, Paper 8

Via-in-Trench: A Revolutionary Panel-based Package RDL Configuration capable of 200-450 IO/mm/ layer, an Innovation for More-Than-Moore System Integration

Fuhan Liu, Chandrasekharan Nair, Hao Lu, Rui Zhang, Hang Chen, Venky Sundaram, and Rao R. Tummala — Georgia Institute of Technology; Atsushi Kubo and Tomoyuki Ando — Tokyo Ohka Kogyi; Kwon Sang Lee — Disco Corporation

TEXAS INSTRUMENTS OUTSTANDING STUDENT INTERACTIVE PRESENTATION — 2017

The winning student receives a personalized plaque and a check for US \$500. The following paper was selected based on the Texas Instruments Outstanding Student Interactive Presentation competition conducted at the 67th ECTC:

Session 39, Paper 6 Development of Die Attachment Technology for Power IC Module by Introducing Indium into Sintered Nano-Silver Joint

Chun An Yang and C. Robert Kao — National Taiwan University; Hiroshi Nishikawa — Osaka University

COMMITTEE MEETINGS • ASSOCIATED COMMITTEE MEMBERS ONLY

Tuesday, May 29, 2018

8:00 a.m. - 5:00 p.m.

Heterogeneous Integration Roadmap Workshop Executive Center 1 & 4

9:00 p.m. - 10:30 p.m.

ECTC Optoelectronics Committee 518, 5th Floor

9:00 p.m. - 10:30 p.m.

ECTC Interconnections Committee 411, 4th Floor

Wednesday, May 30, 2018

7:00 a.m. – 8:00 a.m. EPS Power & Energy TC

514, 5th Floor

4:30 p.m. – 5:30 p.m.

EPS Technical Committee Chairs 511, 5th Floor

6:00 p.m. - 7:00 p.m.

Program Subcommittee Chairs & Assistant Chairs Reception General Chair's Suite (by invitation only)

Thursday, May 31, 2018

7:00 a.m. - 8:00 a.m.

EPS Region 8 Meeting Seabreeze

7:00 a.m. - 8:00 a.m.

EPS Nanotechnology TC 511, 5th Floor

7:00 a.m. – 8:00 a.m. EPS High Density Substrates & Boards TC 514, 5th Floor

7:00 a.m. - 8:00 a.m.

EPS Region 10 Meeting Spinnaker 1

7:00 a.m. - 8:00 a.m.

EPS Reliability TC Spinnaker 2

9:00 a.m. - 10:00 a.m.

ECTC High-Speed, Wireless & Components Committee Marina 2

5:30 p.m. – 6:30 p.m.

ECTC 2019 Program Committee Meeting Harbor Island 3

8:00 p.m.

68th ECTC Steering/Executive Committee Reception General Chair's Suite

Friday, June 1, 2018

7:00 a.m. - 8:00 a.m.

EPS Transaction Editors TC / AEs 511, 5th Floor

7:00 a.m. – 8:00 a.m.

EPS RF & THz Techn. TC/ECTC Components Committee 514, 5th Floor

7:00 a.m. - 8:00 a.m.

EPS Emerging Technologies TC Spinnaker 1

7:00 a.m. - 8:00 a.m.

EPS Electrical Design, Modeling & Simulation TC Spinnaker 2

I:30 p.m. – 4:30 p.m.

ECTC Executive Committee
Executive Center 3

4:45 p.m. - 5:45 p.m.

ECTC Steering Committee Executive Center 3

Program Sessions: Wednesday, May 30, 8:00 a.m 11:40 a.m.			
Session 1: Flexible Electronics, Substrate for High Frequency Applications	Session 2: Advances in Wafer and Panel- Level Fan-Out Packaging	Session 3: 3D Design, Assembly and Additive Manufacturing	
Committee: Materials & Processing	Committee: Advanced Packaging	Committee: Emerging Technologies joint with Advanced Packaging	
Room: Harbor Island I	Room: Harbor Island 2	Room: Harbor Island 3	
Session Co-Chairs: Yan Liu – Medtronic Inc. USA Email: yan.x.liu@medtronic.com Lejun Wang – Qualcomm Technologies, Inc. Email: lejunw@qti.qualcomm.com	Session Co-Chairs: Beth Keser – Intel Corporation Email: beth.keser@intel.com Mike Ma – Amkor Technology Taiwan (ATT) Email: mike.ma@amkor.com	Session Co-Chairs: Benson Chan - Binghamton University Email: chanb@binghamton.edu John Knickerbocker - IBM Corporation Email: knickerj@us.ibm.com	
I. 8:00 AM - In-Situ Stress Determination of Electroless Cu on PCB-relevant Substrates Tobias Bernhard, L. Gregoriades, E. Steinhäuser, S. Kempa, and F. Brüning – Atotech Deutschland GmbH; Ralf Bruening, T. Sharma, D. Brown, and E. A. Luy – Mount Allison University	I. 8:00 AM - A Novel Submicron Polymer Redistribution Layer Technology for Advanced InFO Packaging Han-Ping Pu, H.J. Kuo, C.S. Liu, and Douglas C.H. Yu — Taiwan Semiconductor Manufacturing Company, Ltd.	1. 8:00 AM - Novel Failure Analysis Techniques for 1.8 µm Pitch Wafer-to-Wafer Bonding Christian Schmidt and Lorenz Lechner - ZEISS; Ingrid De Wolf, Soon-Wook Kim and Eric Beyne - IMEC	
2. 8:25 AM - Stretchable, Printable and Electrically Conductive Composites for Wearable RF Antennas Bo Song, Ryan Bahr, Fan Wu, Kyoung-sik Moon, Manos Tentzeris, and C.P. Wong – Georgia Institute of Technology	2. 8:25 AM - Fan-Out Panel Level Package With Fine-Pitch Pattern Jinyoung Kim, Ikjun Choi, JunHyeong Park, Jae-Ean Lee, TaeSung Jeong, Jungsoo Byun, Young Gwan Ko, and Kangheon Hur – Samsung Electro-Mechanics Co., Ltd.; Dae-Woo Kim and Kyung Suk Oh - Samsung Electronics	2. 8:25 AM - Column Interconnects: A Path Forward for Embedded Cooling of High- Power 3D Chip Stacks Mark Schultz, Cyril Cabral, Joana Maria, Paul Andry, Qianwen Chen, and Timothy Chainer – IBM Corporation; Cornelia Tsang Yang – Raytheon	
3. 8:50 AM - A Study on the Anchoring Polymer Layer (APL) Solder Anisotropic Conductive Films (ACFs) for Ultra Fine Pitch Flex-On-Flex (FOF) Assembly Using an Ultrasonic Bonding Method Dal-Jin Yoon, Sang Hoon Lee, and Kyung-Wook Paik – Korea Advanced Institute of Science and Technology	3. 8:50 AM - Ultra Fine RDL Structure Fabrication Using Alternative Patterning and Bottom-Up Plating Processes Richard Hollman – TEL Advanced Packaging.; Ognian Dimov and Sanjay Malik – Fujifilm Electronic Materials U.S.A., Inc.; Markus Arendt and Habib Hichri – SUSS Microtec Photonic Systems, Inc.	3. 8:50 AM - Assembly Process Development of Ultra Large Scale 3D Stacking with Transmission Circuits Via TSVs Shunichi Kikuchi, Hidehiko Kira, Makoto Suwada, and Tatsumi Nakada – Fujitsu Limited; Naoaki Nakamura, Norio Kainuma, Kazuhiro Kanai, and Takumi Masuyama – Fujitsu Advanced Technologies Limited	
Refreshmen	t Break: 9:15 a.m 10:00 a.m. Bayvi	ew Pavilion	
4. 10:00 AM - Development of Novel BT Laminate Material for Low-Loss and High-Speed Transmission Masahiko Shigaki, Mika Suzuki, Takashi Kobayashi, Kentarou Takano, Takaki Tsuchida, Sotaro Hiramatsu, Yoshitaka Ueno, Tsuyoshi Kida, Shu Yoshida, and Toyoji Oshima – Mitsubishi Gas Chemical Company, Inc.	4. 10:00 AM - Low-Cost Si-Less RDL Interposer Package for High-Performance Computing Applications Kyoung-Lim Suk, Seok Hyun Lee, Jong Youn Kim, Seok Won Lee, Hak Jin Kim, Su Chang Lee, Pyung Wan Kim, Dae-Woo Kim, and Dan (Kyung Suk) Oh – Samsung Electronics Co., Ltd.; Jung Soo Byun – Samsung Electro-Mechanics Company, Ltd.	4. 10:00 AM - The Principles of "Smart" Encapsulation: Using Additive Printing Technology for the Realization of Intelligent Application-Specific Packages for 10T, 5G, and Automotive Radar Applications Bijan Tehrani, Ryan Bahr, and Manos Tentzeris – Georgia Institute of Technology; Daniel Revier and Benjamin Cook – Texas Instruments, Inc.	
5. 10:25 AM - Organic Substrate Material With Low Transmission Loss and Effective in Suppressing Package Warpage for 5G Application Shunsuke Tonouchi, Etsuo Mizushima, Tomio Fukuda, Tomokazu Shimada, Yukio Nakamura, and Toshiyuki lijima – Hitachi Chemical Company, Ltd.	5. 10:25 AM - Panel Level Packaging - A View Along the Process Chain T. Braun, K. F. Becker, O. Hoelck, R. Kahle, M. Wöhrmann, L. Boettcher, M. Topper, L. Stobbe, H. Zedel and R. Aschenbrenner – Fraunhofer IZM; S. Voges, M. Schneider-Ramelow, K. D. Lang - Technical University Berlin	5. 10:25 AM - A New Microsystem Packaging Approach Using 3D Printing Encapsulation Process Gabrielle Aspar, Baptiste Goubault de Brugiere, Jean- Charles Souriau, Laetitia Castagne, Gilles Simon, and Lea Di Cioccio – CEA-LETI; Yves Brechet – CEA	
6. 10:50 AM - Porous Epoxy Film for Low Dielectric Constant Chip Substrates and Boards Jisu Jiang, Oluwadamilola Phillips, Landon Keller and Paul Kohl – Georgia Institute of Technology	6. 10:50 AM - Patterning High-Resolution Features Through the Integration of an Advanced Lithography System With a Novel Nozzleless Spray Coating Technology Jack Mach and Corey Shay – Rudolph Technologies, Inc.; Stuart Erickson – Ultrasonic Systems Inc.; Gary Smith - Sumitomo Chemical Advanced Technologies	6. 10:50 AM - A Design Study of 3D Printed Reduced Height Waveguide Structures Vincens Gjokaj and Premjeet Chahal – Michigan State University	
7. I I:15 AM - Development of Multi- Layered Build-Up Insulation Dry-Film Material for Ultra-Low Transmission Loss Wirings for High-Speed Semi-Conductor Packaging Zhong Guan and Arata Endo – Taiyo Ink Mfg. Co. Ltd.; Tadahiko Hanada – Taiyo America, Inc.	7. 11:15 AM - Extreme Thinned-Wafer Bonding Using Low-Temperature Curable Polyimide for Advanced Wafer Level Integrations Julien Bertheau, Fumihiro Inoue, Alain Phommahaxay, Serena Iacovo, Ian Peng, Erik Sleeckx, Kenneth Rebibis, Andy Miller, Gerald Beyer, Eric Beyne, and Nouredine Rassoul – IMEC; Atsushi Nakamura – Fujifilm	7. I I:15 AM - Self-Powered, Inkjet Printed Electrochromic Films on Flexible and Stretchable Substrate for Wearable Electronics Applications Ebraheem Azhar, Hongbin Yu, and Terry Alford – Arizona State University	

Program Sessions:	Wednesday, May 30, 8:00	a.m 11:40 a.m.
Session 4: Automotive and Harsh Environment Reliability	Session 5: Antenna-in-Package for RF and mm-Wave Systems	Session 6: Warpage and Moisture Characterization
Committee: Applied Reliability	Committee: High-Speed, Wireless & Components	Committee: Thermal/Mechanical Simulation & Characterization
Room: Nautilus I & 2	Room: Nautilus 3 & 4	Room: Nautilus 5
Session Co-Chairs: Varughese Mathew – NXP Semiconductors Email: varughese.mathew@nxp.com Vikas Gupta – Texas Instruments, Inc. Email: gvikas@ti.com	Session Co-Chairs: Maciej Wojnowski – Infineon Technologies AG Email: maciej.wojnowski@infineon.com Prem Chahal – Michigan State University Email: chahal@msu.edu	Session Co-Chairs: Przemyslaw Gromala – Robert Bosch GmbH Emall: Przemyslawjakub.gromala@de.bosch.com Jiantao Zheng – Qualcomm Technologies, Inc. Email: jiantaoz@qti.qualcomm.com
1. 8:00 AM - Novel Corrosion Prevention Treatments for Cu Wire Bonded Device to Improve Bonding Reliability Muthappan Asokan, Oliver Chyan, Joshua Caperton, and Zachary Thompson – University of North Texas; Mahmud Chowdhury, Shawn O' Connor, and Luu Nguyen – Texas Instruments, Inc.	I. 8:00 AM - Small Shielded Bluetooth Module Equipped with Slot Antenna on the Surface Keiju Yamada, Makoto Sano, Makoto Higaki, and Akihiko Happoya – Toshiba Corporation	I. 8:00 AM - A Novel Finite Element Technique for Moisture Diffusion Modeling using ANSYS Cagan Diyaroglu – University of Arizona; Selda Oterkus and Erkan Oterkus – University of Strathcly
2. 8:25 AM - A Monte Carlo Approach to Predicting Failure Across Multiple Temperature and Humidity Field Environments Ionathon Tucker, Ramji Dhakal, George Thiel, and Virendra Jadhav – Microsoft Corporation	2. 8:25 AM - A 77 GHz Antenna-in-Package with Low-Cost Solution for Automotive Radar Applications Cheng Yu Ho, Sheng-Chi Hsieh, Ming-Fong Jhong, Chen-Chao Wang, and Chun-Yen Ting – Advanced Semiconductor Engineering, Inc.	2. 8:25 AM - Adaptive Curvature Flexure Te to Assess Flexible Electronic Systems Rui Chen, Justin Chow, Christine Taylor, and Suresh Sitaraman – Georgia Institute of Technology; Jeffrey Meth - DuPont Electronics & Imaging
3. 8:50 AM - Improve Interconnect Reliability of BGA Substrate with Stacked Vias by Reducing Carbon Inclusion in the Interface between Via and Land Pad Kejun Zeng and Jaimal Williamson – Texas Instruments, Inc.	3. 8:50 AM - An Enhanced 64-Element Dual-Polarization Antenna Array Package for W-band Communication and Imaging Applications Xiaoxiong Gu, Duixian Liu, Christian Baks, Jean-Oliver Plouchart, Wooram Lee, and Alberto Valdes-Garcia – IBM Corporation	3. 8:50 AM - Parametric Optimization and Yield Probability Prediction of Package Warpage Shenghua Huang, Zhongli Ji, Ning Ye, Yangming Liu, and Hem Takiar – Western Digital Corporation
Refreshment	 t Break: 9:15 a.m 10:00 a.m. Bayvi	ew Pavilion
4. 10:00 AM - Understanding Underfill Degradation in Reliability Testing Conditions for ADAS Packages Development Ziyin Lin, Vijay Subramanian, Pramod Malatkar, and Nisha Anathakrishnan - Intel Corporation	4. 10:00 AM - InFO_AiP Technology for High-Performance and Compact 5G Wave System Integration Chuei-Tang Wang, Tzu-Chun Tang, Chun-Wen Lin, Che-Wei Hsu, Jeng-Shien Hsieh, Chung-Hao Tsai, Kai-Chiang Wu, Han-Ping Pu, and Douglas Yu – Taiwan Semiconductor Manufacturing Company	4. 10:00 AM - An Integrated Warpage Prediction Model Based on Chemical Shrinkage and Viscoelasticity for Molded Underfill Shu-Shen Yeh, Po-Yao Lin, Kuang-Chun Lee, Jin-Hua Wang, Wen-Yi Lin, Ming-Chih Yew, Po-Chen Lai, Chia-Kuei Hsu, Che-Chia Yang, and Shin-Puu Jeng — Taiwan Semiconductor Manufacturing Company
5. 10:25 AM - Quantification and Modeling of Microstructural Evolution in Lead-Free Solders During Long Term Isothermal Aging Sudan Ahmed, Jing Wu, Nianjun Fu, Jeffrey Suhling, and Pradeep Lall – Auburn University	5. 10:25 AM - Mm-Wave Antenna in Package (AiP) Design Applied to 5th Generation (5G) Cellular User Equipment Using Unbalanced Substrate Ying-Wei Lu, Bo-Siang Fang, Hsuan-Hao Mi, and Kuan-Ta Chen – Siliconware Precision Industries Co., Ltd.	5. 10:25 AM - Trend Plots for Different Mold-thick Selection on Warpage Design of MUF FCCSP with 4L ETS Chih-Sung Chen, Nicholas Kao, and Don Son Jiang – Siliconware Precision Industries Co. Ltd.
6. 10:50 AM - Reliability Enhancement of Automotive Electronic Modules Using Various Glues Dongji Xie, Zhongming Wu, Joe Hai, and Manthos Economou – Nvidia Corp.	6. 10:50 AM - Novel 3D-/Inkjet-Printed Flexible On-Package Antennas, Packaging Structures, and Modules for Broadband 5G Applications Tong-Hong Lin, Ryan A. Bahr, Manos M. Tentzeris, P. Markondeya Raj, Venky Sundaram, and Rao Tummala – Georgia Institute of Technology	6. 10:50 AM - Numerical/Experimental Hybrid Approach to Predict Warpage of Thin Advanced Substrates Byung Kim and Bongtae Han – University of Marylan
7. II:15 AM - High-Temperature and Moisture Ageing Reliability of High-Density Power Packages for Electric Vehicles Shreya Dwarakanath, P. Markondeya Raj, Vanessa Smet, Venky Sundaram, Mark Losego, and Rao Tummala – Georgia Institute of Technology	7. II:15 AM - A Compact 27 GHz Antenna- in-Package (AiP) With RF Transmitter and Passive Phased Antenna Array Mei Xue and Delong Qiu Institute of Microelectronics of Chinese Academy of Sciences; Liqiang Cao University of Chinese Academy of Sciences; Qidong Wang and Jun Li National Center for Advanced Packaging	7. II:15 AM - Warpage and Thermal Stress Under Thermal Cycling Test in SiC and Si Power Device Structures Using Direct Chip-Bonding with Ag Sintered Layer on Cu Plate Masaki Kanemoto, Masaaki Aoki, and Nobuhiko Nakano – Keio University; Akihiro Mochizuki, Yoshik Murakami, and Mutsuharu Tsunoda – MacDermid Performance Solutions

Program Sessions: Wednesday, May 30, 1:30 p.m 5:10 p.m.			
Session 7: Low-Temperature Metallic Interconnection Technologies	Session 8: Fan-Out Packaging- Applications and Architectures	Session 9: Flip-Chip Manufacturing Challenges	
Committee: Interconnections	Committee: Advanced Packaging	Committee: Assembly & Manufacturing Technology	
Room: Harbor Island I	Room: Harbor Island 2	Room: Harbor Island 3	
Session Co-Chairs: David Danovitch – University of Sherbrooke Email: David.Danovitch@USherbrooke.ca Matthew Yao – GE Energy Management Email: matthew.yao@ge.com	Session Co-Chairs: Bora Baloglu – Amkor Technology Email: bora.baloglu@amkor.com Kuo-Chung Yee-TSMC Email: kcyee@tsmc.com	Session Co-Chairs: Jae-Woong Nah - IBM Corporation Email: jnah@us.ibm.com Garry Cunningham - NGC Email: Garry.Cunningham@ngc.com	
I. I:30 PM - Laser Sintering of Dip-Based All-Copper Interconnects Luca Del Carro, Thomas Brunschwiler – IBM Corporation; Martin Kossatz, Lucas Schnackenberg, Matthias Fettke – Pac Tech - Packaging Technologies GmbH; Ian Clark – Intrinsiq Materials Ltd.	I. I:30 PM - Millimeter-Wave Antenna in Fan-Out Wafer Level Packaging for 60 GHz WLAN Application Zihao Chen, Lim Tech Guan, David Soon We Ho, and Surya Bhattacharya – Institute of Microelectronics, A*STAR, Singapore	1. 1:30 PM - Low-Temperature Assembly of Surface-Mount Device on Flexible Substrate using Additive Printing Process Christine Taylor, Vanessa Smet, Xuanke He, Manos Tentzeris, and Suresh Sitaraman – Georgia Institute of Technology	
2. 1:55 PM - Low-Temperature Fine- pitch Wafer-level Cu-Cu Bonding Using Nanoparticles Fabricated by PVD Zijian Wu, Qian Wang, Changming Song, and Jian Cai – Institute of Microelectronics, Tsinghua University	2. 1:55 PM - 3D Heterogeneous Integration with Multiple Stacking Fan-Out Package Feng-Chen Hsu, Jackson Li, Shuo-Mao Chen, Po-Yao Lin, Jerry Fang, Jin-Hua Wang and Shin-Puu Jeng - TSMC	2. 1:55 PM - Evaluation of Chip-last Fan-out Panel Level Packaging with G2.5 LCD Facility Using FlexUP(TM) and Mechanical De-bonding Technologies Wei-Yuan Cheng, Yuh-Zheng Lee, Chen-Tsai Yang, Jie-Mo Lin, Tai-Jui Wang, and Wei-Han Chen – Industrial Technology Research Institute	
3. 2:20 PM - Transient Liquid Phase Bonding Using AgSn-Alloys for Stress Reduced Sensor Mounting Markus Feisst, Jun Yu, and Juergen Wilde – University of Freiburg, IMTEK	3. 2:20 PM - Study of Advanced Fan-Out Packages for Mobile Applications Taejoo Hwang, Dan (Kyung Suk) Oh, Eunseok Song, Kilsoo Kim, Seokwon Lee, and Jaechoon Kim – Samsung Electronics Company, Ltd.	3. 2:20 PM - Design and Application of Innovative Multi-Table and Bond Head Drive System on Thermal Compression Bonder with UPH over 2000 Kohei Seyama, Shoji Wada, Yuji Eguchi, and Tomonori Nakamura – Shinkawa Ltd.; Shigetoshi Sugawa – Tohoku University; Doug Day - Shinkawa USA, Inc.	
Refreshmer	∣ nt Break: 2:45 p.m 3:30 p.m. Bayvie	ew Pavilion	
4. 3:30 PM - Demonstration of Patternable All-Cu Compliant Interconnections with Enhanced Manufacturability in Chip-to- Substrate Applications Kashyap Mohan, Ninad Shahane, Ramon Sosa, Raj Pulugurtha, Antonia Antoniou, Vanessa Smet, and Rao Tummala – Georgia Institute of Technology; Sadia Khan - Texas Instruments, Inc	4. 3:30 PM - An RDL-First Fan-out Wafer Level Package for Heterogeneous Integration Applications Y. M. Lin, S. T. Wu, W. W. Shen, S. Y. Huang, T. Y. Kuo, A. Y. Lin, T. C. Chang, H. H. Chang, and S. M. Lee – Industrial Technology Research Institute (ITRI); C. H. Lee, J. Su, X. Liu, and Q. Wu – Brewer Science Taiwan; K. N. Chen – National Chiao Tung University	4. 3:30 PM - Adhesion Property of Polyimide and Passivation Layer for Polymer/ Metal Wafer-level Hybrid Bonding in 3D Integration Cheng-Hsien Lu, Yi-Tung Kho, Yu-Tao Yang, and Kuan-Neng Chen – National Chiao Tung University; Chiao-Pei Chen, Yu-Pei Chen, Chiu-Feng Chen, and Tsuang-Tai Hung - Taiflex Scientific Corporation	
5. 3:55 PM - Development of Low- Temperature, Presssureless Copper-to- Copper Bonding by Microfluidic Electroless Interconnection Process Sean Yang, H. T. Hung, and C. Robert Kao – National Taiwan University; H. Nisikawa – Joining and Welding Institute Osaka University	5. 3:55 PM - Chip-First Fan-Out Panel-Level Packaging for Heterogeneous Integration C. T. Ko, H. Lang, C. Lin, J. W. Lin, Y. H. Chen - Unimicron Technology Corp.; J. Lau, M. Li, M. Li, N. Fan, Y. M. Cheung, E. Ng, W. Kai, J. Hao, M. Li - ASM Pacific Technology Ltd.; T. Chen, I. Xu, Z. Li, K. H. Tan - Jiangyin Changdian Advanced Packaging Co. Ltd.; C. L. Chang, J. Y. Pan, H. H. Wu, R. Beica, M. Lin - The Dow Chemical Company, Q. X. Wong, Z. Cheng, K. S. Wee, J. Ran, C. Xi - Huawei Technologies Co., Ltd.; S.P. Lim, N.C. Lee- Indium Corporation; M. Tao, J. Lo, R. Lee - Hong Kong University of Science and Technology	5. 3:55 PM - Advances in Memory Die Stacking Oranna Yauw, Daniel Buergi, Jie Wu, Andreas Marte, Horst Clauberg, and Bob Chylak – Kulicke and Soffa, Inc.; Urban Ernst - Kulicke & Soffa Switzerland; Ulrich Barthold and Ulf Friederichs - CADFEM GmbH	
6. 4:20 PM - Scaling Packaging Interconnect Below 20 µm With Hybrid Bonding Guilian Gao, Laura Mirkarimi, Gill Fountain, Liang Wang, Cyprian Uzoh, Thomas Workman, Gabe Guevara, Chandrasekhar Mandalapu, Bongsub Lee, and Rajesh Katkar – Xperi	6. 4:20 PM - Design and Fabrication of Feasible 3D Optoelectronics Integration Based on Embedded IC Fanout Technology Fengman Liu – Institute of Microelectronics, Chinese Academy of Science; Xueping Guo, Fengze Hou, Haiyun Xue, Yu Sun, Huimin He, Zhaoyao Y, Wenqi Zhang and Liqiang Cao - System Packaging and Integration Center/ Institute of Microelectronics, Chinese Academy; Qian She - National Center for Advanced Packaging	6. 4:20 PM - Plasma Treatment for Fluxless Flip-Chip Chip-Joining Process Maxime Godard, Dominique Drouin, and Maxime Darnon – Université de Sherbrooke; Serge Martel and Clément Fortin – IBM Corporation	
7. 4:45 PM - Micro-Silver Sinter Paste Developed for Pressure Sintering on Bare Cu Surfaces Under Air or Inert Atmosphere Ly May Chew, Wolfgang Schmitt, Christian Schwarzer and Jens Nachreiner – Heraeus Deutschland GmbH & Co. KG	7. 4:45 PM - A Novel Fan-Out Concept for Ultra-High Chip-to-Chip Interconnect Density with 20 µm Pitch Arnita Podpod, John Slabbekoom, Alain Phommahaxay, Fabrice Duval, Abdellah Salahouelhadj, Mario Gonzalez, Kenneth Rebibis, Andy Miller, Gerald Beyer, and Eric Beyne – IMEC	7. 4:45 PM - Effects of Laser Selective Reflow on Solder Joint Microstructure and Reliability Luke Wentlent – Universal Instruments Corp.; Mohammed Genanu, Thaer Alghoul, and Peter Borgesen – Binghamton University; Jim Wilcox – Universal Instruments Corp; Francis Mutuku – Indium Corporation	

Program Sessions:	Wednesday, May 30, 1:30	р.т 5:10 р.т.
Session 10: Innovative Design, Modeling and Predictions for Reliability	Session 11: Emerging Packaging Technologies for 5G and Advanced Computing	Session 12: Sintering Pastes, Transient Liquid Phase and Direct Bonding
Committee: Applied Reliability	Committee: Emerging Technologies	Committee: Materials & Processing
Room: Nautilus I & 2	Room: Nautilus 3 & 4	Room: Nautilus 5
Session Co-Chairs: Tim Chaudhry – Amkor Technology, Inc. Email: timchaudhry@gmail.com Lakshmi N. Ramanathan – Microsoft Corporation Email: laramana@microsoft.com	Session Co-Chairs: Vaidyanathan Chelakara – Acacia Communications Email: cvaidyanathan@acacia-inc.com Ramakrishna Kotlanka – Analog Devices Email: rama.krishna@analog.com	Session Co-Chairs: Dwayne Shirley – Inphi Email: shirley@leee.org Mikel Miller – EMD Performance Materials Email: mikel.miller@emdgroup.com
I. 1:30 PM - Die Attach Delamination Analysis and Modeling Between Temperature Cycling and Thermal Shock for Exposed Pad Lead Frame Devices Madison Koziol, Yutaka Suzuki, Siva Gurrum, and Muhammad Khan – Texas Instruments, Inc.	I. I:30 PM - Modeling and Design of a 3D Interconnect Based Circuit Cell Formed with 3D SiP Techniques Mimicking Brain Neurons for Neuromorphic Computing Applications M. Miao, L. Wang, T. Chen, X. Duan, J. Zhang, and N. Li – Beijing Information Science and Technology University; L. Sun, R. Fang, X. Sun, H. Liu and Y. Jin – Peking University	I. I:30 PM – Pressure-less Sintering of Large Dies Using Infrared Radiation and Optimized Silver Sinter Paste Wolfgang Schmitt and Ly May Chew – Heraeus Deutschland GmbH & Co. KG; Robert Miller – Hochschule Aschaffenburg, University of Applied Sciences
2. 1:55 PM - A Comparison Study of Cu Dissolution Kinetics in Solder Joints Under Electromigration and Extended Reflow Pilin Liu, Alan Overson, and Deepak Goyal – Intel Corporation	2. 1:55 PM - Surface Mount Electroosmotic Pump for Integrated Microfluidic Printed Circuit Boards Sarkis Babikian and G. P. Li – University of California, Irvine; Makoto Jinsenji – OM Sangyo Co. Ltd; Mark Bachman – Integra Devices	2. I:55 PM - Direct Bonding Silver to Aluminum Using Eutectic Reaction in Air Shao-Wei Fu and Chin C. Lee – University of California, Irvine
3. 2:20 PM - Anand Parameters for Modeling Prolonged Storage on High Strain Rate Mechanical Properties of SAC-Q Leadfree Solder at High Operating Temperature Pradeep Lall, Vikas Yadav, and Jeff Suhling – Auburn University; David Locker – US Army AMRDEC	3. 2:20 PM - Cryogenic Qubit Integration for Quantum Computing Rabindra Das, Danna Rosenberg, David Kim, Jonilyn Yoder, Donna-Ruth Yost, David Hover, Andrew Kerman, Justin Mallek, Vladimir Bolkhovsky, and William Oliver – MIT Lincoln Laboratory	3. 2:20 PM - Effects of the Interlayer Thickness and Alloying on the Reliability of Transient Liquid Phase (TLP) Bonding Junghyun Cho and Fei Dong – Binghamton University; Liang Yin and David Shaddock – GE Global Research
Refreshment	t Break: 2:45 p.m 3:30 p.m. Bayvie	ew Pavilion
4. 3:30 PM - Innovative Design of Crackstop Wall for I4nm Technology Node and Beyond Mohamed Rabie, Nicholas Polomoff, Md Khaled Hassan, Victoria Calero-DdelC, Danielle Degraw, Michael Hecker, Michael Thiele, and El Mehdi Bazizi – GLOBALFOUNDRIES	4. 3:30 PM - A Novel Structure for Backside Protection Against Physical Attacks on Secure Chips or SiP Stephan Borel, Edouard Deschaseaux, Jean Charbonnier, L. Duperrex, Jessy Clediere, Romain Wacquez, Jacques Fournier, Jean-Charles Souriau, Gilles Simon, and Alain Merle – CEA-LETI	4. 3:30 PM - Nano-Cu Sintering Paste for High-Power Devices Die Attach Applications Jinjin Zhao, Ning-Cheng Lee, Hiroshi Yamaguchi, and Min Yao – Indium Corporation
5. 3:55 PM - Back-end-of-line (BEOL) Mechanical Integrity Evaluation: A Mixed-Mode Double Cantilever Beam Test for Crackstop Strength Assessment Max Cioban, Tuhin Sinha, and Thomas Shaw – IBM Corporation	5. 3:55 PM - Supply-Chain Security Enhancement by Chaotic Wireless Chip- Package-Board Interactive PUF Masanori Takahashi, Makoto Nagata, and Noriyuki Miura – Kobe University	5. 3:55 PM - Transient Liquid Phase Sintering Using Copper-Solder-Resin Composite for High-Temperature Power Modules Hiroaki Tatsumi and Takeshi Monodane – Mitsubishi Electric Corporation; Adrian Lis, Yoshihiro Kashiba, and Akio Hirose – Osaka University
6. 4:20 PM - Study of the Long-Term Reliability of 3D IC under Near-Application Conditions Omar Ahmed, Golareh Jalilvand, Jessica Dieguez, and Tengfei Jiang – University of Central Florida; Peng Su – Juniper Networks	6. 4:20 PM - Interconnect Technology Development for 180 GHz Wireless mm- Wave System-in-Foil Transceivers Krzysztof Nieweglowski, David Fritsche, Patrick Seiler, Sebastian Lüngen, Corrado Carta, Frank Ellinger, Dirk Plettemeier, and Karlheinz Bock – Technical University Dresden	6. 4:20 PM - Detection of Liquefaction by DSC for Cu-Sn TLP bonding Sylvain Lemettre, Nathalie Isac, Sana Hammami, Seonho Seok, Johan Moulin, and Alain Bosseboeuf – C2N; Pierre Alphonse – CIRIMAT
7. 4:45 PM - The Experimental and Numerical Study of Electromigration in 2.5D Packages Jiefeng Xu, Yuling Niu, Stephen R. Cain, and S.B. Park - Binghamton University; Scott McCann, Hohyung Lee, and Gamal Refai-Ahmed – Xilinx, Inc.	7. 4:45 PM - Long Range LiDAR Characterisation for Obstacle Detection for Use by the Visually Impaired and Blind Rosemary O'Keeffe, Cian O'Murchu, and Alan Mathewson – Tyndall National Institute; Salvatore Gnecchi and Steven Buckley – SensL	7. 4:45 PM - High-Performance Metal-based Nanocomposite Thermal Interface Materials Toward Enhanced Cooling Efficiency in Electronic Applications Cengiz Yegin and Nirup Nagabandi – Incendium Technologies LLC; Mustafa Akbulut – Texas A&M University

Program Sessions: Thursday, May 31, 8:00 a.m 11:40 a.m.			
Session 13: Fan-Out and Interposer Interconnections	Session 14: Advanced Substrates and Flip Chip Applications	Session 15: Warpage Control in Assembly Processes	
Committee: Interconnections	Committee: Advanced Packaging joint with Assembly & Manufacturing Technology	Committee: Assembly & Manufacturing Technology	
Room: Harbor Island I	Room: Harbor Island 2	Room: Harbor Island 3	
Session Co-Chairs: Katsuyuki Sakuma – IBM Corporation Email: ksakuma@us.ibm.com Jean-Charles Souriau – CEA Leti Email: jcsouriau@cea.fr	Session Co-Chairs: Markus Leitgeb – AT&S Email: m.leitgeb@ats.net Steffen Kroehnert – Amkor Technology Holding B.V., Germany Email: steffen.kroehnert@amkor.com	Session Co-Chairs: Valerie Oberson – IBM Canada Ltd Email: voberson@ca.ibm.com Jin Yang – Intel Corporation Email: jin1.yang@ieee.org	
I. 8:00 AM - Chip Stackable, Ultra-Thin, High-Flexibility 3D FOWLP (3D SWIFT ^(R)) Technology) for Hetero-integrated Advanced 3D WL-SiP WonMyoung Ki, WonGeol Lee, IlBok Lee, InSu Mok, WonChul Do, Curtis Zwenger, Moh Kolbehdari, Alex Copia,Suresh Jayaraman, and KangWook Lee – Amkor Technology, Inc.	I. 8:00 AM - 2.5D Glass Panel Embedded (GPE) Packages with Better I/O Density, Performance, Cost and Reliability than Current Silicon Interposers and High-Density Fan-Out Packages Giback Park, Han-Wen Chen – Applied Materials Inc.; Siddharth Ravichandran, Tailong Shi, Fuhan Liu, Vanessa Smet, Venky Sundaram, Tailong Shi, Chintan Buch, and Rao Tummala – Georgia Institute of Technology; Shuhei Yamada – Murata Manufacturing Co., Ltd.	I. 8:00 AM - Reduce the Wafer Warpage Introduced by Cu in RDL Through Adjusting the Cooling Temperatures Gong Cheng, Gaowei Xu, Wei Gai, and Le Luo – Shanghai Institute of Microsystem and Information Technology	
2. 8:25 AM - High-Performance, High-Density RDL for Advanced Packaging Chun Hui Yu, L. J. Yen, C. Y. Hsieh, C. H. Hsieh, C. S. Liu, KC Yee, C. T. Wang, Victor C. Y. Chang, J. S. Hsieh, and Doug C. H. Yu – Taiwan Semiconductor Manufacturing Company	2. 8:25 AM - Analysis of Warpage and Stress Behavior in a Fine Pitch Multi-Chip Interconnection with Ultrafine-Line Organic Substrate (2.1D) Chen-Yu Huang, Yuan-Hung Hsu, Ying-Ju Lu, Kuo-Hua Yu, Wen-Shan Tsai, Chang-Fu Lin, and C. Key Chung – Siliconware Precision Industries Co., Ltd.	2. 8:25 AM - Ultra-Thin 50 µm Fan-Out Wafer Level Package: Development of an Innovative Assembly and De-Bonding Concept Markus Woehrmann, Tanja Braun, Kai Zoschke, and Michael Toepper – Fraunhofer IZM; Klaus-Dieter Lang – Technical University Berlin	
3. 8:50 AM - Warpage Measurements and Characterizations of Fan-Out Wafer-Level Packaging (FOWLP) with Large Chips and Multiple Re-Distributed Layers (RDLs) J. Lau, M. Li, M. Li, K. Janadhanan, W. Kai, N. Fan and E. Kuah - ASM Pacific Technology; I. Xu, T. Chen, Z. Li and K.H. Tan – JCAP; R. Beica - The Dow Chemical Company; Q.X. Yong and C. Xi - Huawei Technologies Co. Ltd.; S. Chen and W. Bao - Disco Hi-Tec China Co. Ltd.	3. 8:50 AM - A Novel Application of Chemical Mechanical Polishing for Panel Level Organic and Glass Substrate Shyh-Lian Cheng, Wei-Chun Chen, Yu Hua Chen, Puru Lin, and Cheng-Ta Ko – Unimicron Technology Corp.	3. 8:50 AM - Design Guideline of 2.5D Package with Emphasis on Warpage Control and Thermal Management Jisun Hong and Kyongsei Cho – Samsung Electronics Company, Ltd.; Seungbae Park, Shuai Shao, Yuling Niu, Huayan Wang, and Van Lai Pham – Binghamton University	
Refreshmen	Break: 9:15 a.m 10:00 a.m. Bayvi	ew Pavilion	
4. 10:00 AM - Development of Novel Fine Line 2.1 D Package with Organic Interposer Using Advanced Substrate-based Process Weii-Chung Chen, Chiu-Wen Lee, Min-Hua Chung, Chaung-Chi Wang, Shang-Kun Huang, Yen-Sen Liao, Hung-Chun Kuo, and Chen-Chao Wang – Advanced Semiconductor Engineering, Inc.	4. 10:00 AM - Various Chip Attach Evaluations in a Fine Bump Pitch and Substrate Flip-Chip Package Chi-Yuan Chen, lan Hsu, and Stanley Lin – MediaTek, Inc.; KeonTaek Kang and Ming-Che Hsieh – STATS ChipPAC Pte. Ltd.	4. 10:00 AM - Stacking Yield Prediction of Package-on-Package Considering the Statistical Distributions of Top/Bottom Package Warpages and Solder Ball Heights Hsiu-Ping Wei and Bongtae Han – University of Maryland	
5. 10:25 AM - Micro Bump System for 2nd Generation Silicon Interposer with GPU and High Bandwidth Memory (HBM) Concurrent Integration Jaesik Lee, Chun Yang Lee, Chongho Kim, and Shantanu Kalchuri – Nvidia Corporation	5. 10:25 AM - The Effect of the SnAg Solder Joint Morphology on the Thermal Cycle Reliability of 40 µm Fine-Pitch Cu-pillar/SnAg Micro Bump Interconnection SeYong Lee, HanMin Lee, JongHo Park, SangMyung Shin, and Kyung-Wook Paik – Korea Advanced Institute of Science and Technology; Woojeong Kim and Taejin Choi – Doosan Corporation Electro-Materials BG	5. 10:25 AM - Warpage Control During Mass Reflow Flip-Chip Assembly Using Temporary Adhesive Bonding Normand-Pierre Goodhue, David Danovitch, and Jeff Moussodji – Université de Sherbrooke; Benoit Papineau and Eric Duschesne – IBM Corporation	
6. 10:50 AM - Low-Cost Panel-Based 1-2 Micron RDL Technology with Lower Resistance than Si BEOL for Large Packages Fuhan Liu, Rui Zhang, Bartlet DeProspo, Venky Sundaram, and Rao Tummala – Georgia Institute of Technology; Hirokaza Ito – JSR Corporation	6. 10:50 AM - Chip-Package Interaction Challenges for Large Die Applications Z. Wu, C. Carey, S. Donavan, D. Hunt, P. Justison, T. Anemikos and J. Cincotta – GLOBALFOUNDRIES; H. Gagnon, O. Chacon, R. Martel and T. Wassick – IBM Corporation	6. 10:50 AM - Fabrication and Characterization of Epoxy Molding Films (EMFs) for Wafer-Level and Panel-Level and Fan-Out Packages JongHo Park, HanMin Lee, SeYong Lee, and Kyung-Wook Paik – Korea Advanced Institute of Science and Technology; Youjin Kyung, Jung Hak Kim, and Kwangjoo Lee – LG Chem R&D Center	
7. II:15 AM - Advanced Anodic Aluminum Oxide Interposer Fabrication and 3D Embedded Inductors Hsiang Yu Chan, Mark Bachman, and Guann Pyng Li — University of California, Irvine	7. I 1:15 AM - Injection of Molten Solder (IMS) Technology for Solder Bumping on Wafers, Ceramic/Organic/Flexible Substrates, and Si via Filling from Fine Pitch to Large Pitch Jae-Woong Nah, Li-Wen Hung, Paul Andry, and John Knickerbocker – IBM Corporation	7. I I:15 AM - Determination of a Meaningful Warpage Acceptance Criterion for Large PBGA Components Through the Correlation with Scattering in Material Properties Qiming Zhang, Jeffery C. C. Lo, and S. W. Ricky Lee – The Hong Kong University of Science & Technology; Wei Xu – Huawei Technologies Co., Ltd.	

Program Sessions: Thursday, May 31, 8:00 a.m 11:40 a.m.			
Session 16: Advances in Interconnect Reliability and Techniques	Session 17:Technology Advances in Nano, Biochemical, Thermal and Flexible Applications	Session 18: Silicon Photonics	
Committee: Applied Reliability	Committee: Emerging Technologies	Committee: Optoelectronics	
Room: Nautilus I & 2	Room: Nautilus 3 & 4	Room: Nautilus 5	
Session Co-Chairs: S. B. Park – Binghamton University Email: sbpark@binghamton.edu Tz-Cheng Chiu – National Cheng Kung University Email: tcchiu@mail.ncku.edu.tw	Session Co-Chairs: Hongqing Zhang – IBM Corporation Email: zhangh@us.ibm.com Ajit Dubey – GLOBALFOUNDRIES Email: ajitmdubey@gmail.com	Session Co-Chairs: Takaaki Ishigure – Keio University Email: ishigure@appi.keio.ac.jp Soon Jang – ficonTEC USA Email: soon.jang@ficontec.com	
I. 8:00 AM - Reliability of Copper, Gold, Silver, and PCC Wirebonds Subjected to Harsh Environment Pradeep Lall and Shantanu Deshpande – Auburn University; Luu Nguyen – Texas Instruments, Inc.	I. 8:00 AM - Development of Integrated Thermistor Sensor and Heating Electrode for Renal Denervation Procedure Ruiqi Lim, Ming-Yuan Cheng, Weiguo Chen, David Sze Wai Choong, and Yuandong Gu – Institute of Microelectronics; Sebastian Song, Jae Hyung Park, Jung Soo Oh, and Eul Joon Park – Handok Kalos Medical Inc.	I. 8:00 AM - Backside Optical I/O Module for Si Photonics Integrated with Electrical ICS Using Fan-Out Wafer-Level Packaging Technology Hiroshi Uemura, Kaori Warabi, Kazuya Ohira, Yoichiro Kurita, Haruhiko Yoshida, and Hideto Furuyama — Photonics Electronics Technology Research Association; Yoshiaki Sugizaki and Hideki Shibata — Toshiba Corporation	
2. 8:25 AM - Study of Interface Micro-Voids Between Sputter Cu & Plating Cu: The Role of Photoresist Y. B. Ou, T. L. Yang, W. C. Wu, B. T. Chen, K. Y. Lee, H. L. Huang, C. S. Liu, P. Pang, E. Chen, K.C. Liu, M. Liao and H. Ku — Taiwan Semiconductor Manufacturing Company	2. 8:25 AM - Nanomembrane Hybrid Electronics for Wireless Detection of Sourness and Saltiness Toward an Artificial Taste System Yongkuk Lee, Yun Soung Kim, Musa Mahmood, Wong-Hong Yeo, and Saswat Mishra – Georgia Institute of Technology	2. 8:25 AM - Single Mode Optical Coupling Technology Using Movable Micro-Mirror Array and Surface Emitting DFB Laser Array for High-Density 3-D Integration Takanori Suzuki, Koichiro Adachi, Yasunobu Matsuoka, and Shigehisa Tanaka – Oclaro Japan, Inc.	
3. 8:50 AM - Prediction of Statistical Distribution of Vibration-induced Solder Fatigue Failure Considering Intrinsic Variations of Mechanical Properties of Anisotropic Sn-rich Solder Alloys Bulong Wu, Hsiu Ping Wei, Yu-Hsiang Yang, and Bongtae Han – University of Maryland	3. 8:50 AM - Cost-Efficient Formation of Flexible Pressure Sensor with Micropillar Arrays by Metal-Assisted Chemical Etching for Wearable Electronic Skin Yougen Hu, Xinyu Zhang, Pengli Zhu, Tao Zhao, Yuan Zhang, and Rong Sun – Shenzhen Institutes of Advanced Technology; Ching-Ping Wong – The Chinese University of Hong Kong	3. 8:50 AM - 3D System-on-Packaging Using Through Silicon Via on SOI for High- Speed Optical Interconnections with Silicon Photonics Devices for Application of 400 Gbps and Beyond Do-Won Kim, Hong Yu Li, Ka Fai Chang, Woon Leng Loh, Ser Choong Chong, Hong Cai, and Surya Bhattacharya – Institute of Microelectronics, A*STAR	
Refreshment	t Break: 9:15 a.m 10:00 a.m. Bayvi	ew Pavilion	
4. 10:00 AM - Experimental Strain Energy Densities Dissipated in SAC305 Solder Joints During Different Thermal Cycling Conditions Using Strain Gages Measurements Jean-Baptiste Libot, Philippe Milési, and Frédéric Dulondel – Safran Electronics & Defense; Joël Alexis, Lionel Arnaud, and Olivier Dalverny – University of Toulouse - INP/ENIT	4. 10:00 AM - A Harmonic RF Phase-Shifter Based Wireless pH Sensor Saikat Mondal, Deepak Kumar, Saranraj Karuppuswami, and Prem Chahal – Michigan State University	4. 10:00 AM - Broadband, Polarization- Insensitive Lensed Edge Couplers for Silicon Photonics Bradley Snyder, Guy Lepage, Sadhishkumar Balakrishnan, Peter Verheyen, Marianna Pantouvaki, Philippe Absil, and Joris Van Campenhout – IMEC	
5. 10:25 AM - Understanding the Impact of PCB-Changes in the Latest Published JEDEC Board Level Drop Test Method Varun Thukral, Jeroen Zaal, Romuald Roucou, Jeroen Jalink, and Rene Rongen – NXP Semiconductors	5. 10:25 AM - Integration of Chip- Scale SERF Atomic Magnetometers for Magnetoencephalography Measurement Guoliang Li, Jintang Shang, Yu Ji, Lin Lu, and Zhihua Pan – Southeast University	5. 10:25 AM - 400 Gbps 2-Dimensional Optical Receiver Assembled on Wet Etched Silicon Interposer Chenhui Li, Ripalta Stabile, Teng Li, Finn Kraemer, and Oded Raz – Eindhoven University of Technology	
6. 10:50 AM - Non-destructive Inspection of Flip-Chip BGA Solder Ball Defects Using Two Laser Beam Probe Ultrasonic Inspection Technique Chidinma Imediegwu, Vishnu Reddy, Charles Ume, and Aaron Mebane – Georgia Institute of Technology, Kola Akinade, Amiya Chaudhuri, Bryan Rogers, Mark Hill, and Cherif Guirguis – Cisco Systems, Inc.; Tae-Kyu Lee – Portland State University	6. 10:50 AM - Cu-In Fine-Pitch- Interconnects with Enhanced Shear Strength Steffen Bickel, Robert Höhne, and Joerg Meyer – Technical University Dresden; Iuliana Panchenko and M. Juergen Wolf – Fraunhofer IZM-ASSID	6. 10:50 AM - EOCB-Platform for Integrated Photonic Chips Direct-on-Board Assembly within Tb/s Applications Tobias Lamprecht and Felix Betschon – Vario-Optics AG; Alex Bruderer and Romeo Premerlani – Varioprint AG; Joris Lambrecht and Hannes Ramon – IDLab, Ghent University-IMEC; Xin Yin – Ghent University-IMEC	
7. I I:15 AM - Enhanced Design and Reliability Analysis of Copper Post Wafer-Level Package Kuei Hsiao Kuo, Austin Chen, Yen Neng Wang, Jiunn Jie Wang, Jovi Chang, Feng Lung Chien, and Rick Lee – Siliconware Precision Industries Co. Ltd.	7. I 1:15 AM - Study of Wearables with Embedded Electronics through Experiments and Simulations Joseph May, Christopher May, Justin Chow, and Suresh Sitaraman – Georgia Institute of Technology	7. I I:15 AM - Integrated Multi-Wavelength Laser Source for Sensing G. Paré-Olivier, S. Ayotte, F. Costin, A. Babin, M. Morin, B. Filion, K. Bédard, B. Ghislain, E. Girard-Deschênes, P. Chrétien, L. P. Perron, C. A. Davidson, D. D'amato, M. Laplante and J. Blanchet-Létourneau - TeraXio	

Program Sessions: Thursday, May 31, 1:30 р.m 5:10 р.m.		
Session 19: Interconnect Reliability	Session 20: MEMS, Sensor, IoT and Flex	Session 21: Materials and Process Trends for Fan-Out Wafer-Level Packaging
Committee: Interconnections joint with Applied Reliability	Committee: Advanced Packaging	Committee: Materials & Processing
Room: Harbor Island I	Room: Harbor Island 2	Room: Harbor Island 3
Session Co-Chairs: Chuan Seng Tan – Nanyang Technological University Email: tancs@alum.mit.edu Keith Newman – AMD Email: keith.newman@amd.com	Session Co-Chairs: Joseph W. Soucy – Draper Laboratory Email: jsoucy@draper.com Allyson Hartzell – Veryst Engineering Email: AHartzell@veryst.com	Session Co-Chairs: Kimberly Yess – Brewer Science Email: kyess@brewerscience.com Tanja Braun – Fraunhofer IZM Email: tanja.braun@izm.fraunhofer.de
I. I:30 PM - Characterization of Material Damage and Microstructural Evolution Occurring in Lead-Free Solders Subjected to Cyclic Loading Md Mahmudur Chowdhury, Mohd Aminul Hoque, Nianjun Fu, Jeffrey Suhling, Sa'd Hamasha, and Pradeep Lall – Auburn University	I. 1:30 PM - Development of a High- Resolution Magnetic Field Position Sensor System Based on a Through Silicon Via First Integration Concept Kai Zoschke and Hermann Oppermann – Fraunhofer IZM; Johannes Paul, Heiko Knoll, and Franz-Josef Braun – Sensitec GmbH; Monika Saumer and Martin Theis – University of Applied Sciences Kaiserslautem; Peter Frank – Sandvik; Andreas Lenkl and Fabian Klose	I. I:30 PM - Warpage Control of Liquid Molding Compound for Fan-Out Wafer- Level Package Yosuke Oi, Yasuhito Fujii, Takashi Hiraoka, Yukio Yada, and Katsushi Kan – Nagase ChemteX Corporation
2. 1:55 PM - Effects of Au and Pd in Pad Surface Finish on Electro-Migration of Flip Chip Interconnection Between Cu-Pillar and Sn-Bi Solder Alloy System Kei Murayama, Mitsuhiro Aizawa, and Kiyoshi Oi – Shinko Electric Industries Company, Limited	2. 1:55 PM - High Dielectric Constant Molding Compounds for Fingerprint Sensor Packages Tom Tang, Kelly Chen, Kevin Yeh, Terry Tsai, Max Lu, Jensen Tsai, and Yu-Po Wang – Siliconware Precision Industries Co., Ltd.	2. I:55 PM - Warpage Analysis with Newly Molding Material of Fan-Out Panel-Level Package and the Board Level Reliability Test Results Kazuhiro Kikuchi, Yuusuke Nedzu, and Takashi Sugino – Lintec Corporation
3. 2:20 PM - The Stress State of BGA Solder Joints Influenced by the Grain Orientations of Neighboring Joints Andreas Lövberg and Per-Erik Tegehall – Swerea IVF AB	3. 2:20 PM - Concept for Using MID Technology for Advanced Packaging Marc Wurz, Sebastian Bengsch, Ing Wurz, and Sebastian Beringer – Institute of Micro Production Technology; Bernd Roesener – LPKF Laser & Electronics AG	3. 2:20 PM - The Impact of Thermal Shrinkage of Glass Carriers on Achieving Fine-Pitch Wiring through Fan-Out WLP/ PLP Process Shuhei Nomura and Kazutaka Hayashi – Asahi Glass Co., Ltd.
Refreshmen	t Break: 2:45 p.m 3:30 p.m. Bayvie	ew Pavilion
4. 3:30 PM - Microstructure Evolution of Cu/ In/Cu Joints after Solid-Liquid Interdiffusion Yu Shan Chiu and C. Robert Kao – National Taiwan University	4. 3:30 PM - Chipless RFID with Fully Inkjet Printed Tag: A Practical Case Study for Low-Cost Smart Packaging Applications Jarrid Wittkopf, Ning Ge, Robert Ionescu, Doug Pederson, Wagston Staehler, and Helen Holder – Hewlett Packard Inc.	4. 3:30 PM - Advances in Temporary Bonding and Release Technology for Ultrathin Substrate Processing and High-Density Fan-Out Device Build-Up Alain Phommahaxay, Arnita Podpod, John Slabbekoorn, Erik Sleeckx, Gerald Beyer, and Eric Beyne – IMEC; Alice Guerrero, Dongshun Bai, and Kim Arnold – Brewer Science
5. 3:55 PM - Isothermal Fatigue of Interconnections in Flexible Hybrid Electronics Based Human Performance Monitors R. Sivasubramony, N. Adams, M. Alhendi, G. S. Khinda, M. Z. Kokash, J. P. Lombardi, A. Raj, S. Thekkut, D. L. Weerawarne, M. Yadav, A. V. Zachariah, M. D. Poliks and P. Borgesen – Binghamton University; N. C. Stoffel, D. M. Shaddock and L. Yin – GE Global Research	5. 3:55 PM - Low Temperature Solder Attach of SnAgCu Bumped Components for a Flexible Hybrid Electronics Based Medical Monitor Thaer Alghoul, Manu Yadav, Sanoop Thekkut, Rajesh Sivasubramony, Christopher Greene, Mark Poliks, and Peter Borgesen – Binghamton University; Luke Wentlent and Michael Meilunas – Universal Instruments; Nancy Stoffel, David Shaddock and Liang Yin – GE Global Research	5. 3:55 PM - Novel Microwave Process for RDL Photosensitive Dielectric Polymer Curing on FOWLP Reconstructed Wafer Kazunori Yamamoto, Chun-Mei Wang, and Xiang-Yu Wang – Institute of Microelectronics; Tuck-Foong Koh and Felix Deng – Applied Materials
6. 4:20 PM - Board Level Reliability Investigation of Fan-Out Wafer Level Package Stephen Hou, K. H. Tsai, M. F. Wu, M. F. Ku, P. H. Tsao, and L. H. Chu – Taiwan Semiconductor Manufacturing Company	6. 4:20 PM - Mechanical Strength Characterization of Direct Bond Interfaces for 3D-IC and MEMS Applications B. Lee, R. Katkar, G. Gao, G. Fountain, S. Lee, L. Wang, C. Mandalapu, C. Uzoh and L. Mirkarimi – Xperi; B. Sykes and M. Litjens – Xyztec; Y. Niu, S. Shao, J. Wang and S. Park – Binghamton University	6. 4:20 PM - Fabrication of Fine Via and Line / Space in Low CTE Film for Panel Fan-Out Using a Dry Etching Technology Muneyuki Sato, Takahide Murayama, Tetsushi Fujinaga, and Yasuhiro Morikawa – ULVAC, Inc.
7. 4:45 PM - Multi-Axis Loading Impact on Thermo-Mechanical Stress-Induced Damage on WLCSP and Components with Via-in Pad Plated Over (VIPPO) Board Design configuration Andy Hsiao, Tae-Kyu Lee and Mohamed Sheikh – Portland State University; Weidong Xie and Steven Perng – Cisco Systems, Inc.; Edward Ibe and Karl Loh – Zymet	7. 4:45 PM - Study on an Improved Wafer- Level Fabrication Process to Achieve Size Uniformity for Micro Glass Shell Resonators Zhaoxi Su, Jintang Shang, and Bin Luo – Southeast University; Ching-Ping Wong – The Chinese University of Hong Kong	7. 4:45 PM - Reliability Studies of Excimer Laser-Ablated Microvias Below 5 Micron Diameter in Dry Film Polymer Dielectrics for Next Generation, Panel-Scale 2.5D Interposer RDL Chandrasekharan Nair, Bartlet DeProspo, Fuhan Liu, Venky Sundaram, and Rao Tummala – Georgia Institute of Technology; Habib Hichri and Markus Arendt – SUSS Microtec Photonic Systems, Inc.

Program Sessions: Thursday, May 31, 1:30 р.т 5:10 р.т.		
Session 22: Thermal Mechanical Modeling and Characterization	Session 23: RF and THz Module Components	Session 24: Optical Module Integration
Committee: Thermal/Mechanical Simulation & Characterization	Committee: High-Speed, Wireless & Components	Committee: Optoelectronics
Room: Nautilus I & 2	Room: Nautilus 3 & 4	Room: Nautilus 5
Session Co-Chairs: Pradeep Lall- Auburn University Email: lall@auburn.edu Yong Liu - ON Semiconductor Email: Yong.Liu@onsemi.com	Session Co-Chairs: Craig Gaw – NXP Semiconductor Email: c.a.gaw@ieee.org Amit P. Agrawal – Microsemi Corporation Email: amit.agrawal@microsemi.com	Session Co-Chairs: Hiren Thacker – Tech301 Email: hiren@tech301.com Ajey Jacob – GLOBALFOUNDRIES Email: ajey.jacob@globalfoundries.com
I. 1:30 PM - Seal Ring Toughness Characterization by Numerical and Experimental Approaches Idir Raid, Sébastien Gallois-Garreignot, and Vincent Coutellier – STMicroelectronics; Rafael Estevez – SIMaP	1. 1:30 PM - Package Co-Design of a Fully Integrated Multimode 76-81 GHz 45nm RFCMOS FMCW Automotive Radar Transceiver Minhong Mi, Jie Chen, Meysam Moallem, Ming Li, and Rajen Murugan – Texas Instruments, Inc.	I. 1:30 PM - Direct Fabrication for Polymer Optical Waveguide in PMT Ferrule Using th Mosquito Method Takaaki Ishigure, Hikaru Masuda, Chinami Marushima Kumi Date, and Tadayuki Enomoto – Keio University
2. 1:55 PM - Reliability Life Assessment of WLCSP Using Different Creep Models K. N. Chiang, V. Ramachandran, K. C. Wu, and C. C. Lee – NTHU	2. 1:55 PM - Embedded Active Elements in 3D Printed Structures for the Design of RF Circuits Mohd Ifwat Mohd Ghazali, Saikat Mondal, Saranraj Karuppuswami, and Premjeet Chahal – Michigan State University	2. 1:55 PM - Solder-Reflowable, High- Throughput Fiber Assembly Achieved by Partitioning of Adhesive Functions Alexander Janta-Polczynski, Elaine Cyr, Richard Langlois, Paul Fortier, Yoichi Taira, Nicolas Boyer, ar Tymon Barwicz – IBM Corporation
3. 2:20 PM - On the Uniqueness and Sensitivity of Nanoindentation Testing for Determining the Elastic and Plastic Material Properties of Electroplating Copper Filled in Through-Silicon-Via (TSV) Liangbiao Chen and Yong Liu – On Semiconductor; Fei Qin – Beijing University of Technology; Mahmound El Barbary and Xuejun Fan – Lamar University	3. 2:20 PM - Miniaturized High- Performance Filters for 5G Small-Cell Applications Muhammad Ali, Atom Watanabe, Markondeya Raj Pulugurtha, Venkatesh Sundaram, Manos M. Tentzeris, Fuhan Liu, and Rao R. Tummala – Georgia Institute of Technology	3. 2:20 PM - Low Reflectance and Reflowable Thermoplastic Optical Lens Without AR Coating Takuro Watanabe, Sho Yakabe, and Takayuki Shima - Sumitomo Electric Industries, Ltd.; Ryohei Hokari and Kazuma Kurihara – National Institute of Advanc Industrial Science and Technology; Shouhei Okabe – Sumitomo Electric Fine Polymer, Inc.
Refreshment	t Break: 2:45 p.m 3:30 p.m. Bayvie	w Pavilion
4. 3:30 PM - Co-Design for Extreme Large Package Solution with Embedded Fine Pitch Interposer (EFI) Technology Faxing Che, David Ho, and T. C. Chai – Institute of Microelectronics	4. 3:30 PM - 3D-IPD with High Aspect Ratio Cu Pillar Inductor Cheng-Yuan Kung, Chien-Hua Chen, Teck Chong Lee, Hung-Yi Lin, Shiuan-Yu Lin, Yu-Chang Hsieh, Pao-Nan Lee, and Chen-Chao Wang – Advanced Semiconductor Engineering Group	4. 3:30 PM - Wide Range 2D InP Chipto-Fiber Alignment Through Bimorph Piezoelectric Actuators Simone Cardarelli, Nicola Calabretta, Ripalta Stabile, and Kevin Williams – Technical University Eindhover Xiao Luo and Jan Mink – Vtec
5. 3:55 PM - Study of Polyimide in Chip Package Interaction for Flip-Chip Cu-Pillar Package Wei Wang, Dingyou Zhang, Yangyang Sun, David Rae, Lily Zhao, Jiantao Zheng, Mark Schwarz, Milind Shah, and Ahmer Syed – Qualcomm, Inc.	5. 3:55 PM - Ultra-Compact, High- Performance, 3D-IPD Integrated Using Conformal 3D Interconnects Ayad Ghannam, Alessandro Magnani, David Bourrier, and Thierry Parra – 3DiS Technologies S.A.S.	5. 3:55 PM - Co-integration of High- Bandwidth Photonic and Electronic RDL on 2.5D Glass Interposers Using Low Optical Absorption Photoimageable Dielectric Polymer Rui Zhang, Fuhan Liu, Venky Sundaram, and Rao Tummala – Georgia Institute of Technology; Michael Gallagher and Ed Anzures – Dow Chemical Compar
6. 4:20 PM - A Study of Organic Chip Carrier Fatigue Cracking Shidong Li, Sushumna Iruvanti, Kamal Sikka, and Rui Wang – IBM Corporation	6. 4:20 PM - Glass in Electronic Packaging and Integration: High Q Inductances for 2.35 GHz Impedance Matching in 0.05 mm Thin Glass Substrates Martin Letz and Matthias Jotz - SCHOTT AG; Zihan Wu, Sukhadha Viswanathan, P Markondeya Raj, Venkatesh Sundaram, and Rao Tummala - Georgia Institute of Technology; Holger Maune and Matthias Jost - Technical University of Darmstadt, IMP	6. 4:20 PM - Thin Glass Based Optical Sub-Assemblies For Embedding in Electronic Systems Wojciech Lewoczko-Adamczyk, Gunnar Böttger, Henning Schröder, Klaus-Dieter Lang, and Martin Schneider-Ramelow – Fraunhofer Institute for Reliability and Microintegration
7. 4:45 PM - Developments for Highly Reliable Electronics - Experiments on Combined Thermal and Vibration Loading Karsten Meier and Karlheinz Bock - Technical University Dresden; Mike Roellig - Fraunhofer IKTS	7. 4:45 PM - Through Glass Via (TGV) Based Band Pass Filter for 5G Communications Renuka Bowrothu and Yong-Kyu Yoon – University of Florida; Jay Zhang – Corning, Inc.	7. 4:45 PM - Integration of Ball Lens in Through-Package Via to Enable Photonic Chip-to-Board Coupling Nivesh Mangal, Jeroen Missinne, and Geert Van Steenberge – Ghent University/IMEC; Joris Van Campenhout and Brad Snyder – IMEC

Program Sessions: Friday, June 1, 8:00 a.m 11:40 a.m.		
Session 25: Fabrication and Characterization of TSV	Session 26: Wafer-Level Packaging Fan-In and Fan-Out Key Developments	Session 27: Automotive and Power Electronics
Committee: Interconnections	Committee: Assembly & Manufacturing Technology joint with Advanced Packaging	Committee: Advanced Packaging
Room: Harbor Island I	Room: Harbor Island 2	Room: Harbor Island 3
Session Co-Chairs: Dingyou Zhang – Qualcomm Technologies, Inc. Email: zhangdingyou04@gmail.com Wei-Chung Lo – ITRI Email: lo@itri.org.tw	Session Co-Chairs: Jan Vardaman – Techsearch International Email: jan@techsearchinc.com Andrew Kim – Intel Corporation Email: hyoung.il.kim@intel.com	Session Co-Chairs: Young-Gon Kim – Integrated Device Technology, Inc. Email: young.kim@idt.com Subhash L. Shinde – Notre Dame University Email: sshinde@nd.edu
1. 8:00 AM - Low-Cost, Self-Formed Vertical Nanowires with Aspect Ratio > 100x in Deep Si-Trenches for Future 3D-LSI/IC Applications Murugesan Mariappan, Takafumi Fukushima, JiChel Bea, Hiroyuki Hashimoto, and Mitsumasa Koyanagi — Tohoku University	I. 8:00 AM - Development of WLCSP for Accelerometer Packaging with Vertical CuPd Wire as Through Mold Interconnection (TMI) Zhaohui Chen, Boon Long Lau, Zhipeng Ding, Eva Leong Ching Wai, Beibei Han, Lin Bu, Hyun- Kee Chang and Tai Chong Chai – Institute of Microelectronics - A*STAR	I. 8:00 AM - Embedded Components for High-Temperature Automotive Applications Stephanie Groß, Bernhard Schuch, and Wolfgang Grübl – Continental
2. 8:25 AM - First Demonstration of Silicon- Like >250 I/O per mm per layer Multilayer RDL on Glass Panel Interposers by Embedded Photo-Trench and Fly Cut Planarization Bartlet DeProspo, Fuhan Liu, Venkatesh Sundaram, Chandra Nair, and Rao Tummala – Georgia Institute of Technology; Frank Wei and Ye Chen – Disco Corporation; Atsushi Kubo – TOK	2. 8:25 AM - Fan-Out Package: Performance and Scalability Perspective Jong Heon Kim, Yong Tae Kwon, Yong Ho Kwon, Yong Woon Yeo, Young Mo Lee, Yoon Mook Park, Eung Ju Lee, Jun Kyu Lee and Nam Chul Kim — Nepes Corporation; Sangdon Lee, Seongwook Choi and Yoonyoung Bae — Giparang, Inc.; Young June Park — Seoul National University	2. 8:25 AM - New Failure Mechanism in High-Temperature Resin Materials Michael Guyenot, D. Maas, and Roumen Ratchev – Robert Bosch GmbH; Ali Khoshamouz and Thomas Gottwald – Schweizer Electronic AG; Sascha Kreuer – Isola Group
3. 8:50 AM - Dielectric Quality of 3D Capacitor Embedded in Through-Silicon Via (TSV) Ye Lin and Chuan Seng Tan – Nanyang Technological University	3. 8:50 AM - Board Level Reliability Enhancement of WLCSP with Large Chip Size Pei-Haw Tsao, T. H. Lu, T. M. Chen, K. C. Chang, C. M. Kuo, M. J. Lii, and L. H. Chu - Taiwan Semiconductor Manufacturing Company	3. 8:50 AM - Next Generation of Automotiv Radar with Leading-Edge Advances in SiGe Devices and Glass Panel Fan-Out Packaging Tailong Shui, Yunyi Gong, Siddharth Ravichandran, Venky Sundaram, John D. Cressler, and Rao Tummal – Georgia Institute of Technology
Refreshment Break: 9:	15 a.m 10:00 a.m. Harbor Island Fo	oyer & Nautilus Foyer
4. 10:00 AM - Experimental Assessment and Analysis of the Influence of Radiation on Through-Silicon Vias Qinghua Zeng, Jing Chen, and Yufeng Jin – Peking University	4. 10:00 AM - Controlling Underfill Lateral Flow to Improve Component Density in Heterogeneously Integrated Packaging Systems Christophe Faucher-Courchesne and David Danovitch – Université de Sherbrooke; Lise Brault, Marie-Claude Paquet, and Eric Turcotte – IBM Corporation	4. 10:00 AM - Solderless Leadframe Assisted Wafer-Level Packaging Technology for Power Electronics Kremena Vladimirova and Julie Widiez - CEA-LETI; Jean-Christophe Crebier - CNRS-G2ELab; Bastien Letowski, Pierre Perreau, Gregory Enyedi, Perceval Coudrain and Nicolas Rouger - University Grenoble Alpes
5. 10:25 AM - Co-Deposition of Nano-Size SiC particles in Micro-Via Houya Wu, Yan Wang, Fuliang Wang, Zhuo Chen, Hu He, and Liancheng Wang – Central South University	5. 10:25 AM - Dual-Carrier Process using Mechanical and Laser Release Technologies for Advanced Wafer-Level Packaging Michelle Fowler, Ram Trichur, John Massey, and Matt Koch – Brewer Science	5. 10:25 AM - Material Characterization of Advanced Cement-Based Encapsulation Systems for Efficient Power Electronics With Increased Power Density B. Boettge, F. Naumann, S. Klengel and M. Petzold - Fraunhofer Institute for Microstructure of Materials and Systems IMWS; S. Behrendt and R. Eisele - FuE-Zentrum Fachhochschule Kiel GmbH; M. G. Scheibel and A. Z. Miric Heraeus Deutschland GmbH & Co. KG; S. Kaessens, G. Heigmann - Rober Bosch GmbH; and K. G. Nickel - University of Tuebingen
6. 10:50 AM - A Study of Crystal Orientation of Solder TSVs Yuki Ohara, Yuki Inagaki, Atsushi Mizutani, and Kazushi Asami – DENSO Corporation	6. 10:50 AM - Optimization of Electrodeposited Copper for Sub 5 µm L/S RDL Lines by Plating Additives Ralf Schmidt and T. Beck – Atotech Deutschland GmbH; R. Rooney and A. Gewirth – University of Illinois	6. 10:50 AM - Mechanism of Ultrasonic- Assisted Sintering of Cu@Ag NPs Paste in Air for High-Temperature Power Device Packaging Hongjun Ji and Mingyu Li – Harbin Institute of Technology (Shenzhen)
7. 11:15 AM - Characterization of Optical End-point Detection for Via Reveal Processing Anne Jourdain, Nina Tutunjyan, Joeri DeVos, Stefano Sardo, Daniele Piumi, Andy Miller, Eric Beyne and Nouredine Rassoul – IMEC; Edward Walsby, Huma Ashraf and Dave Thomas – SPTS Technologies	7. I1:15 AM - UBM/RDL Deposition by PVD for FOWLP in High Volume Production Chris Jones, Tony Wilby, Paul Densley, and Stephen Burgess – SPTS Technologies Ltd.	7. I 1:15 AM - Design Consideration of a 3D Stacked Power Supply on Chip Kota Ono, Kengo Hiura, and Satoshi Matsumoto – Kyushu Institute of Technology

Program Sessions: Friday, June 1, 8:00 a.m 11:40 a.m.		
Session 28: High-Speed and High- Bandwidth Packaging	Session 29: Modeling of Power Electronics	Session 30: Emerging Materials and Technologies
Committee: High-Speed, Wireless & Components	Committee: Thermal/Mechanical Simulation & Characterization	Committee: Materials & Processing
Room: Nautilus I & 2	Room: Nautilus 3 & 4	Room: Nautilus 5
Session Co-Chairs: Rockwell Hsu – Cisco Systems, Inc. Email: rohsu@cisco.com Zhaoqing Chen – IBM Corporation Email: zhaoqing@us.ibm.com	Session Co-Chairs: Ning Ye – Western Digital Email: ning:ye@wdc.com Xuejun Fan – Lamar University Email: xuejun.fan@lamar.edu	Session Co-Chairs: Bing Dang - IBM Research Email: dangbing@us.ibm.com Lewis Huang - Senju Electronic Email: lewis@senju.com.tw
I. 8:00 AM - Electrical Characterization of High Performance Fine Pitch Interconnects in Silicon Interconnect Fabric SivaChandra Jangam, Adeel Ahmed Bajwa, Kannan Kalappurakal Thankappan, Premsagar Kittur, and Subramanian Srikantes Iyer – University of California, Los Angeles	I. 8:00 AM - Prognostication of Damage on Automotive Underhood Electronics Subjected to Temperature and Vibration Pradeep Lall, Tony Thomas, and Jeff Suhling – Auburn University	I. 8:00 AM - On-Chip Solid-State CMOS Compatible Micro-Supercapacitors Rickard Andersson, Amin Muhammad Saleem, and Vincent Desmaris – Smoltek AB; Bo Song and C. P. Wong – Georgia Institute of Technology
2. 8:25 AM – High Bandwidth Memory Interface on Organic Substrate: Challenge to Electrical Design Vadim Heyfitch, Shen Dong, Nanju Na, Hong Shi, Jaspreet Gandhi, Jane Xi, and Susan Wu – Xilinx, Inc.	2. 8:25 AM - Interface Fracture Toughness Characterization in Electronic Packages Using the Crack Surface Displacement Extrapolation Method Przemyslaw Gromala, Mateus Jeronimo, and Alexandru Prisacaru – Robert Bosch GmbH; Marcus Schulz and Juergen Keller – AMIC GmbH	2. 8:25 AM - Fabrication of High Capacitance Density Capacitor Using Spray Coater Ba0.6Sr0.4TiO3 Thin Films Emannuel Testi, Isabelle Bord Majek, Gilles Philippot, Cyril Aymonier— Université de Bordeaux; Jean Aude and Roxan Lemire—IBM Canada Ltd, Laurent Bechand Dominique Drouin— Université de Sherbrooke
3. 8:50 AM - Advanced Fan-Out Package Performance SI/PI/Thermal Performance Analysis of Novel RDL Packages Se-Ho You, Seonghwan Jeon, Dan (Kyung Suk) Oh, Kilsoo Kim, Jaechoon Kim, Seung-Yong Cha, Gyoungbum Kim – Samsung Electronics Company, Ltd.	3. 8:50 AM - Simulation for Enhancing Automotive Power Module DBC Reliability During Assembly Process Yong Liu and Qiuxiao Qian – ON Semiconductor	3. 8:50 AM - Structuring Methods of Polymers for Low-Cost Sensor Manufacturing Sebastian Bengsch and Marc Wurz – Institute of Mic Production Technology; Maximilian Aue and Sascha Wall – Leibniz University Hanover
Refreshment Break: 9:	 	oyer & Nautilus Foyer
4. 10:00 AM - FCBGA Fundamental Technology Realizing 56 Gbps PAM-4 System with 50 cm Electric Transmission Kazuyuki Nakagawa, Keita Tsuchiya, Shinji Katayama, Yoshiaki Sato, Hiroyuki Uchida, and Shinji Baba — Renesas Electronics Corporation; Norio Chujo, Masayoshi Yagyu, and Yutaka Uematsu — Hitachi, Ltd.	4. 10:00 AM - A Methodology to Integrate Thermo-Mechanical Reliability Predictions into Co-Design of Flip-Chip-On-Lead Devices Siva Gurrum, Manu Prakuzhy, Guangxu Li, Hung-Yun Lin, Saumya Gandhi, J. Carlos Arroyo, Frank Mortan, and Amit Nangia – Texas Instruments, Inc.	4. 10:00 AM - Solely Calcine Controlled Ferroelectricity and Resistivity of Barium Titanate Thin Films and Their Advanced Memory Applications Todd Schumann, Xiaochen Zhu, Jacob Neff, Arthur Hebard, Henry Zmuda, and Yong-Kyu Yoon – University of Florida
5. 10:25 AM - Desensitization Design and Analysis for Highly Integrated RFSoC and DRAM Stacked-Die Design Sheng Mou Lin, Chih-Chun Hsu, Yi-An Hsu, Fu-Yi Han, Duen-Yi Ho, Wen-Zhou Wu, and Charles Nan-Cheng Chen – Mediatek, Inc.	5. 10:25 AM - High Power-Density 3D Integrated Power Supply Module Based on Panel-Level PCB Embedded Technology Fengze Hou, Xueping Guo, Qidong Wang, Tingyu Lin, and Liqiang Cao – Institute of Microelectronics of Chinese Academy of Sciences; Wenbo Wang, J. A. Ferreira and G.Q. Zhang – Delft University of Technology; Tingyu Lin – National Center for Advanced Packaging	5. 10:25 AM - Electrochemical Analysis of Mechanically Flexible Magnesiumion Battery Electrodes in a Polymer Gel Perchlorate Electrolyte Todd Houghton and Hongbin Yu – Arizona State University
6. 10:50 AM - Thermal Stability of Cu/Co Metaconductor and Its Millimeter Wave Applications Timothy Clingenpeel, Seahee Hwangbo, Nicolas Garraud, David Arnold, and Yong-Kyu Yoon – University of Florida	6. 10:50 AM - Mars 2020 Rover Laser Power Supply Thermomechanical Analysis Juan Cepeda-Rizo – Jet Propulsion Laboratory	6. 10:50 AM - Demonstration of Hermetic Sealing on Ultra-Thin, Wafer-Integrated Aluminum-Polymer Capacitors for High-Voltage and High-Temperature Application Robert Spurney, Himani Sharma, P. M. Pulugurtha, and Rao Tummala — Georgia Institute of Technology; Naom Lollis and Mitch Weaver — AVX Corporation; Saumya Gandhi and Matt Romig — Texas Instruments, Inc.
7. II:15 AM - Comparative Study on Electrical Performance of eWLB, M-Series and Fan-Out Chip Last Chih-Yi Huang, Tsun-Lung Hsieh, Po-Chih Pan, Ming-Fong Jhong, Chen-Chao Wang, Sheng-Chi Hsieh — Advanced Semiconductor Engineering Inc.	7. II:15 AM - Mechanical Modelling of High-Powered Lateral IGBT for LED Driver Applications Chris Bailey, P. Rajaguru, and Hua Lu – University of Greenwich; Alberto Castellazzi and Mattia Antonini – University of Nottingham; Vasantha Pathirana, Nishad Udugampola, and Florin Udrea – University of Cambridge; Paul Mitchelson and Samer Aldhaher – Imperial College	7. I I:15 AM - Hydrothermal Exfoliation for 2D Boron Nitride Nanosheets Guang Yang, Haixu Wang, Ning Wang, Rong Sun an Ching-Ping Wong – Shenzhen Institute of Advanced Technology

Program Sessions: Friday, June 1, 1:30 p.m 5:10 p.m.		
Session 31: Advanced Wirebond and Interconnect Technologies	Session 32: Heterogeneous Integration	Session 33: Next-Generation Materials and Processes for Through Vias and 3D Interconnects
Committee: Interconnections	Committee: Advanced Packaging	Committee: Materials & Processing
Room: Harbor Island I	Room: Harbor Island 2	Room: Harbor Island 3
Session Co-Chairs: Li Li – Cisco Systems, Inc. Email: LiLi2@cisco.com Bernd Ebersberger – Intel Corporation Email: bernd.ebersberger@intel.com	Session Co-Chairs: Luke England – GLOBALFOUNDRIES Email: luke.england@globalfoundries.com Kuldip Johal – Atotech Email: kuldip.johal@atotech.com	Session Co-Chairs: Praveen Pandojirao-S – Johnson & Johnson Email: praveen@its.jnj.com Qianwen Chen – IBM Corporation Email: chenq@us.ibm.com
I. I:30 PM - Effects of Epoxy Molding Compound on Electrical Resistance Degradation of Pd-Coated Cu Wire Bonds in the I75 °C to 225 °C Range Michael Hook and Michael Mayer – University of Waterloo; Stevan Hunter – ON Semiconductor	I. 1:30 PM - Void-Free Copper Pillar Hybrid Wafer Bonding Using a BCB Based Polymer Adhesive and Chemical Mechanical Polishing Michael Gallagher, Julia Kozhukh, Matthew VanHanehem, Edgardo Anzures, Rosemary Bell and Masaki Kondo – DowDupont Electronic Materials	I. 1:30 PM - Extreme Thinning of Si Wafers for Via-Last and Multi Wafer Stacking Applications Anne Jourdain, Joeri De Vos, Nouredine Rassoul, Houman Zahedmanesh, Andy Miller, Gerald Beyer, Eric Beyne, and Dave Thomas – SPTS; Edward Walsby, Jash Patel, Oliver Ansell, Huma Ashraf, and Dave Thomas – SPTS; Shifang Li, Timothy Chang, Stephen Hiebert, Moritz Stoerring and Andrew Cross – KLA-Tencor
2. 1:55 PM - Molecular Dynamics Simulation of Microwelds Formation and Breakage During Ultrasonic Copper Wire Bonding Yangyang Long, Bo He, Weizhe Cui, Bo He, Xiaoying Zhuang, and Jens Twiefel – Leibniz Universität Hannover	2. 1:55 PM - Heterogeneous Integration Challenges within Wafer Level Fan-Out SiPs for Wearables and IoT Alberto Martins, Marcio Pinheiro, Ana Filipa Ferreira, Rodrigo Almeida, F. Matos, J. Oliveira, and Rui Pedro Silva Amkor Technology, Inc.; H. M. Santos and H. Gamboa INESC TEC; M. C. Monteiro Fraunhofer Portugal AICOS	2. I:55 PM - Development of a Polyimide/ SiC-Whisker/Nano-Particles Composite with High Thermal Conductivity and Low Coefficient of Thermal Expansion as Dielectric Layer for Interposer Application Yunna Sun, Jiangbo Luo, Yan Wang, Zhuoqing Yang, and Guifu Ding – Shanghai Jiao Tong University; Zhenqian Wang – Clemson University
3. 2:20 PM - Investigation for Highly Reliable Free Air Ball Formation for Silver Wire Noritoshi Araki, Ryo Oishi, and Takashi Yamada – Nippon Micrometal Corporation; Yasutomo Ichiyama - Nippon Steel & Sumikin Technology	3. 2:20 PM - Embedded Silicon Fan-Out (eSiFO): A Promising Wafer-Level Packaging Technology for Multi-Chip and 3D System Integration Shuying Ma, Jiao Wang, Fengxia Zheng, Zhiyi Xiao, Teng Wang, and Daquan Yu – Huantian Technology (Kunshan) Electronics Co., Ltd.	3. 2:20 PM - An Advanced Photosensitive Dielectric Material for High-Density RDL with Ultra-Small Photo-Vias and Ultra-Fine Line/Space in 2.5D Interposers and Fan-Out Packages Daichi OKamoto, Yoko Shibasaki Daisuke, Shibata and Tadahiko Hanada - Taiyo Ink Mfg. Co. Ltd.; Fuhan Liu, Venky Sundaram and Rao R. Tummala - Georgia Institute of Technology
Refreshment Break: 2	:45 p.m 3:30 p.m. Harbor Island Fo	yer & Nautilus Foyer
4. 3:30 PM - Corrosion Mechanisms of Cu Wire Bonding on Al Pads Wentao Qin, Harold Anderson, Tom Anderson, George Chang, and Denise Barrientos – ON Semiconductor	4. 3:30 PM - "Hole-In-One TSV," a New Via Last Concept for High-Density 3D-SOC Interconnects Joeri De Vos, Stefaan Van Huylenbroeck, Anne Jourdain, Nancy Heylen, Lan Peng, Geraldine Jamieson, Nina Tutunjyan, Stefano Sardo, Andy Miller, and Eric Beyne – IMEC	4. 3:30 PM - Highly Productive Solder Interconnect Formation by Bump Stabbing for 3D-TSV Die Stacking Shizu Fukuzumi, Hitoshi Onozeki, Naoya Suzuki, and Toshihisa Nonaka — Hitachi Chemical Co., Ltd.
5. 3:55 PM - Low-Temperature Solder – A Breakthrough Technology for Surface Mounted Devices Shubhada Sahasrabudhe, Scott Mokler, Mukul Renavikar, Sandeep Sane, Eric Brigham, Kevin Byrd, Owen Jin, Satish Parupalli, Pubudu Goonetilleke, and Nilesh Badwe – Intel Corporation	5. 3:55 PM - Flexible (Imm bending radius) Biocompatible Heterogeneous Fan-Out Wafer-Level Platform With the Lowest Reported Die-Shift (<6 µm) and Reliable Flexible Cu-Based Interconnects Amir Hanna, Takafumi Fukushima, Arsalan Alam, Steven Moran, William Whitehead, Siva Jangam, S. Pal, G. Ezhilarasu, R. Irwin, Adeel Bajwa, and Subramanian Iyer — University of California, Los Angeles	5. 3:55 PM - Reliability Studies of 5 µm Diameter Photo Vias With Daisy Chain Resistance Using Dry Film Photosensitive Dielectric Material Atsushi Kubo and Tomoyuki Ando – Tokyo Ohoka Kogyo Co., Ltd.; Chandrasekharan Nair, Bartlet DeProspo, Fuhan Liu, Venky Sundaram, and Rao Tummala – Georgia Institute of Technology
6. 4:20 PM - Advances in Wire Bonding Technology to Overcome Resonance Conditions Aashish Shah, Jon Brunner, Gary Schulze, Ivy Qin, Bob Chylak, and Nelson Wong – Kulicke and Soffa Industries, Inc.	6. 4:20 PM - Heterogeneous Multi-Die Stitching: Technology Demonstration and Design Considerations Paul Jo, Md Obaidul Hossen, Xuchen Zhang, Yang Zhang, and Muhannad Bakir – Georgia Institute of Technology	6. 4:20 PM - Metal-Alloy Cu Surface Passivation Leads to High Quality Fine-Pitch Bump-Less Cu-Cu Bonding for 3D IC and Heterogeneous Integration Applications Asisa Kumar Panigrahi – Koneru Lakshmaiah Education Foundation- Hyderabad; Hemanth Kumar Cheemalamarni, Satish Bonam, Tamal Ghosh, Nirupam Paul, Siva Rama Krishna Vanjari, Paul K. Brince, Tamal Ghos and Shiv Govind Singh – Indian Institute of Technology Hyderabad
7. 4:45 PM - 3D Antenna-in-Package Design with Metallic Coating Technology Chih-Chun Hsu, Sheng-Mou Lin, Ying-Chih Chen, Wen-Zhou Wu, Che-Ya Chou and Charles Nan- Cheng Chen – MediaTek, Inc.; Gavin Gao and Chen- Chao Wang – Advanced Semiconductor Engineering, Inc.	7. 4:45 PM - Heterogeneous Integration Technology Demonstrations for Future Healthcare, IoT, and AI Computing Solutions J.U. Knickerbocker, R. Budd, B. Dang, Q. Chen, E. Colgan, L.W. Hung, S. Kumar, K. W. Lee, M. Lu, J. W. Nah, R. Narayanan, K. Sakuma, V. Siu, and B. Wen – IBM Corporation	7. 4:45 PM - Interconnection Process Using Laser and Hybrid Underfill for LED Array Module on PET Substrate Kwang-Seong Choi, Leeseul Jeong, Keon-Soo Jang, Seok Hwan Moon, Hyun-Cheol Bae, Wagno Alves Braganca Junior, Ieeseul Jeong, Keon-Soo Jang and Yong-Sung Eom – Electronics and Telecommunications Research Institute; Min Kyo Cho and Seung II Chang – Beyond! Technology Innovator

Program Sessions: Friday, June I, I:30 р.m 5:10 р.m.		
Session 34: Fan-Out Wafer-Level Package Reliability	Session 35: Multiphysics and Solder Joint Reliability	Session 36: Power Delivery Solutions for Components and Systems
Committee: Applied Reliability	Committee: Thermal/Mechanical Simulation & Characterization	Committee: High-Speed, Wireless & Components
Room: Nautilus I & 2	Room: Nautilus 3 & 4	Room: Nautilus 5
Session Co-Chairs: Darvin R. Edwards – Edwards Enterprise Consulting, LLC Email: darvin.edwards (@gmail.com Pilin Liu – Intel Corporation Email: pilin.liu@intel.com	Session Co-Chairs: Christopher J. Bailey – University of Greenwich Email: C.Bailey@greenwich.ac.uk Wei Wang – Qualcomm Technologies, Inc. Email: weiwng@qti.qualcomm.com	Session Co-Chairs: Rajen M Murugan – Texas Instruments Email: r-murugan@t.com P. Markondeya Raj– Georgia Institute of Technology Email: raj@ece.gatech.edu
I. I:30 PM - Reliability of Fan-Out Wafer-Level Packaging (FOWLP) with Large Chips and Multiple Re-Distributed Layers (RDLs) Y. M. Cheung, Nelson Fan, Ji-Hao, Wu Kai, Eric Kuah, John Lau, Ming Li, Penny Lo, Eric Ng, Lei Yang and Margie Li - ASM; Qing Xiang Yong, Cao Xi, Koh Sau Wee, Jiang Ran and Zhong Cheng Huawel Technologies Co. Ltd.; Tony Chen, Iris Xu, Zhang Li and Kim Hwee Tan - Jiangyin Changdian Advanced Packaging Co. Ltd.; Rozalia Beica - Dow Chemical Company, Sze Pei Lim and N. C. Lee - Indium Corporation; Cheng-Ta Ko, Henry Yang and Y. H. Chen - Unimicron Technology Corporation; Mian Tao, Jeffery Lo and Ridcy Lee - Hong Kong University of Science and Technology	I. I:30 PM - Numerical Multiphysics Model for Cu-Al Wire Bond Corrosion Subjected to Highly-Accelerated Stress Test Pradeep Lall and Yihua Luo – Auburn University; Luu Nguyen – Texas Instruments, Inc.	I. I:30 PM - Analog Power Filtering: Modeling, Measuring & Verifying Analog PI Layne Berge, Matt Doyle, and Kyle Schoneck – IBM Corporation
2. 1:55 PM - Passivation Materials for a Reliable Fine Pitch RDL Stéphane Moreau, Nacima Allouti, Céline Ribière, David Bouchu, Jean Charbonnier, Jean-Philippe Michel, Nicolas Buffet, and Pascal Chausse – CEA-LETI	2. 1:55 PM - Smart Packaging - Microscopic Temperature and Moisture Sensors Embedded in a Flip-Chip Package Aurore Quelennec, Yosri Ayadi, Quentin Vandin, and Dominique Drouin - Université de Sherbrooke; Éric Duchesne - IBM Canada, Ltd.; Hélène Frémont - Université de Bordeaux	2. I:55 PM - Improved Staggered Through Silicon Via Inductors for RF and Power Applications Xiao Sun, Geert Van der Plas, and Eric Beyne – IMEC
3. 2:20 PM - Experimentally Minimizing the Gap Distance Between Extra Tall Packages and PCB Using the Digital Image Correlation (DIC) Method Van Lai Pham, Yuling Niu, Jing Wang, Huayang Wang, Shuai Shao, Charandeep Singh and Seungbae Park — Binghamton University; Cheng Zhong, Sau Wee Koh and Jifan Wang — Huawei Technology Co., Ltd.	3. 2:20 PM - Improving Solder Joint Reliability for PoP Packages in Current Mobile Ecosystem Karthikeyan Dhandapani, Jiantao Zheng, Brian Roggeman, and Marcus Hsu — Qualcomm, Inc.	3. 2:20 PM - Realization of High Electrical Performance On-Chip Thick Copper Inductor Package by Via Interface Process Improvement for Metal Contact Ting-Li Yang, S. B. Yang, W. L. Huang, C. C. Chen, C. C. Kuo, G. C. Huang, K.Y. Wu, T.C. Chang, C. C. Hsu, C. L. Chang, H. L. Huang, Harry Ku, Edward Chen, K. C. Liu, Marvin Liao, and Alex Kalnitsky – Taiwan Semiconductor Manufacturing Company
Refreshment Break: 2	45 p.m 3:30 p.m. Harbor Island Fo	yer & Nautilus Foyer
4. 3:30 PM - Reliability of Ultra-thin Embedded Silicon Fan-out (eSiFO) Package Directly Assembled on PCB for Mobile Applications Cheng Chen and Lixi Wan – Institute of Microelectronics of Chinese Academy of Sciences; Teng Wang, Daquan Yu, Shuying Ma, and Zhiyi Xiao – Huatian Technology (Kunshan) Electronics Co., Ltd.; Kai Zhu – Huatian Technology (Xi'an) Electronics Co., Ltd.	4. 3:30 PM - Experimental Investigation on Temperature and Mean Stress Effects on High Cycle Fatigue Behavior of SnAgCu-Solder Alloy Youssef Maniar, Georg Konstantin, and Alexander Kabakchiev – Robert Bosch GmbH; Peter Binkele and Siegfried Schmauder – University of Stuttgart	4. 3:30 PM - An Approach for PDN Simplification of a Mobile Processor Sungwook Moon, Seungki Nam, Jungil Son, and Sunha Lee – Samsung Electronics Company, Ltd.
5. 3:55 PM - Interfacial Strength Characterization and Simulation on Stacked Copper-Polymer Structures in Fan-Out Packages Chia-Kuei Hsu, Po-Yao Lin, Wen-Yi Lin, Ming-Chih Yew, Shu-Shen Yeh, Kuang-Chun Lee, Jin-Hua Wang, Po-Chen Lai, Che-Chia Yang, and Shin-Puu Jeng – Taiwan Semiconductor Manufacturing Company	5. 3:55 PM - Water Effects in Polymers Through Molecular Dynamics Nancy Iwamoto – Honeywell International, Inc.	5. 3:55 PM - Design Optimization and Accurate Extraction of On-Die Decoupling Capacitors for High-Performance Applications Xiaoping Liu, Jihong Ren, Wendem Beyene, Simon Ku, Chin Hong Heah, and Sherman Hsu – Intel Corporation
6. 4:20 PM - Effects of Underfill on Thermo- Mechanical Behavior of Fan-out Wafer Level Package Used in PoP: An Experimental Study by Advancements of Real-Time Moiré Interferometry Bulong Wu and Bongtae Han – University of Maryland College Park	6. 4:20 PM - Comprehensive Study on 2.5D Package Design for Board-Level Reliability in Thermal Cycling and Power Cycling Shuai Shao, Yuling Niu, Jing Wang, Ruiyang Liu, and Seungbae Park - Binghamton University; Hohyung Lee, Gamal Refai-Ahmed, Laurene Yip - Xilinx, Inc.	6. 4:20 PM - Signal and Power Integrity Analysis of InFO Interconnect for Networking Application Po-Hao Chang, Chia-Yuan Hsieh, Chun-Wei Chang, Chih-Lun Chuang, and Chen-Feng Chiang — Mediatek, Inc.
7. 4:45 PM - Reliability Study of Large Fan- Out BGA Solution on FinFET Process C.K. Yu, W.S. Chiang, Cooper Peng, M.Z. Lin, Y.H. Fang, M.J. Lin, Benson Lin, Michael Huang, and P.S. Huang – MediaTek, Inc.	7. 4:45 PM - Comparative Study on Mechanical and Thermal Performance of eWLB, M-Series and Fan-Out Chip Last Packages Meng-kai Shih, Ryan Chen, PeterBS Chen, Ying-Chih Lee, Karen Yu Chen, lan Hu, Tang-Yuan Chen, Lung Tsai, Eatice Chen, Eddie Tsai, David Tarng, and Chih- Pin Hung — Advanced Semiconductor Engineering, Inc.	7. 4:45 PM - A System-In-Package Based Energy Harvesting for IoT Devices With Integrated Voltage Regulators and Embedded Inductors Edward Lee, Mohammad Amir, Sridhar Sivapurapu, Colin Pardue, Hakki Torun, Mohamed Bellaredj, Madhavan Swaminathan, and Saibal Mukhopadhyay – Georgia Institute of Technology

Interactive Presentations: Wednesday, May 30, 9:00 a.m. - 11:00 a.m. and 2:00 p.m. - 4:00 p.m.

Wednesday, May 30, 2018 Session 37: Interactive Presentations I 9:00 AM - I I:00 AM

Committee: Interactive Presentations Room: Nautilus Foyer, Lower Level Session Co-Chairs:

Mark Eblen – Kyocera International SC Email: mark.eblen@kyocera.com Patrick Thompson – Texas Instruments, Inc.

Email: patrick.thompson@ti.com

I) Achieving of Intensified Conductive Interconnections for Flex-On-Flex by Using Metal Passivated Copper-Copper Thermocompression Bonding

Hemanth Kumar Cheemalamarri, Satish Bonam, Nirupam Paul, Siva Rama Krishna Vanjari, and Shiv Govind Singh – Indian Institute of Technology, Hyderabad; Asisa Kumar Panigrahi – KL University Hyderabad Campus

2) Reliability Test of Organic Substrate Processed by New Desmear Method "PhotodesmearTM"

Shinichi Endo, Tomoyuki Habu, and Yasushi Muto – Ushio Inc.; Shintaro Yabu – Ushio America Inc.

3) Highly Conductive Stretchable Electrically Conductive Composites by Halogenation Treatment and Its Application in Stretchable Electronics

Peng Zheng, Haoyue Zhuo, Yuxiao Zou, and Zhuo Li – Fudan University; Wei Guo and Hao Wu – Huazhong University of Science and Technology

4) Electroplating Enhanced Silver Nanowire Networks for Transparent Heaters

Shang Wang and Yanhong Tian – Harbin Institute of Technology

5) Low Transmission Loss Film Material for High-Speed/High-Frequency Devices

Takao Tanigawa, Shin Takanezawa, Minoru Kakitani, Kohji Morita, Mami Shimada, and Etsuo Mizushima – Hitachi Chemical Co. Ltd.

6) Wet-Spun Graphene Sheet as Flexible Heat Spreader for Efficient Thermal Management

Guang Yang, Yuze Yan, and Zhuo Li – Fudan University; Chaowei Li and Yagang Yao – Chinese Academy of Sciences

7) Aging Characteristics of Green Mold Compound for Use in Encapsulation of Microelectronic Devices

Subramani Manoharan, Carlos Morillo, and Patrick McCluskey – University of Maryland; Chandradip Patel and Steven Dunford – Schlumberger Technology Corporation

8) Effective Stress Relief Without Jeopardizing Reliability in Overmolded Packages With Stress Buffers

Amar Mavinkurve, Jeroen Zaal, Yukai Liang, Sean Xu, Antoine Storez, Seng Kiong Teng, Yuan Guo, and Sheila Chopin – NXP Semiconductors

9) High-Temperature Mechanical Behavior of SAC and SAC+X Lead-Free Solders

Mohammad Alam, Jeffrey Suhling, Pradeep Lall, K.M. Rafidh Hassan – Auburn University

10) Flexible Wearable Biometric Band and Smartphone Application for Prevention of Sudden Causes of Death

Pradeep Lall and Hao Zhang – Auburn University; Rahul Lall – Stanford University

II) Backward Compatible Connectors for Next Generation PCIe Electrical I/O

Lei Shan and Daniel Freidman – IBM Corporation; Craig Kennedy, Warren Persak, and Kevin Lau – Amphenol Corporation

12) PCB Pin Area Wire Modeling Based on Representative Layer 2D Misregistration Zhaoqing Chen – IBM Corporation

13) Compact Low-Power Avionics for the Europa Lander Concept and Other Missions to Ocean Worlds

Don Hunter, Gary Bolotin, Doug Sheldon, Malcolm Lias, and Christopher Stell, and Jong-ook Suh – Jet Propulsion Laboratory

14) Optimization of Laser Release Process for Throughput Enhancement of Fan-Out Wafer-Level Packaging

Chia-Hsin Li, Qi Wu— Brewer Science, Inc.; Jay Su — Electronics and Optoelectronics Research Laboratories; Yu-Hua Chen — Unimicron Technology Corp; Yu-Min Lin — Electronics and Optoelectronics Research Laboratories; Xiao Liu— National Chiao Tung University; Jim-Wein Lin, Puru Lin, Cheng-Ta Ko, Yu-Hua Chen — Unimicron Technology Corp.; Wen/Wei Shen, Tzu-Ying Kou, Shin-Yi Huang, Ang-Ying Lin, Yu-Min Lin, Kuan-Neng Chen — ITRI

I5) Thermally Conductivity Underfill and Its Viscoelastic Properties Using Hexagonal Boron Nitride Nanofiller

Sara Razgaleh and Shyam Aravamudhan – Joint School of Nanoscience and Nanoengineering

16) Self-Assembly Technology for FlexTrate

Tak Fukushima – Tohoku University and University of California, Los Angeles; Yuki Susumago, Hisashi Kino, and Tetsu Tanaka – Tohoku University; Arsalan Alam, Amir Hanna, and Subramanian Iyer – University of California, Los Angeles

17) High-Performance EMI Shielding Materials and Spraying Process Parameters for High-Frequency FCBGA Package Application

Kisu Joo, Kyu Jae Lee, Jung Woo Hwang, Jin-Ho Yoon, Yoon-Hyun Kim, Joo-Wook Park, and Se Young Jeong – Ntrium Incorporation; Myung Jin Yim – Intel Corporation

18) Physical Aging of Epoxy Molding Compound and Its Influences on the Warpage of Reconstituted Wafer

Tz-Cheng Chiu and En-Yu Yeh – National Cheng Kung University; Wei-Jie Yin, Yu-Ting Yang, Dao-Long Chen, and Yi-Hsiu Tseng – Advanced Semiconductor Engineering, Inc.

19) High Thermal Conductive Semi-Sintering Die Attach Paste

Rajasekhar Peddi, Wei Yao, Kily Wu, Robin Fu, and Hoseun Yoo – Henkel Corporation

20) Non-Destructive Assessment of the Porosity in Ag-sinter Joints Using Acoustic Waves

Sebastian Brand, Bianca Böttge, Michael Kögel, Falk Naumann, and Frank Altmann – Fraunhofer IMVVS; Jurrian Zijl and Sebastiaan Kersjes – BESI Netherlands; Thomas Behrens – Infineon Technologies

22) Reliability Study and Finite Element Modeling of a Wearable Sensor Patch (WSP) to Monitor ECG Signals

Varun Soman, Mark Poliks, and James Turner – Binghamton University; Mark Schadt, Michael Shay, and Frank Egitto – i3 Electronics, Inc.

Wednesday, May 30, 2018 Session 38: Interactive Presentations 2

2:00 PM - 4:00 PM
Committee: Interactive Presentations
Room: Nautilus Foyer, Lower Level
Session Co-Chairs:

Rao Bonda

Amkor Technology Email: rao.bonda@amkor.com John Hunt

Advanced Semiconductor Engineering, Inc.

Email: john.hunt@aseus.com

I) Fabrication and Characteristics of Spin-on Dielectric for Multi-level Interconnect in WLP

Changmin Song, Sarah Kim, and Sungdong Kim – Seoul National University of Science and Technology

2) High Density TSV-Free Interposer (TFI) Packaging with Submicron Cu Damascene RDLs for Integration of CPU/GPU and HBM

Masaya Kawano, Chun-Mei Wang, Hong-Yu Li, Mian-Zhi Ding, Sharon Lim, Teck-Guan Lim, Zi-Hao Chen, and Fa-Xing Che – IME

3) Dynamic Warpage Analysis of QFP Packages During Soldering Reflow Process and Thermal Cycle

Marco Rovitto, Arianna Morelli, Carlo Passagrilli, and Claudio Maria Villa – STMicroelectronics

4) Improvement of Mechanical Properties of Zn Added Sn58Bi Alloy by Zn Segregation on the Sn-Bi Phase Boundaries During Thermal Aging

Shiqi Zhou, Omid Mokhtari, and Hiroshi Nishikawa – Osaka University

5) Low Dielectric Properties Encapsulation for High-Frequency Devices

Naoki Kanagawa, Daisuke Sasaki, and Shigeru Yamatsu

– Panasonic Corporation

6) Controlling Die Warpage by Applying Under Bump Metallurgy for Fan-Out Package Process Applications

Hwan-Pil Park and Young-Ho Kim – Hanyang University; Young-Moon Jang and Sung-Hoon Choa – Seoul National University of Science and Technology

7) Influence of Metallization and Size on Conductive Properties of Metal-Coated Polymer Particles in Anisotropic Conductive Adhesive

Molly Bazilchuk and Helge Kristiansen – Conpart AS; Jianying He – Norwegian Institute of Science and Technology

Interactive Presentations: Thursday, May 31, 9:00 a.m. - 11:00 a.m.

8) Demonstration of a Heterogeneously Integrated System-on-Wafer (SoW) Assembly

Adeel Ahmad Bajwa – University of California, Los Angeles and K&S; SivaChandra Jangam, Randall Irwin, Boris Vaisband, Saptadeep Pal, Mark Goorsky, and Subramanian Iyer – University of California, Los Angeles

9) Novel Temporary Adhesive Materials for RDL-First Fan-Out Wafer-Level Packaging

Hong Zhang, Xiao Liu, Rama Puligadda, Shawna RIckard, and Tony Flaim – Brewer Science, Inc.

10) The Reliability and the Effect of NCA Trapping in Thermo-compression Flip-Chip Solder Joints Fabricated Using Sn-Ag Solder Capped 40 µm Pitch Cu Pillar Bumps and Low Temperature Curable Non-conductive Adhesive (NCA)

Jae-Yong Park, Hwan-Pil Park, Seongchul Kim, and Young-Ho Kim – Hanyang University; Taeyoung Lee and Sehoon Yoo – Korea Institute Industrial Technology

II) Performance of Fine and Ultra-Fine Lead-Free Powders for Solder Paste Applications

Amir Nobari and Sylvain St-Laurent – 5N Plus Micro Powders Inc.; Yannig Thomas – National Research Council Canada; Arslane Bouchemit and Gilles L'Espérance – École Polytechnique de Montréal

12) Laser Based Full Cut Dicing Evaluations for Thin Si Wafers

Jeroen van Borkulo, Paul Verburg, and Richard van der Stam – ASM Pacific Technology

I3) Thermal Design and Characterization of High-Power SiC Inverter with Low Profile and Enhanced Thermal Performance

Gongyue Tang, Tai Chong Chai, and Xiaowu Zhang – IMF

14) Challenges of Large Body FCBGA on Board Level Assembly and Reliability

Fletcher (Cheng Piao) Tung, Chung (Hsiang Chun) Chen, Max (Chin Yu) Lu, Jensen Tsai, and Yu-Po Wang – Siliconware Precision Industries Co., Ltd.

15) Optimization of Via Bottom Cleaning for Bumpless Interconnects and Wafer-On-Wafer (WOW) Integration

Youngsuk Kim, S. Kodama, Y. Mizushima, N. Araki, and T. Ohba – Tokyo Institute of Technology; C. Hsiao, H. Chang, and C. Lin – Industrial Technology Research Institute of Taiwan

16) Design, Fabrication, and Characterization of TSV Interposer Integrated 3D Capacitor for SIP Applications

Jiwei Li and Shenglin Ma – Xiamen University; Huan Liu, Wei Wang, Yufeng Jin, Yong Guan, and Jing Chen – Peking University; Min Miu – Beijing Information Science and Technology University; Liulin Hu and Shuwei He – Chengdu Garner Haiwei Co., Ltd.

17) High-Speed Precision Handling Technology of Micro-Chip for Fan-Out Wafer Level Packaging (FOWLP) Application

Qianwen Chen, Li-wen Hung, Bing Dang, Bo Wen, Russell Budd, Jae-Woong Nah, Evan Colgan, and John Knickerbocker – IBM Corporation

18) A Novel Inorganic Substrate by Three-Dimensionally Stacked Glass Core Technology

Toshiki Iwai, Tajji Sakai, Daisuke Mizutani and Seiki Sakuyama – Fujitsu Laboratories, Ltd.; Kenji Iida, Takayuki Inaba, Hidehiko Fujisaki, and Yoshinori Miyazawa - Fujitsu Interconnect Technologies, Ltd.

19) High-Reliability Sintered Silver-Indium Bonding With Anti-Oxidation Property for High-Temperature Applications

Chun An Yang and C. Robert Kao – National Taiwan University; Hiroshi Nishikawa – Osaka University; Chin C. Lee – University of California, Irvine

20) RF Characterization, Analysis and Miniaturization Impact of RDL Interconnects

Hélène Jacquinot, Roselyne Ségaud, Lucile Arnaud, Jean-Charles Barbe, and Séverine Cheramy – CEA-LETI; Kévin Morot, Alexis Farcy, and Rémi Velard – ST-Microelectronics; Thierry Lacrevaz and Bernard Flechet – IMEP-LAHC

21) Integration of the SERF Magnetometer and the Mz Magnetometer Using Micro-Fabricated Alkali Vapor Cell

Jin Zhang, Jintang Shang, Yu Ji, Guoliang Li, Lin Lu, and Zhihua Pan – Southeast University; Ching-Ping Wong – The Chinese University of Hong Kong

22) Integrated Copper Heat Spreaders in Glass Panel Embedded Packages with Near-Zero Thermal Interface Resistance

Nithin Nedumthakady, Bartlet DeProspo, Venkatesh Sundaram, P. Markondeya Raj, and Rao Tummala – Georgia Institute of Technology; Sean Garrison, Kyle Byers, and Barbara Reed – Honeywell Federal Manufacturing and Technologies, LLC; Chris Gibson and Michael Elsbury - Sandia National Labs

23) Investigation of Material Dynamic Processes During Shear Test of Heavy Wire Bond Contacts

Robert Klengel, Sebastian Tismer, Falk Naumann, and Sandy Klengel – Fraunhofer IMWS

24) Leading-Edge and Ultra-Thin 3D Glass-Polymer 5G Modules With Seamless Antenna-to-Transceiver Signal Transmissions

Atom Watanabe, Tong-Hong Lin, Markondeya R. Pulugurtha, Venky Sundaram, Manos M. Tentzeris, and Rao R. Tummala – Georgia Institute of Technology; Tomonori Ogawa – Asahi Glass Company

25) Effect of Surface Finish and High Bi Solder Alloy on Component Reliability In Thermal Cycling

Sa'd Hamasha, Francy Akkara, Jeffery Suhling, John Evans, Mohammed Abueed, Mumen Rababah, Cong Zhao and Sianan Su – Auburn University

26) Electromigration Behavior and Mechanical Properties of the Whole Preferred Orientation Intermetallic Compound Interconnects for 3D Packaging

Mingliang Huang, Lin Zou, and S. Q. Yin – Dalian University of Technology

Thursday, May 31, 2018
Session 39: Interactive Presentations 3
9:00 AM - 11:00 AM
Committee: Interactive Presentations
Room: Nautilus Foyer, Lower Level
Session Co-Chairs:

Nam Pham IBM Corporation

Email: npham@us.ibm.com Ibrahim Guven Virginia Commonwealth University Email: iguven@vcu.edu

I) 3D Stacking Process With Thermo-Sonic Bonding Using Non-Conductive Film

Shigeru Yamatsu, Kazuki Watanabe, Naoki Kanagawa, Teppei Kojio, and Takatoshi Ishikawa, Panasonic Corporation

2) 2D Magnetic Inductors for DC-DC Converters on Glass Interposer

Vincent Lafage, Yann Beillard, and Dominique Drouin – Université de Sherbrooke; Arvind Sridhar and Thomas Brunschwiler – IBM Zurich

3) Modeling and Characterization of a Hermetic Ceramic Package and Its Performance Impact on a 1.5-7V Input, 3-A, Radiation-Hardened Ultra-Low Dropout (LDO) Regulator

Javier Valle, Li Ming, Jeff Holloway, and Leon Stiborek – Texas Instruments, Inc.

4) Electrical Characterization of a High-Speed HBM Interface for a Low-Cost Interposer

Andy Heinig, Fabian Hopsch, and Michael Dittrich – Fraunhofer IIS/EAS

5) Millimeter-Wave Wireless Chip-to-Chip (C2C) Communications in 3D System in Packaging (SiP) Using Compact Through Glass Via (TGV)-integrated Antennas

Seahee Hwangbo and Yong-Kyu Yoon – University of Florida; Aric Shorey – Corning, Inc.

6) Reliability of Sintered and Soldered High-Power Chip Size Packages and Flip-Chip LEDs

Alexander Hanss, Maximilian Schmid, Gordon Elger, and Sri Krishna Bhogaraju – Technische Hochschule Ingolstadt; Fosca Conti – University of Padova

7) Comparison of Package-on-Package Technologies Utilizing Flip Chip and Fan-Out Wafer Level Packaging

Amy Lujan – SavanSys Solutions LLC

8) Fork Type Structure of Silicon Waveguide for Optical Coupling Efficiency Optimization

Meiju Lu – Advanced Semiconductor Engineering, Inc.; Warren Wang, OnionZY Yang, Shian Tu, Meiju Lu, Jihan Chen, and Vincent Lin – Corporate R&D / Optical Communication SiP Technology

9) MEMS Optical Packaging Technology Trends and Challenges

John Miranda – STATS ChipPAC, Inc.; TaeKeun Lee – STATS ChipPAC Korea, Ltd.

10) Effect of Improved Optimization of DFE Equalization on Crosstalk and Jitter in High-Speed Links With Multi-Level Signal

Nana Dikhaminjia and M. Tsiklauri – Ilia State University; Han Deng, Jiayi He, and James Drewniak – Missouri University of S&T; Arun Chada and Bhyrav Mutnury – Dell, Inc.

Thursday & Friday Refreshment Breaks: 9:15 a.m. - 10:00 a.m. and 2:45 p.m. - 3:30 p.m. • See pages 15-22 for locations.

Interactive Presentations: Thursday, May 31, 9:00 a.m. - 11:00 a.m. and 2:00 p.m. - 4:00 p.m.

II) Copper Transparent Antennas on Flexible Glass by Subtractive and Semi-Additive Fabrication for Automotive Applications

Jack Lombardi, Robert Malay, and Mark Poliks – Binghamton University; James Schaffner and Hyok Jae Song – HRL Laboratories; Ming-Huang Huang and Scott Pollard – Corning, Inc.; Timothy Talty – General Motors

12) Correlated Model for Wafer Warpage Prediction of Arbitrarily Patterned Films

Gregory Ostrowicki, Siva Gurrum, and Amit Nangia – Texas Instruments, Inc.

I3) Thermomechanical Properties of Fan-Out Wafer-Level Package with Various Chip and Mold Thickness

Haksan Jeong, Woo-Ram Myung, Kwang-Ho Jung, and Seung-Boo Jung – Sungkyunkwan University

14) Design of a Compact Broadband Butler Matrix and Its Application in Organic Beam-Former at the 5 GHz Band

Chung-Yi Hsu, Chia-Ling Chiang, and Lih-Tyng Hwang – National Sun Yat-Sen University; Fa-Shian Chang – Cheng Shiu University

I5) Three-Dimensional Simulation of Effects of Microstructure Evolution and Interfacial Delamination on Cu Protrusion in Copper Filled Through Silicon Vias by Combined Monte Carlo and Finite Element Methods

Shui-Bao Liang, Chang-Bo Ke, Cheng Wei, Min-Bo Zhou, and Xin-Ping Zhang — South China University of Technology

16) Electrical Design for the Development of FOWLP for HBM Integration

Teck Guan Lim and David Ho Soon Wee – Institute of Microelectronics

I7) Accurate Electrical Modeling of Through Silicon Via with Minority Carrier Redistribution Effect

Huan Liu, Runiu Fang, and Xin Sun – Peking University; Min Miao – Beijing Information Science and Technology University; Yufeng Jin – Shenzhen Graduate School of Peking University

18) Thermal and Electrical Characterization of TSV Interposer Embedded With Microchannel for 2.5D Integration of GaN RF Devices

Han Cai and Shenglin Ma –Xiamen University; Wei Wang, Yufeng Jin, and Jing Chen – Peking University; Weiwei Xiang and Jian Zhang – Southwest China Research Institute of Electronic Equipment; Liulin Hu and Shuwei He - Chengdu Ganide Technology Co., Ltd.

19) Alternative Deposition Solution for Cost Reduction of TSV Integration

Julien Vitiello and Fabien Piallat - KOBUS

20) Evaluation of Mechanical Stress Induced During IC Packaging

Vladimir Cherman, Melina Lofrano, Mario Gonzalez, Francisco Cadacio Jr., Kenneth June Rebibis, and Eric Beyne – IMEC; Akihito Takano and Mitsutoshi Higashi – Shinko Electric Industries, Co. Ltd.

21) Wireless EAS Sensor Tags for Volatile Profiling in Food Packages

Saranraj Karuppuswami, Mohd Ifwat Mohd Ghazali, Saikat Mondal, and Premjeet Chahal – Michigan State University

22) High Throughput and Improved Edge Straightness for Memory Applications Using Stealth Dicing

Natsuki Suzuki and Takayuki Oba – Tokyo Institute of Technology; Yuta Kondo, Takeshi Sakamoto, Kazuhiro Atsuki, and Naoki Uchiyama – Hamamatsu Photonics K.K.

23) Thick 3D Printed RF Components: Transmission Lines and Bandpass Filters

Kyoung Youl Park – Agency for Defense Development; Mohd Ifwat Ghazali and Premjeet Chahal – Michigan State University; Nophadon Wiwatcharagoses – King Mongkut's University of Technology North Bangkok

24) Introduction of a New Metric for the Solder Joint Reliability Assessment of BGA Packages on System Level

Fabian Schempp, Marc Dressler, Daniel Kraetschmer, and Friederike Loerke – Robert Bosch GmbH; Juergen Wilde – University of Freiburg, IMTEK

25) Compact Optical Coherent Receiver for Avionics Applications

Simon Ayotte, Ghislain Bilodeau, Jocelyn Blanchet-Létourneau, Michel Morin, Pascal Deladurantaye, Francois Costin, André Babin, Louis-Philippe Perron, Guillaume Brochu, C. A. Davidson, D. D'Amato, É. Girard-Deschênes, P. Chrétien, M. Laplante, M. Drolet, G. Paré-Olivier – Teraxion

26) Parylene as a Dielectric Material for Electronic Applications in Space

Franz Selbmann – Fraunhofer ENAS; Mario Baum - TU Bergakademie Freiberg & Fraunhofer ENAS Chemnitz; Maik Wiemer - Fraunhofer ENAS Chemnitz; Yvonne Joseph - TU Bergakademie Freiberg; Thomas Otto - TU Chemnitz & Fraunhofer ENAS Chemnitz

27) On Using Packaging Parasitics to Implement a Tunable Matching Circuit for Low Power Wake-Up Receivers

 $\label{eq:continuous} \mbox{Jack Ou-California State University, Northridge}$

Thursday, May 31, 2018 Session 40: Interactive Presentations 4 2:00 PM - 4:00 PM

Committee: Interactive Presentations Room: Nautilus Foyer, Lower Level Session Co-Chairs: Swapan Bhattacharya

Engent Inc.

Email: Swapan.bhattacharya@engentaat.

Mark Poliks

Binghamton University Email: mpoliks@binghamton.edu

I) Practical Design Method to Reduce Crosstalk for Silicon Wafer Integrated Fan-Out Technology (SWIFT)

HoJeong Lim, JeongKyu Yang, and Ruben Fuentes – Amkor Technology, Inc.

2) Fully Inkjet-Printed Three-Dimensional Bandpass Filter on Liquid Crystal Polymer Substrate

Hsuan-Ling Kao – Chang Gung University; Cheng-Lin Cho – National Tsing Hua University

3) A Dynamic Bending Method for PoP Package Board Level Reliability Validation

Jeffrey Lee and Cheng-Chih Chen – iŠT-Integrated Service Technology Inc; Lane Brown, Esme Mehretu, Thomas Obrien, and Feng Lu – Motorola Lenovo

4) Eliminating Harmful Intermetallic Compound Phase in Silver Wire Bonding by Alloying Silver with Indium

Chin C. Lee and Jiaqi Wu – University of California, Irvine

5) Cyanate Ester/Epoxy Co-Curing System With Thermal Stabilizers for High-Temperature Stability

Fan Wu, Bo Song, Kyoung-Sik Moon, and C.P. Wong – Georgia Institute of Technology

6) Demonstration of 28 GHz Band Pass Filter Toward 5G Using Ultra Low Loss and High Accuracy Through Quartz Vias

Yoichiro Sato and Nobutaka Kidera – Asahi Glass Co., Ltd.

7) Micromesh-Enabled Low-Cost Thermal Ground Planes for High Heat Flux Power Electronics

Shanshan Xu, Ryan Lewis, Rongfu Wen, Ronggui Yang, and Y.C. Lee – University of Colorado, Boulder; Luu Nguyen and Woochan Kim-Texas Instruments, Inc.

8) 3D Integration of Physics System Using Foldable Packaging for MEMS Atomic Clocks

Jongcheol Park, Tae Hyun Kim, Hee Yeoun Kim, Gil Sun Roh, Gapseop Sim, HaeCheol Hwang, and JinWon Ko – National NanoFab Center; Taeg Yong Kwon and Hyun Gue Hong – Korea Research Institute of Standards and Science

9) Die Edge Crack Propagation Modeling for Risk Assessment of Advanced Technology Nodes

Tingge Xu, Zhuo-Jie Wu, Haojun Zhang, Carole Graas, and Patrick Justison – GLOBALFOUNDRIES

10) Development of a Through-Silicon Via (TSV) Process Module for Multi-Project Wafer SiGe BiCMOS and Silicon Interposer

Matthias Wietstruck, Steffen Marschmeyer, Philipp Kulse, Thomas Voß, Marco Lisker, Andreas Krüger, Dirk Wolansky, Mirko Fraschke, and Mehmet Kaynak – IHP

II) A New, Efficient Method for Preparation of 3D Integrated Systems by Laser Techniques

Robert Klengel, Sandy Klengel, Georg Schusser, and Michael Krause – Fraunhofer IMWS

I2) Effect of Interaction Between Multiple Defects on Z-Depth Estimate in Lock-In Thermography Applications

Bharath Viswanath Ravi, Mayue Xie, and Deepak Goyal – Intel Corporation

13) Practical High-Speed PCB Stackup Tool – Generation and Validation

Wei Jiang, Kevin Cai, and Bidyut Sen – Cisco Systems, Inc; Guoan Wang – University of South Carolina

14) Volatile Molecular Sensors Using Terahertz Resonators on Porous Substrates

Saranraj Karuppuswami, Jennifer Byford, and Premjeet Chahal – Michigan State University

I5) Effects of the Adhesion Strength on the Bending Fatigue Behavior of Cu Pattern Laminated Fabrics Using B-Stage Non-Conductive Films (NCFs)

Seung-Yoon Jung and Kyung-Wook Paik – Korea Advanced Institute for Science and Technology

16) Process Development of 4-die Stack Module Using Moldable Underfill

Ser Choong Chong, Hongyu Li, Ling Xie, Simon Boon Lim, and Zhaohui Chen – Institute of Microelectronics

17) Integrated Fully Solid-State Capacitor Based on Carbon Nanofibers and Dielectrics

Rickard Andersson, Amin Muhammad Saleem, and Vincent Desmaris – Smoltek AB

Interactive Presentations: Friday, June 1, 8:30 a.m. - 10:30 a.m.

18) Effects of ACFs Modulus and Adhesion Strength on the Bending Reliability of CIF (Chip-in-Flex) Packages in Thermal and Humid Conditions

Tae-Ik Lee, Taek-Soo Kim, Kyung-Wook Paik, and Ji-Hye Kim – Korea Advanced Institute of Science and Technology

19) Warpage Simulation / Experiments and Analysis of 12" Wafer-Level Fan-Out Packaging Technology

Jia-Shen Lan and Mei-Ling Wu — National Sun Yat-sen University; Shang Lee, Yaochen Wang, Brian Wu, and Chiyu Wang — Advanced Semiconductor Engineering, Inc.

20) Design Considerations of a Matching Circuit for Low-Power Wake-Up Receivers

Jie Geng, Hongwen Zhang and Francis Mutuku – Indium Corporation

21) Warpage and Reliability Challenges for Stacked Silicon Interposer Technology in Large Packages

Scott McCann, HoHyung Lee, Gamal Refai-Ahmed, Tom Lee, and Suresh Ramalingam – Xilinx, Inc.; Ning-Cheng Lee – Indium Corporation

22) Effect of Shallow Cycling on Flexible Power-Source Survivability Under Bending Loads and Operating Temperatures Representative of Stresses of Daily Motion

Pradeep Lall and Amrit Abrol – Auburn University; Jason Marsh – NextFlex; Ben Leever – US AFRL

23) Nanomechanical Characterization of Intermetallic Compounds in Lead Free Solder Joints

Abdullah Fahim, Sudan Ahmed, Jeffrey Suhling, and Pradeep Lall – Auburn University

24) Fan-Out Wafer Level Packaging for Heterogeneous Integration

John Lau, Ming Li, Margie Li, Nelson Fan, Eric Kuah, Y. M. Cheung, Eric Ng, Penny Lo, Wu Kai, and Ji Hao – ASM Pacific Technology, Ltd.; Tony Chen, Iris Xu, Zhang Li, and Kim Hwee Tan – Jiangyin Changdian Advanced Packaging Co. Ltd.; Qing Xiang Yong, Zhong Cheng, Koh Sau Wee, Jiang Ran, and Cao Xi – Huawei Technologies Co. Ltd.; Rozalia Beica – Dow Chemical Company; Sze Pei Lim and N. C. Lee – Indium Corporation; Cheng-Ta Ko, Henry Yang, and Y. H. Chen – Unimicron Technology Corporation; Mian Tao, Jeffrey Lo, and Ricky Lee – Hong Kong University of Science and Technology

Friday, June 1, 2018 Session 41: Student Interactive Presentations

8:30 AM - 10:30 AM
Committee: Interactive Presentations
Room: Nautilus Foyer, Lower Level
Session Co-Chairs:
Michael Mayer

University of Waterloo Email: mmayer@uwaterloo.ca Pavel Roy Paladhi IBM Corporation

Email: Pavel.Roy.Paladhi@ibm.com

I) Broad-Band Dielectric Probes for On-Wafer Characterization of Terahertz Devices Jennifer Byford and Premjeet Chahal – Michigan State

University 2) Machine Learning Driven Advanced Packaging and Miniaturization of IoT for Wireless Power Transfer Solutions

Hakki Torun, Colin Pardue, Mohamed Belladredj, Anto K. Davis, and Madhavan Swaminathan – Georgia Institute of Technology

3) Application of Additive Manufacturing Technologies for Realization of Multilayer Microstrip Directional Filter

Ilona Piekarz, Jakub Sorocki, Slawomir Gruszczynski, and Krzysztof Wincza – AGH University of Science and Technology; John Papapolymerou – Michigan State University

4) 3D Printed Liquid Jet Impingement Cooler: Demonstration, Opportunities and Challenges

Tiwei Wei, Herman Oprins, Vladimir Cherman, Ingrid De wolf, and Eric Beyne – IMEC; Martine Baelmans and Shoufeng Yang – KU Leuven

5) Design and Surface Modification of PET Substrates Using UV/Ozone Treatment for Roll-to-Roll Processed Solar Photovoltaic (PV) Module Packaging

Bo Song, Jinho Hah, Kyoung-sik Moon, C.P. Wong, and Samuel Graham – Georgia Institute of Technology

6) A Study on the High-Frequency Performance and Physical Modelling of ACFs Joints Using Coplanar Waveguide for Flexon-Board Applications

Shuye Zhang, Tiesong Lin, and Peng He – Harbin Institute of Technology; Junyong Park, Gapyeol Park, Huijin Song, Joungho Kim, and Kyung-Wook Paik – Korea Advanced Institute of Science and Technology

7) Low-Temperature Cu-Cu Bonding by Anti-Oxidative Copper Nanoparticle Paste

Yun Mou, Yang Peng, Junjie Li, Hao Cheng, Xingxing Liu, and Mingxiang Chen – Huazhong University of Science and Technology

8) Deep Understanding of the Role of Cu in RDL to Warpage by Exploring the Warpage Evolution With Microstructural Changes

Gong Cheng, Gaowei Xu, Wei Gai, and Le Luo – Shanghai Institute of Microsystem and Information Technology

9) A 56 Gbps I/O Interface Design with Exact Power Source Simulation - Total I/O Circuit Design with over 28 GHz from Driver to Receiver Device Models

Daisuke Ogawa, Chihiro Ueda, Kaoru Hashimoto, and Kanji Otsuka – Meisei University; Daisuke Iguchi, Yusuke Taira, Nobutaka Hara, and Yusuke Niisaka – Fuji Xerox Co., Ltd.; Naoto Yoshii – Murata Manufacturing Co., Ltd.

10) Enhancements on Underfill Materials' Thermal Conductivity by Insulation Coating Layer Control of Conductive Particles

Tae-Ryong Kim – Seoul National University/Ntrium; Kisu Joo and Se Young Jeong – Ntrium Incorporation; Boo Taek Lim and Boung Ju Lee – National Nanofab Center; Sung-Soon Choi – Korea Electronics Technology Institute; Euijoon Yoon – Seoul National University

II) Fabrication of Fe-3.5 wt.%Si Magnetic Cores for Power Electronic Converters by Selective Laser Melting

Wangyun Li, Jing Wang, Guang Chen, Daniel Engstrom, and Changqing Liu – Loughborough University; Xinping Zhang – South China University of Technology; Adam Walker and Gaurang Vakil – University of Nottingham; Andrew Forsyth – University of Manchester

12) Accurate Core Alignment for Polymer Optical Waveguide in the Mosquito Method for High-Efficient Coupling

Takaaki Ishigure, Kumi Date, and Yoshie Morimoto – Keio University

I 3) Synthesis of a Graphene CarbonNanotube Hybrid Film by Joule Self-HeatingCVD for Thermal Applications

Josef Hansson, Majid Kabiri Samani, Andreas Nylander, Nan Wang, Torbjörn Nilsson, and Johan Liu – Chalmers University of Technology; Lilei Ye – SHT Smart High Tech AB

14) Size and Shape Effect in the Determination of the Fracture Strength of Silicon Nitride in MEMS Structures at High Temperatures

 $\label{eq:Alex-Axel-Navarrete} Alex Axel \ Navarrete \ Gonzalez, \ Eric \ Brace, \ and \ Patricia \\ Nieva - University \ of \ Waterloo$

I 5) A Study on the Curing Properties and Viscosities of Non-Conductive Films (NCFs) for Sn-Ag Solder Bump Flip Chip Assembly

HanMin Lee, SeYong Lee, JongHo Park, and Kyung-Wook Paik – Korea Advanced Institute of Science and Technology; Chang-kyu Chung, Kyung-Woon Jang, Il Kim, and SeongWoo Choi – Samsung Electronics Company, Ltd.

16) Suspended Microstrip Low-Pass Filter Realized Using FDM Type 3D Printing with Conductive Copper-Based Filament

Jakub Sorocki, Ilona Piekarz, Slawomir Gruszczynski, and Krzysztof Wincza – AGH University of Science and Technology; John Papapolymerou – Michigan State University

17) Modeling and Design of 2.5D Package With Mitigated Warpage and Enhanced Thermo-Mechanical Reliability

Jing Wang, Yuling Niu, and Seungbae Park – Binghamton University; Alexander Yatskov – Juniper Networks

18) Piezoelectric Ceramics and Flexible Printed Circuits (FPCs) Interconnection Using Anisotropic Conductive Films (ACFs) for Ultrasound Transducers Assembly

Jae-Hyeong Park and Kyung-Wook Paik – Korea Advanced Institute of Science and Technology

19) Design, Fabrication and Characterization of a Novel TSV Interposed Integrated Inductor for RF Applications

Yunheng Sun, Yufeng Jin, Wei Wang, and Jing Chen – Peking University; Han Cai, Jiwei Li, and Shenglin Ma – Xiamen University; Min Miao – Beijing Information Science and Technology University; Liulin Hu and Shuwei He – Chengdu Ganide Technology

20) A Novel Integration of Stereolithography and Inkjet Printing for Multichip Modules with High Frequency Packaging Applications

Ryan Bahr, Bijan Teharani, and Manos Tentzeris

– Georgia Institute of Technology; Kyle Byers –
Honeywell International, Inc.

Thursday & Friday Refreshment Breaks: 9:15 a.m. - 10:00 a.m. and 2:45 p.m. - 3:30 p.m. • See pages 15-22 for locations.

2018 TECHNOLOGY CORNER EXHIBITS AND INTERACTIVE PRESENTATIONS

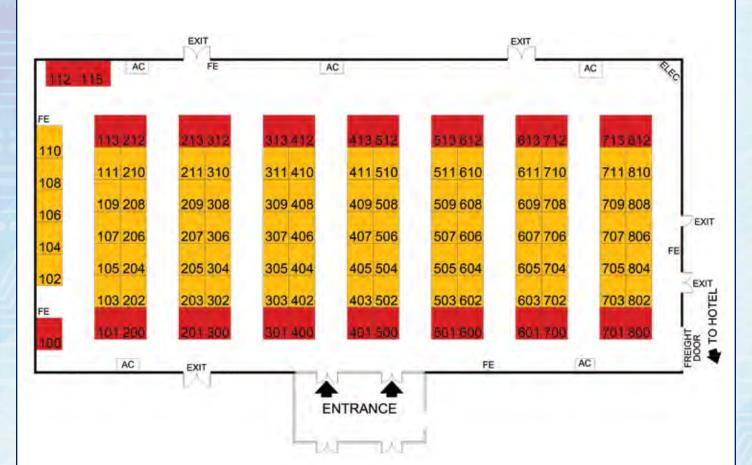
Technology Corner Exhibits

Wednesday, May 30

9:00 a.m. - 12:00 Noon / 1:30 p.m. - 6:30 p.m.

Thursday, May 31

9:00 a.m. - 12:00 Noon / 1:30 p.m. - 4:00 p.m. Bayview Pavilion



Interactive Presentation Sessions

Wednesday, May 30

Session 37: 9:00 a.m. - 11:00 a.m. / Session 38: 2:00 p.m. - 4:00 p.m.

Thursday, May 31

Session 39: 9:00 a.m. - 11:00 a.m. / Session 40: 2:00 p.m. - 4:00 p.m.

Friday, June 1

Session 41: 8:30 a.m. - 10:30 a.m. Nautilus Foyer, Lower Level

TECHNOLOGY CORNER EXHIBITORS

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The 3D Systems Packaging Research Center (PRC) at the Georgia Institute of Technology is a Center dedicated to leading-edge research, education of highly interdisciplinary students and global industry collaborations in the System-on-a-Package (SOP) vision to enable highly miniaturized, mega-functional systems in a single package. Led by Prof. Rao Tummala, the PRC's research encompasses advanced 3D systems packaging technologies including: electrical, mechanical and thermal design; ultrathin and ultra-high density glass interposers and packages; ultrafine pitch chip-level and board-level interconnections; passive and active components and integration into power, RF, photonic and analog modules. The PRC model for industry collaboration is enabled by a world-class team of cross-disciplinary academic and research faculty, students, visiting industry engineers, and supply-chain manufacturers. The current industry consortium at PRC consists of the most comprehensive industry ecosystem of material and tool suppliers, substrate and assembly manufacturers, and end users in a wide variety of consumer and high-performance applications including high-performance cloud computing and networking. New applications being integrated into the consortium are new era of automotive electronics that include connectivity and infotainment, autonomous driving and all-electric cars requiring high-power and high-temperature electronics.

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ASM Pacific Assembly Products is a sales and marketing division of ASM Pacific Technology (ASMPT). ASMPT is the world leader in back-end IC assembly equipment, SMT equipment, and lead frame materials. With a vision of providing cost effective solutions, we offer assembly equipment and lead frame technology that are in the forefront of the semiconductor industry.

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The S3IP is a research and development organization that addresses research challenges in electronics packaging system design, process development, prototyping, and manufacturing for academia and the microelectronics industry. Located at Binghamton University, the Center brings together partners from government, industry and academia, providing opportunities for collaborations that will advance microelectronics research and development, with particular focus on electronics packaging design and manufacturing technology; thermal analysis and management for electronics; characterization of materials, surfaces, and physical interfaces for electronics devices and assemblies; and failure analysis and reliability improvement for electronics. Subject areas addressed include packaging of microelectronics, 2.5D/3D chip assemblies, power electronics, and integrated photonics.

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CEA-LETI is an institute providing R&D and prototyping services in the field of Micro and Nanotechnologies. Capabilities include 8" and 12" wafer process flows for advanced CMOS, 3D stacking, MEMS and Silicon Photonics. Based in Grenoble, France, CEA-LETI has offices in the US and Japan. Over the past 10 years CEA-

LETI has developed a wide range of expertise in the fields of silicon interposers and high density interconnects to address the needs of the semiconductor industry in market segments such as mobile telephones and low power computing. Leti is working on hybrid bonding, wafer-towafer or chip-to wafer integration. Pitch of few microns is envisioned, without underfill, room temperature and ambient pressure bonding. Selfalignment using capillary force is also developed for high-precision, high-throughput chip-to-wafer bonding. With the support of its internal IC design teams, LETI provides industrial partners with a unique environment for validating new concepts through models, new design tools, test vehicles and implementing fully functional demonstrators such as wide I/O memory standard, 60 GHz RF SOCs for video data transfer or photonic interposers. Recently CEA-LETI has developed CoolCube, an original technique for stacking transistors sequentially in the same process flow for 3D-VLSI. The technology is designed to allow a connection of the stacked active layers on a nanometric scale, with a very high density, due to their alignment by a standard lithographic process. CEA-LETI is embedded in a dynamic and international ecosystem that include European and Global leaders.

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Dynaloy develops, manufactures, and markets world class advanced cleaning solutions for the semiconductor industry. Thoroughly removing photoresist and other residues is a critical part of enhancing device performance. In short, cleaning matters in this fast-paced and competitive industry. That's why Dynaloy offers custom and stock formulations to tackle the full range of jobs, from the least complicated to the most challenging. Whether you're removing photoresist or residue, Dynaloy's portfolio includes products for unique cleaning applications in the wafer-level packaging market. Dynaloy offers the solutions for silicon post-etch residue removal, Cu μ-pillar bumping and fan-out wafer-level packaging (FO-WLP) photoresist removal. Our professional staff is committed to helping engineers achieve optimum performance through creative product development, chemical expertise, unmatched technical support and steadfast customer service. Dynaloy is a subsidiary of Eastman Chemical Company.

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EMD Performance Materials, an affiliate of Merck KGaA, Darmstadt, Germany is proud to partner with ECTC to exhibit and introduce its material solutions for the semiconductor industry. Our Semiconductor Solutions business unit develops, produces and sells materials used in the manufacturing of integrated circuits. EMD champions many innovative technologies for the semiconductor industry with key and enabling results to meet future technology node requirements. Thanks to comprehensive investments in research & development, we are constantly extending our leadership position as an innovator and reliable partner. Our chemical deliveries make a difference in the development of NAND/FLASH/DRAM memory, microprocessor chips, mobile packaging modules, internet of things, artificial intelligence and big data storage.

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From 5G networks and the new micro LED display technology to EMI shielding for our smartphones, our thin film deposition systems enable manufacture of the worlds highest performance semiconductor, optoelectronic and optical devices. Evatec Advanced Process Control technologies enables new levels of production yields for the most challenging thin film performance specifications in Advanced Packaging, Power Devices, MEMS, Wireless Communication, Optoelectronics and Photonics. Within Advanced Packaging, our solutions on **HEXAGON** and **CLUSTERLINE** deliver high yield UBM / RDL production with stable low Rc values at up to 56 wafers per hour in FOWLP. Combining our latest batch degas, etch and deposition technologies achieves the even lower Rc values of < I mOhm needed for contacts and interconnects for next-generation power management in IOT applications. For FOPLP applications, our PNL cluster tools offer high throughput production up to 25 panels per hour on panel sizes of 500mm for low CoO.

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ficonTEC provides a wide range of micron- and submicron-precision T&M, vision inspection, and assembly automation systems for opto-electronic, fiber-optic/array and micro-optics components, among others. Such automation systems for applications include submicron-precision LDB/ die bonding, LDB stacking-unstacking, microlens assembly (e.g., FAC, SAC, mirror, etc.), OE component attachment, and integrated photonic device assembly. ficonTEC is also the recognized industry leader in SiPh device test, inspection, and assembly automation systems for various product development and production requirements. Our systems are designed for high-yield and -throughput, -precision semiand full-automation production environment. ficonTEC's system platforms are pre-engineered for specific applications, where each platform for given application can be optimized for the unique needs of each customer, resulting in a competitive technical advantage. ficonTEC assists its customers with their 'lab-to-fab' activities through collaborative product/process development activities, leveraging our extensive experiences for customers' rapid time-to-market needs. Please discuss ficonTEC's capabilities for your application(s) at our booth.

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Finetech supplies sub-micron accuracy die bonders for die attach, advanced packaging and micro assembly applications. Manual, motorized and automated models provide high process flexibility within one platform - utilizing a modular, flexible design. Bonding technologies include thermo-compression, ultrasonic, eutectic, epoxy, sintering, ACF/ACP, Indium and precision vacuum die bonding. Applications areas cover optical packages, sensors, Si photonics, microLEDs, C2W, Cu pillar, focal plane arrays, chip-on-glass, chip-on-flex and more. Finetech also provides precision dispensers and advanced rework systems for today's challenging applications. The deep process knowledge we have gained through decades of experience adds value to our equipment. Our engineers work with customers to create effective solutions for specific applications - they understand that "one size" does not necessarily fit all.

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FCI supplies turnkey advanced packaging and test services focused on the consumer, automotive, medical, and industrial industries. FCI supports a wide range of customers frequently partnering with them to engineer customized solutions including expedite bumping and backend services on Multi-Project Wafers. FCI is a leader in wafer-level packaging with patented technologies spanning from Cu Pillar Bumping, Spheron™ Wafer Level Chipscale Packaging, and ChipsetT™ Embedded Die Packaging. FCI is a division of Huatian Technologies (HT). HT is among the top five OSATs in the world with \$1.3 billion in annual revenue. It is listed on the Shenzhen Stock Exchange Market. Huatian Technology Group operates six ISO/IATF16949 factories located within China and the U.S. Huatian's world-class factories offer a complete range of semiconductor packaging and turnkey services.

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Fraunhofer IMWS-CAM is a leading service provider of failure diagnostics and material assessment for industry including semiconductor technologies, microelectronic components, microsystems and nanostructured materials. We consider the entire workflow, from non-destructive defect localization over high precision target preparation to cutting edge nanoanalytics supplemented by micro-mechanical testing, finite element modeling and numerical simulation. Our goal is to support cooperation partners in introducing innovative materials and technologies, improving manufacturing process steps, securing reliable field use of components, analyzing field returns, and consequently optimizing manufacturing yield, product quality, reliability, and cost efficiency. In addition, we are collaborating with suppliers of microstructure diagnostics and material testing equipment in developing innovative failure analysis methods and instrumentation, problem-adapted work flows for quality and reliability control, and new industrycompatible applications for future markets.

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Invisible – but indispensable – nowadays nothing works without highly integrated microelectronics and microsystem technology. Reliable and cost-effective assembly and interconnection technologies are the foundation of integrating these in products. Fraunhofer IZM, a worldwide leader in the development and reliability analysis of electronic packaging technologies, provides its customers with tailor-made system integration technologies on wafer, chip and board level. Our research also ensures that electronic systems are more reliable, so that we can accurately predict lifecycle.

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FUJIFILM Electronic Materials is a leading supplier of advanced materials to the electronics industry. We offer full complement of advanced photoimageable and non-photoimageable polyimide and PBO materials designed to meet current and future packaging requirements, as well as temporary bonding materials tailored for demanding wafer thinning applications. Fujifilm is demonstrating its innovative iACF anisotropic conductor technology drawn from our proprietary printing and metal substrate expertise.

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Silicon is transforming traditional businesses, bringing real-time connectivity and onboard intelligence to everything from homes to retail, from automobiles to drones, and from manufacturing and smart cities. GLOBALFOUNDRIES is the leader in enabling this connected intelligence. Our unique assets and flexible engagement models help us serve visionary customers looking to transform their industries through silicon. GF is owned by Mubadala Investment Company.

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Hitachi Chemical is a leading company in providing various materials used in advanced semiconductor assembly packages, such as FO-WLP/PLP, 2.5 & 3D packages, SiP etc. In addition to those materials, Hitachi Chemical provides "Open Laboratory" located in Japan where any customers can utilize advanced fabrication and analytical equipment to achieve an accelerated development for complex and advanced structures. The Open Laboratory will relocate to more convenient location, closer to Tokyo, in Q4 2018. Our sales offices are located

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i3 Electronics, Inc., with headquarters in Binghamton, NY, is a vertically integrated provider of high performance electronic solutions consisting of design and fabrication of printed circuit boards and advanced semiconductor packaging, full turnkey services for printed circuit board assembly and integrated circuits assembly and test, systems integration, cable and harness manufacturing, heterogeneous MCM, die extraction and reassembly and world class reliability and failure analysis laboratories. i3 unites advanced technology and technical know-how with a robust manufacturing environment to meet the current and emerging needs of the most demanding markets, including defense and aerospace, communications and computing, advanced test equipment, and medical.

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Founded in 1994, iST began its business from IC circuit debugging and modification and gradually expanded its scope of operations, including failure analysis, reliability verification, material analysis and so on. iST has offered full-scope verification and analysis services to the IC engineering industry, its customers cover the whole spectrum of the electronics industry from IC design to end products. In response to rising Cloud Intelligence, Internet of Things (IoT) and Internet of Vehicles (IoV), iST not only focuses on its core services but is also expanding its service offerings based on international trends, such as Automotive electronic verification platforms and signal integrity testing services.

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Interconnect Systems, Inc. (ISI), specializes in high-density module packaging and advanced system-level interconnect solutions. ISI offers design, qualification, and testing, coupled with fully integrated in-house manufacturing. Capabilities include: high-density PCB design, fine pitch SMT, flip chip, wirebond assembly, IC packaging, custom molding, over molding, and automated optical inspection.

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Kyocera International, Inc., Semiconductor Components Group offers an extensive array of organic FC-CSP / FC-BGA / SHDBU packages, complex ceramic modules, embedded PWB, and high-density PCBs for numerous applications including RF/MW, ASICs, MPUs, graphics processors, data centers, power semiconductors, phased array radar, telecom, avionics and space.

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LINTEC is a worldwide leader in adhesive technologies. For more than 30 years, LINTEC has created equipment and materials to solve difficult semiconductor process issues. With a catalog of hundreds of tapes and equipment, and decades of application experience LINTEC is positioned to help. Whether you are looking for tape, need equipment to mount, peel or UV cure - our staff stands ready to assist you to provide the Adwill Advantage.

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Mentor, A Siemens Business is the worldwide market leader in PCB systems design, advanced IC packaging solutions, and analysis technologies. Recently awarded the 3DInCites "EDA Supplier of the Year" award, Mentor will showcase its Xpedition(R) High Density Advanced Packaging (HDAP) solutions for prototyping, design, and verification of heterogeneous multi-substrate

designs such as FO-WLP, 2.5D, and system-in-package. Visit booth 704 to learn more about Mentor's technologies and best practices for IC/Package/Board co-design.

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Mini-Systems, Inc. (MSI) is a world class leader in the manufacture of high-reliability passive components and hermetic packages. For over 50 years MSI has been delivering superior quality products for Military, Aerospace, Communications, Medical and Industrial applications. MSI manufactured products consist of precision: Thin/Thick film Chip Resistors/ Networks, QPL Resistors to MIL-PRF-55342, MOS Chip Capacitors, Chip Attenuators, Full Line of RoHS Compliant Products, QPL Jumpers to MIL-PRF-32159/Mounting Pads, Glassto-metal seal packages, and Custom Design Packages. Resistors values from 0.1 Ohm to 100GOhm and operating frequencies up to 40 GHz. Absolute tolerances starting at 0.005% and TCRs as low as ±2ppm/°C. Sizes start at 0101.

The hermetic packages meet or exceed package evaluation requirements per MI-PRF-38534, Table C-VI. Hermeticity of the packages is less than 10-10 atm cc/sec per MIL-STD-883, method 1014, condition A4. MSI is ISO 9001 certified. Compliance includes RoHS, REACH, and DFAR. Standard deliveries start in just 2 WEEKS!

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ICROS™ Tape has been the world's top protective tape used in semiconductor wafer backgrinding (BG) for decades. In order to meet the strict requirements of semiconductor market, we optimize whole production processes from material design to final inspection. Everything takes place within state-of-the-art clean room production environments with strict quality controls in place every step of the way. The result is ICROS™ Tape, an ultraclean tape with superior TTV (total thickness variation). Today, ICROS™ Tape is not only used for BG but also for many other processes in semiconductor manufacturing flow and electronic components manufacturing flow, such as dicing, packaging process, tape for metal lift off, protective tape for etching, tape for CMOS image sensor handling, and protection tape for back metalizing. ICROS $^{\text{TM}}$ Tape is now being developed for latest generation semiconductor process, such as TSV wafer BG and dicing, fan-out WLP, Panel Level Package and many other processes.

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Nagase ChemteX is a leading company for semiconductor encapsulant of epoxy resin, especially Liquid Molding Compound (LMC) for FOWLP, 2.5D, 3D, SiP, Non-Conductive Paste (NCP) for Fine pitch FC-PKG, Underfill for Pb-free. Engineered Materials Systems, Inc. technology focus on electronic materials and negative photoresist for semiconductor, circuit assembly, photovoltaic, printer head, camera module, disk drive, printed electronics and photonics assembly product lines. These Nagase Group companies create continual improvements guiding its customers into the future.

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NAMICS CORPORATION is a leading source for underfills, encapsulants, adhesives, and insulating and conductive materials used by producers of semiconductor devices, passive components and solar cells. Headquartered in Niigata, Japan with subsidiaries in the USA, Europe, Taiwan, Singapore, Korea and China, NAMICS serves its worldwide customers with enabling products for leading-edge applications.

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Neu Dynamics offers encapsulation molding systems for micro BGG and PBGA array devices, Top and Bottom Transfer as well as multi-plunger mold tooling for the latest in small outline devices (TQFP, TSSOP, MSOP, QFN, LGA, etc.) and molded Optoelectronic packages, Automatic and semi-automatic trim and form dies and systems supplied with trim presses (both Servo and Hydraulic driven). Neu Dynamics further offers contract transfer molding services. Our fully equipped molding lab allows for mold tryouts, pilot runs and low to medium volume production. Neu Dynamics is also capable of building high-precision injection molds specializing in insert and overmolding applications. Our sister company, NDC International, is a distributor of a wide range of back-end semiconductor assembly packaging equipment and materials, and custom automation solutions.

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nepes is a leading-edge provider of Wafer Level Packaging, Panel Level Packaging and turnkey assembly solutions, including testing and DPS services. Since 2001, nepes has been providing OSAT services in partnership with Fabless and IDM customers worldwide. With ISO/TS 16949, ISO 14001, OHSAS 18001 and AEO certified facilities located in South Korea and China, nepes provides an extensive range of packages:

bump, wafer level package (WLP), fan-out wafer level package (FO-WLP), fan-out wafer level System in Package (FO-WL-SiP) as well as 2 and 3D modules. Its PLP (Panel Level Package) has revolutionized the mass production of advanced semiconductor packages while providing price competitiveness by utilizing an innovative process and structure based on extensive touch screen panel (TSP) and LCD production experience. nepes is well positioned to support leading semiconductor companies, foundries and electronics IDMs with their advanced packaging requirements. For more information, please visit www.nepes.us.

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Nikon Metrology, Inc. offers the most complete and innovative metrology product portfolio, with state-of-the-art vision measuring instruments x-ray machines with CT options, and a complete line of 3D metrology options. These reliable and innovative solutions respond to the advanced inspection requirements of manufacturers active in aerospace, electronics, automotive and other industries. To learn more about our innovative products and to view all our product lines please visit our website.

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Nitto is a global supplier of materials and equipment for semiconductor manufacturing, represented by the following products: ELEP holder tapes for back-grinding and dicing; high-temperature resistant masking tape; NEL machines (Taper/Detaper/ Wafer Mounter with or without peeling function/ UV machine) for thin wafer application; ELEPMOUNT (2-in-1: DAF+Dicing Tape conductive/non-conductive) for thin stacked chip package; REVALPHA thermal-release tape for various applications, such as dicing, grinding and MLCC production process; clear molding compound and sheet encapsulating resin.

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Nordson DAGE manufacturers wire pull, ball and die shear test systems along with X-ray inspection systems that are recognized as the industry standard. The 4800 bondtester brings the latest developments in automated wafer testing technology to users testing wafers from 200mm upwards. When combined with an integrated wafer handling device the 4800-INTEGRA™ can test multiple wafers consecutively. Automation on non-wafer samples can also be conducted on the 4000Plus which performs shear tests up to 200kg, pull tests up to 100kg and push tests up to 50kg. The 4000HS high speed bond tester is used for pull and shear testing of solder spheres to identify brittle fractures at speeds up to 4m/ sec in shear and 1.3m/sec pull. Technologies such as TSV, PoP, 2.5D and 3D integration demand a new level of metrology. The XM8000 intelligent X-ray metrology system delivers fully automated, non-destructive, radiation safe defect detection of all complex devices.

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Nordson SONSOCAN®, Inc. is a worldwide leader and innovator in Acoustic Micro Imaging (AMI) technology. We manufacture acoustic microscope instruments and automated inspection equipment to nondestructively inspect and analyze products. Our C-SAM® scanning acoustic microscope provides unmatched accuracy and robustness setting the standard in AMI for the inspection of products for hidden internal defects such as poor bonding, delaminations between layers, cracks and voids. In addition, we offer analytical services through regional testing laboratories in Asia, Europe and the U.S. and educational workshops for beginners to advance users on AMI technology.

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NTK Technologies is a leader in IC Ceramic Packaging. For nearly half a century, NTK has developed specialized technologies to provide advanced ceramic IC packaging solutions for large and start-up semiconductor companies. NTK's technical centers support design optimization and simulation services through all development and production stages - prototype, small volume, and volume manufacturing. With global service centers, NTK offers a wide range of packaging materials and design services for MEMS Sensors, CMOS/CCD Image Sensors, Opto, FPGA, CPU, MPU, MCM, RF, LED Substrates, Hi-Rel, Satellite, Automotive and Medical applications. Wafer Probe Substrates utilizing multilayer co-fired ceramic and multilayer thin film available. Optimum package designs for IOG to 400G. As one of the industries' largest packaging manufacturers, NTK's products and services have evolved to match the roadmaps of mainstream and advanced IC packaging applications.

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We are a Nano Alchemists and EMI/EMC total solution provider. Ntrium is presented with the opportunity to converge Nano-material technology and the Microelectronics packaging technology of Automotive and Automotive/ Semiconductor/Mobile/IT products to ignite bright minds that solve technical problems customers face, to provide collaborate and innovative solutions. Our product list is as follows: EMI shielding paste for spraying method / EMI shielding Film / EMI absorber / Conductive Bonding Film for camera module / Thermal Interface Material(TIM) / Conductive Particles for Elastomer Test Socket / Conductive Beads for Anisotropic Conductive Film(ACF). Are you interested in our products or technology? Please visit our booth or contact us.

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Packaging Technologies GmbH (group member of NAGASE & CO. Ltd.) is headquartered in Nauen, Gremany with wholly owned subsidiaries: PacTech USA Packaging Technologies Inc. in Silicon Valley, USA, and PacTech ASIA Sdn. Bhd. in Penang, Malaysia. PacTech is comprised of two unique advanced packaging units: EQUIPMENT MANUFACTURING: PacLine 300 A50-Automatic ENIG & ENEPIG plating tools. SB2-Jet: Laser solder jetting equipment; Ultra-SB: Waferlevel solder ball transfer systems; LAPLACE:

Laser assisted flip-chip bonders SUBCONTRACT SERVICES: Flip Chip and Wafer Level Package Bumping Services including ENIG or ENEPIG for UBM (solder bumping) or OPM (wirebond). Other services include AOI, X-Ray, Repassivation, RDL, Wafer Thinning, Backmetal, Laser Marking, Dicing, and Tape and Reel.

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Palomar Technologies is a leading supplier of automated microelectronic assembly machines and contract assembly services with specialization in precision die attach, wire bonding and vacuum reflow processes. High-precision assembly systems enable customers to increase yield and reduce costs in the manufacturing of optoelectronic, RF and power module packages.

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Panasonic Factory Solutions Company of America (PFSA) develops and supports innovative manufacturing processes around the core of circuit manufacturing technologies and computer-integrated manufacturing software—thereby, contributing to the growth and prosperity of our customers' businesses regardless of their mix or volume.

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Since the founding of our company in 1918, we at Panasonic have been providing better living for our customers, always making people central to our activities, and thus focusing on people's lives. Going forward from this, and based on our innovative electronics technology, we will continue to provide a wide variety of products, systems and services.

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Plasma-Therm® is a leading provider of advanced plasma processing equipment. Plasma-Therm systems perform critical process steps in the fabrication of integrated circuits, micromechanical devices, solar power cells, lighting, and components of products from computers and home electronics to military systems and satellites. Specifically, Plasma-Therm systems employ innovative technology to etch and deposit thin films. The company's Mask Etcher® series for photomask production has exceeded technology roadmap milestones for more than 15 years. Plasma-Therm's Singulator® systems bring the precision and speed of plasma dicing to chippackaging applications. Manufacturers, academic and governmental institutions depend on Plasma-Therm equipment, designed with "lab-to-fab" flexibility to meet the requirements of both R&D and volume production. Plasma-Therm's products have been adopted globally and have earned their reputation for value, reliability, and world-class support. Customers consistently rank Plasma-Therm among the top equipment suppliers, with multiple awards in the annual VLSIresearch Customer Satisfaction Survey, including being named "Ranked 1st" Etch and Clean Equipment Supplier five years in a row.

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Promex provides heterogeneous assembly processing integrating conventional surface mount technology (SMT) with semiconductor microelectronic packaging and assembly methods for flip chip or chip/wire devices. The company operates a 30,000 sq. ft. assembly facility with Class 100 and 1000 clean rooms in Silicon Valley that is ISO 13485:2003, ISO 9001:2008 certified, ITAR registered and compliant to regulatory requirements for medical products. With a highly skilled engineering team, Promex combines broad technical capabilities, advanced packaging, and microelectronics assembly expertise with scalable manufacturing capacity to produce new medical and bioscience products from concept to production.

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Pure Technologies manufactures low (0.02, 0.01 cph/cm2), ultra-low (0.005, 0.002 cph/2) and super ultra-low (<0.001 cph/cm2) alpha emitting Tin (Sn), Lead-Free (including all SAC) alloys, Pb, Pb/Sn, Bi and virtually all alloys for over 23 years. These ALPHALO® products are available in various shapes and sizes – ingots, anodes, slugs, pellets, foil, rods, bricks, PbO and SnO powder, etc. for wafer-level packaging, interconnects, electroplating and sphere and powder/paste manufacturing. ALPHA-LO® reduces/eliminates soft errors from alpha particle emissions from solders, enhances performance reliability and reduces corporate liability. All materials are guaranteed and certified to be at secular equilibrium and are tested and retested over time before shipping to insure that the alpha emission rate is stable and will not increase over time.

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QualiTau offers a variety of reliability test equipment for characterization and development of new materials used in the manufacturing of Integrated Circuits, as well as process monitoring and process qualification. The MIRA, Infinity, ACE, and Multi-Probe reliability test systems perform tests for Hot Carrier Injection (HC), Dielectric Breakdown (TDDB), and electromigration(EM) of interconnects, TSV, Solder Bump (8 amperes max) at test temperatures of up to 450°C. QualiTau's Test Lab service is ideal for both fabless companies and foundries seeking: Reliable, independent evaluation and analysis. Virtual capacity during times of under-capacity. Cost-effective means of performing tests on an irregular or infrequent basis. A productive and beneficial way to test drive the equipment before committing to a purchase.

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Quik-Pak, a division of Promex, provides IC packaging, assembly, and wafer preparation services in its ISO 9001:2008 and ITAR registered facility in San Diego, California. Quik-Pak manufactures over molded QFN/DFN packages and pre-molded air cavity QFN packages that provide a fast, convenient solution for prototype to full production needs. Same-day assembly services are provided to shorten time to market. Due to customer demand, Quik-Pak now provides high volume IC assembly services utilizing its automated assembly and molding equipment for production runs in the 10,000s of units. In addition to wire bond assembly, the company assembles flip chips, BGAs, stacked die, sensors, MEMS, and chip-on-board and chip-onflex assemblies.

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Royce Instruments, your preeminent supplier for Bond Testing and Die Sorting equipment. Our high-precision equipment covers the spectrum of bond test and die sorting requirements. Since bond testing and die sorting are our sole focus, we are dedicated to developing and supplying dynamic solutions for our customers. The Royce 600 Series Bond Testers bring unparalleled networking capability and scalability to the market. With three bond testers, Royce offers an instrument solution to meet the evolving needs of institutions worldwide. Royce Die Sorters (DE35-ST, MP300, and AP+) offer semi- and fully automatic die sorting solutions for die as small as 200um square or 50um thick. Our new automated sorter, the AP+, has the capability to handle diverse input and output mediums (carrier tape, waffle pack, Gel-Pak, Jedec, film frame and more) while maintaining input to output traceability at the die level. Visit us at Booth 108 to learn more!

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Rudolph Technologies is a leader in the design, development, manufacture and support of defect inspection, advanced packaging lithography, process control metrology, and data analysis systems and software used by semiconductor device manufacturers worldwide. Rudolph's product suite offers hardware and software solutions for the demanding requirements of the advanced packaging market, including 2D/3D bump inspection, RDL and overlay metrology, and a lithography stepper specifically designed for the back-end. Turn data into useful information with Rudolph's proprietary software solutions including run-to-run control, fault detection and classification and yield management systems.

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Known as the worldwide service leader for electronic connectors and cables, Samtec has focused on leading edge high speed products and services for the last two decades. The tremendous success in these areas has driven Samtec to further move into faster and smaller arenas. They now provide full turnkey solutions for your entire signal chain from IC, through the package, and through substrates, connectors and cables. Samtec can help you design, model, layout, and assemble your IC package. Advanced Semiconductor, MEMS, and Sensor substrate design, flip chip, die attach, wire bonding, dam, encapsulation, transfer molding, and lid attach, modeling and prototyping, electrical testing and debug, in-house mid-board optical/photonic engine design, manufacturing, and packaging, and new capabilities in glass interposers and substrates with low loss electrical characteristics. biomedical microstructuring, and 2.5D package integration.

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Sanyu Rec Company Ltd. is a Japanese electronics material supplier to the semiconductor market place including LED market. With creative development and numerous proprietary technologies, SANYU REC contributes to these growth fields which are driven by environmental considerations and mobile applications. SANYU REC has provided a variety of products centering on encapsulation materials like liquid MUF (mold underfill) material to the market. Capillary underfill, die attach materials, and mold sheets are also in our main product lines. Not only these materials but also VPES (vacuum printing equipment) and pressure oven are in our product lines to offer comprehensive solutions to the customers, which distinguishes us from our competitors. SANYU REC is continuing our effort in development of unique and new technologies, such as LED, one of the areas SANYU REC promotes the shift to.

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SavanSys is the industry standard choice for electronics manufacturing cost modeling. The company began in the mid-nineties with a focus on multi-chip module and PCB fabrication and assembly before expanding into electronics packaging. SavanSys provides both cost modeling services and software products and maintains an extensive library of manufacturing activity costs. Projects range from multi-year ventures focused on detailed supply chain modeling to one-time projects comparing a new technology to the current industry standard. All SavanSys projects and products use activity based cost modeling, which is a bottom-up approach to cost that aggregates individual cost contributors (labor, material, throughput, equipment cost, etc.) for every step in a process flow.

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SCHOTT Advanced Optics is a valuable partner for its customers in developing products and customized solutions for applications in optics, lithography, astronomy, opto-electronics, life sciences, and research. With a product portfolio of more than 120 optical glasses, special materials and components, we master the value chain: from customized glass development to highprecision optical product finishing and metrology. SCHOTT is one of the world's leading suppliers of thin and ultra-thin glass wafers and substrates made of different materials in sizes of between 4" and 12", with various surface qualities and customized features. The use of proprietary production processes, a wide selection of different materials, and continuous expansion of state-of-the-art processing capabilities make SCHOTT's wafer offerings unique in the industry. Process Capabilities include polishing, structuring, edge treatment, ultrasonic washing, and clean room packaging. SCHOTT's portfolio of Thin and Ultra-Thin glasses includes: AF 32® eco, an alkalifree flat glass with a CTE matched to silicon; D 263® eco, a high CTE and high transmission glass; SCHOTT AS 87 eco, a ultra-thin and toughenable glass; B 270®, a crown glass with extremely high CTE; and MEMpax®, an anodic bondable glass with a CTE corresponding to silicon. The portfolio is supplemented by FLEXINITYTM, SCHOTT's glass structuring revolution.

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Senju Comtek Corp. is an American subsidiary of Senju Metal Industry Co. (SMIC) of Tokyo, Japan. Senju is a global leader in solder materials and related processing equipment with over two dozen manufacturing, technical, and sales support facilities located around the world. Our wide array of solder products include Cu-core balls and columns, micro-spheres, flux for ball-attach and chip-attach, unique preforms, jet dispensing paste, low temp and high reliability alloys. Senju offers customized solutions for IC technology challenges.

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To enable high-density interconnect, SET-North America offers surface preparation and high-accuracy bonding tools with unparalleled performance. For removing native oxides, residual organics or other bond inhibitors, the ONTOS7 Atmospheric Plasma Surface Preparation tool cleans and passivates bonding surfaces to provide high-quality bonds with superior electrical and mechanical integrity. This tool is also effective in activating surfaces to enhance wetting and wicking for aqueous processes or underfill materials. The device bonders manufactured by SET are globally renowned to deliver unsurpassed bonding accuracy (±0.5 µm) at high temperatures and forces for chips and substrates ranging from tiny, fragile components up to 300 mm wafers. With a product portfolio ranging from manually loaded versions to fully-automated operation, SET offers bonding and nanoimprint solutions with high flexibility and field-proven reliability.

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SHENMAO America, Inc. is the American Subsidiary of SHENMAO Technology, Inc. of TaoYuan City 328, Taiwan. Shenmao is a global leader in manufacturing solder materials for over 45 years with 10 manufacturing, technical, and sales support facilities located around the world. SHENMAO America, Inc. manufactures solder paste in San Jose, CA, USA, also supporting a wide range of products for the Semiconductor Packaging and PCB Assembly industries. SHENMAO produces SMT Solder Paste, Laser Soldering Paste, Wave Solder Bar, Solder Wire with/without Flux, Liquid and Paste Flux, Solder Preforms, Semiconductor Packaging Solder Spheres, Wafer Bumping Solder Paste, Dipping Flux, LED Die Bonding Solder Paste, Plating Anode and Solar PV Ribbon. 11 of the 12 largest EMS Companies are valued customers that are continuously using SHENMAO Technology, Inc. Solder Materials with great success. OSAT's, EMS and OEM's qualify/re-qualify our products for many years.

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Shin-Etsu MicroSi, Inc. is a wholly owned subsidiary of Shin-Etsu Chemical Ltd. Shin-Etsu MicroSi is a world-class supplier of packaging materials for the semiconductor industry. With a global support network- Sales Engineers, R&D, Manufacturing, Quality Assurance, and Logisticswe are able to quickly develop and provide new technologies to benefit our customers. This allows our clients to meet their ever changing technical, commercial and environmental needs by implementing Shin-Etsu MicroSi's technology. Shin-Etsu MicroSi is known for supplying high performance Thermal Interface Materials, Underfills, Molding Compounds, High Purity Silicone Encapsulants, and Die Attach Materials.

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Shinkawa is a leading supplier of flip chip, die, and wire bonding equipment. The wide range of equipment supports various applications including automotive, server, mobile, and communication devices for the IoT society. Our automated features also are suited for the smart factory concept. For leading edge packaging technology Shinkawa provides innovative solutions with highaccuracy TCB flip chip bonders and ultra-high throughput flip chip bonders for the mass reflow process (C4/C2). For die and wire bonding Shinkawa provides technologies for ultra-thin die pick up and unique wire shape for RF, memory, and many other devices. Founded in 1959 in Tokyo and with a strong presence today in the semiconductor market, Shinkawa supports a diverse network of global customers and partners around the world.

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SHINKO Electric Industries Co., LTD., is a leading manufacturer of products used in the assembly of IC's such as Organic Substrates, Etched and Stamped Leadframes, TO Packages and Integrated Heatspreaders. We manufacture a full line of Organic Substrate structures including coreless options offering enhanced electrical performance and package miniaturization. SHINKO also provides subcontract IC assembly services with an emphasis on packaging solutions such as PoP, SiP as well as advanced technologies such as Molded Core Embedded Package

(MCeP®) and Module assembly and test. Our headquarters and primary production plants are in the greater Nagano, Japan area. In addition to our production facilities we also provide the ultimate in service and solutions for customers, with Sales and Engineering support Worldwide. See us to learn more about our latest product offerings for fine pitch interconnection, miniaturization and high density mounting for 3D assembly.

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SPTS Technologies, an Orbotech company, designs, manufactures, sells, and supports advanced etch, PVD, CVD and MVD® wafer processing equipment and solutions for the global semiconductor and micro-device industries, with focus on the Advanced Packaging, MEMS, highspeed RF device, power management and LED manufacturing. With the acquisition of SPTS. Orbotech is able to offer a broader range of process solutions for Advanced Packaging, which includes Orbotech's Inkjet/3D printing solutions for die level printing and UV Laser Drilling for through mold vias. SPTS has manufacturing facilities in Newport, Wales and Allentown, Pennsylvania, and operates across 19 countries in Europe, North America and Asia-Pacific.

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STATS ChipPAC is a leading outsourcing provider of semiconductor design, wafer bump, packaging and test solutions for well-established market such as communications, consumer and computing as well as emerging markets in automotive electronics, Internet of Things (IoT) and wearable devices. STATS ChipPAC is a member of the JCET group of companies. JCET is one of the top semiconductor packaging and test providers in the world and the largest OSAT provider in China. Headquartered in Jiangyin, China, ICET has an extensive global manufacturing base with operations in China, Singapore and South Korea. The comprehensive packaging portfolio of ICET and its subsidiaries include discrete, leaded, laminate, flip chip, Molded Interconnect System, wafer level packaging and System-in-Package technologies. For more information, visit www.statschippac.com or www. jcetglobal.com.

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TAIYO INK MFG. CO., LTD has more than 90% market share of solder resist products on IC-Packaging industry. We have recently introduced two important solder resist products to the market: AZI and SR3. AZI provides very robust TST crack resistance with high Tg best for large body FCBGA and high temperature automotive BGA products. SR3 offers very low CTE (15-20ppm) with high modulus (>10GPa), being ideal for coreless/thin core applications. Taiyo additionally offer photo-imageable dielectric dry film materials (PID) based on our expertise in photo-imageable dielectric technology. Application of the PID materials are many, including as build-up materials for BGA substrates or interposers, as insulation materials for embedded applications, and as PI/PBO alternative for WLP / PLP products with greater advantages. For more details, please visit our booth 605. Our engineers will meet you there to answer all your questions including those about our materials for your applications.

TATSUTA USA Inc. 101 Metro Drive, Suite 355 San Jose, CA 95110 Phone: +1-408-642-1938 Fax: +1-408-982-3391 www.tatsuta.com **Contact: Mike Sakaguchi** Email: m-sakaguchi@tatsuta.com Booth 700

TATSUTA is leading provider of EMI shielding conductive material for semiconductor industry. TATSUTA provides innovative solutions for conformal and compartment shielding. TATSUTA also provides unique high reliability metallizing paste for TMV& TGV filling, low-temperature cure type conductive paste for circuitry printing and 3D SMT, For more details, please visit Booth 700. We will provide solutions for your applications.

TDK Corporation 475 Half Day Road Suite 100 Lincolnshire, IL 60069 Tel: +1-847-795-2163 www.tdk.com **Contact: Philip Couts** Email: philip.couts@us.tdk.com Booth 103

TDK is a leading provider of 300mm loadports and Thermosonic Flip Chip Die Bonders. TDK is featuring its TAS300 PLP Loadport (Large Panel Loader) for large panel sizes 500mm to 650mm (FOWLP Process ools). Options include N2 Purge, Mapping, and ethernet communication. TDK TAS300 00mm JI Loadport has FAB Proven interoperability with MCBF Over 750,000, 30% Improvement in Cycle Time, 50% Reduction is Shipping Package Volume, and N2 Purge Field

Retrofit Option. TDK will also promote our Wireless Humidity Sensor Module for N2 Purge FOUPs. TDK sensor modules with integrated humidity and temperature sensor are installed inside 300mm N2 Bottom Purge FOUPs. Real time monitoring of inside FOUP humidity and temperature helps reduce wafer films oxide and allows N2 loadport purge process based upon actual data. TDK Humidity and Temperature Sensors features include wireless communication with FAB host computer, a wireless charging plate for existing loadports, easy install and setup with existing FA equipment.

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TechSearch International, Inc. has a 30-year history of market and technology trend analysis focused on semiconductor packaging, materials, and assembly. Research topics include WLP, FO-WLP, flip chip, CSPs including stacked die, BGAs, 3D ICs with TSVs, 2.5D interposers, and System-in-Package (SiP), embedded components, ADAS and automotive electronics, and panelbased processing. In conjunction with SavanSys Solutions, wire bond, flip chip, WLP, and 3D IC cost models are offered. TechSearch International professionals have an extensive network of more than 18,000 contacts in North America, Asia, and Europe and travel extensively, visiting major electronics manufacturing operations and research facilities worldwide.

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TECNISCO is process service provider of precision component. Since established, we have expanded the technical process field and generated "Cross-edge" micro processing which means cross over the 5 (Kiru, Kezuru, Migaku, Metalize, and assembling) cutting edge technologies for supporting in the field of Opto-telecommunication, Industrial lasers and MEMS devices for medical industries. We are doing processing services and able to supply customized parts that are manufactured with metal, ceramic, glass and silicon by its advanced high-precision processes and composite technologies. TECNISCO's expertise includes: Dicing, Sandblasting, Milling (CNC machining), Assembling (AuSn, AuGe, AgCuln, AgCu),

Polishing, Bonding, Metallization (Plating, Sputtering, Vapor deposition) for producing such as CuW, CuMoCu, CuAlNCu, Cu heatsinks (for high power laser diode) and structured glass wafer (for MEMS and medical device).

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Since founded in 1955 in Japan, Threebond has been offering the adhesive/sealant products globally with its cutting-edge technologies. Threebond has developed networks across six regions: Japan, North/central Americas, south America, Europe, Asia, and China. Threebond offers unique products such as hot water removable temporary bonding adhesive, UV-curing black adhesive, 60°C x I minute curing elastic adhesive, moisture blocking adhesive, UV-activated dual curing epoxy, ultra low viscosity (2cP) UV-curing adhesive, high thermally conductive epoxy, etc. Over 1,600 products will provide solutions to the problems you are facing. Ask Threebond if you need any specific adhesives or sealants.

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Booth 710

Teikoku Taping System specializes in the design, development and manufacture of semiconductor equipment used for taping ("Haru"), de-taping ("Hagasu") and handling ("Hakobu") of wafers and panels. TTS is the leader in Dry Film Resist lamination, as well as the handling of thin wafers for back grind tape lamination, UV irradiation, removal and mounting to dicing tape on film frame. Customer support for demos, process development, field service are all based in our offices in Phoenix, AZ.

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TOK's unique packaging / MEMS manufacturing technologies, in terms of both materials and equipment. We have developed and commercialized optimal photoresists and processing equipment for a range of packaging processes. Photoresists for packaging are available for a wide range of production technologies including wafer-level CSP, SiP, RDL, TAB

and COF. We have commercialized thick-film permanent photoresists for MEMS, and developed a non-spin coater that can form thick films capable of highly uniform photoresist coating at a 100 μ m level with a single application and a developing machine for thick films. We offer high quality, most advanced and most effective processing technologies in the MEMS field as well, thus widely supporting the miniaturization of electronic components in terms of both materials and equipment.

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Abstracts must be received by October 8, 2018. All abstracts must be submitted electronically at www.ectc.net. You must include the mailing address, business telephone number, and email address of presenting author(s) and affiliations of all authors with your submission.

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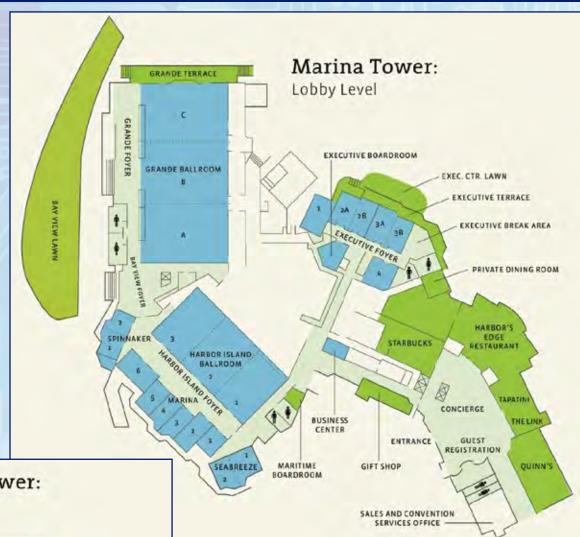
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Marina Tower: Lower Level









69TH ELECTRONIC COMPONENTS & TECHNOLOGY CONFERENCE

The Cosmopolitan of Las Vegas Las Vegas, Nevada, USA May 28 - May 31, 2019

The spectacular city of Las Vegas awaits you in 2019. As the entertainment capital of the world, there are over 100 spectacular live shows and entertainment venues to see daily. Las Vegas also touts world-class cuisine with an array of restaurants by world famous chefs.

Next year ECTC will be back at The Cosmopolitan hotel located directly adjacent to the world-renown Bellagio and its famed fountain show. The hotel itself is a \$4 billion stunning architectural statement with a chandelier bar that spans two stories. It also has some of the country's top chefs, three distinctive pools, and 44,000 square feet of salon, spa, and fitness areas.

Should you want to put aside Vegas' bright lights and casinos, visit many of the natural wonders that surround this city. Over five major parks and wonders are in close proximity. From Red Rock Canyon to Death Valley or Hoover Dam to Grand Canyon National Park, there is so much to do and see.



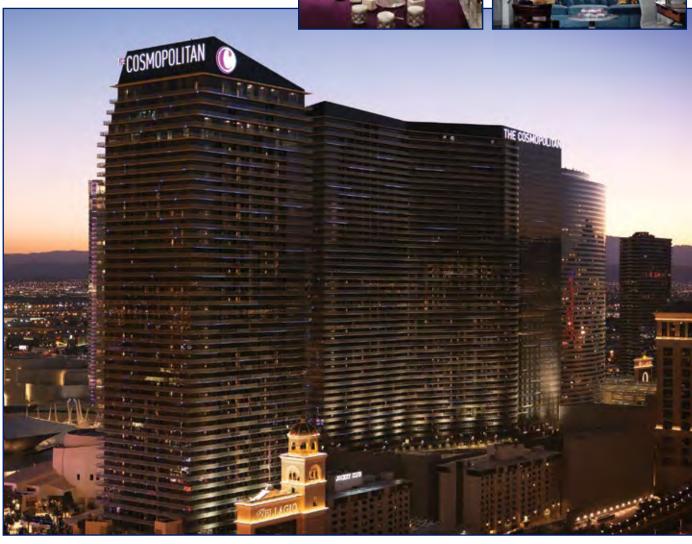












Conference At A Glance

REGISTRATION

Monday 3:00 p.m. - 5:00 p.m.

Tuesday

6:45 a.m. - 5:00 p.m.

Wednesday

6:45 a.m. - 4:00 p.m.

Thursday

7:30 a.m. - 4:00 p.m.

Friday

7:30 a.m. - 12:00 p.m. Bayview Foyer

TECHNOLOGY CORNER EXHIBITS

Wednesday 9:00 a.m. - 12:00 p.m. 1:30 p.m. - 5:30 p.m. Reception - 5:30 p.m. - 6:30 p.m.

Thursday

9:00 a.m. - 12:00 p.m. 1:30 p.m. - 4:00 p.m. Bayview Pavilion

TUESDAY - FRIDAY

Speaker Preparation Room

7:00 a.m. – 5:00 p.m. *Marina 3*

TUESDAY ONLY

PDC Instructors and Proctors Briefing & Breakfast

7:00 a.m. – 7:45 a.m. Grande Ballroom B

Professional Development Courses (PDCs)

8:00 a.m. – Noon 1:15 p.m. - 5:15 p.m. See page 9 for locations

EPS Heterogeneous Integration Roadmap Workshop

8:00 a.m. – 5:00 p.m. Executive Center 1 & 4

Special Sessions: Emerging Technologies Special Session

10:00 a.m. – 11:30 a.m. Grande Ballroom C

ECTC Special Session

2:00 p.m. – 3:30 p.m. *Grande Ballroom C*

Refreshment Breaks

10:00 a.m. – 10:20 a.m. 3:00 p.m. – 3:20 p.m. Harbor Island Foyer, Grande Ballroom A Foyer, and Nautilus Foyer

Lunch for PDCs

12 p.m. Noon Grande Ballroom B

Technology Corner SetUp

1:00 p.m. – 5:00 p.m. Bayview Pavilion

ECTC Student Reception

5:00 p.m. – 6:00 p.m. Executive Center 3

General Chair's Speakers Reception

6:00 p.m. – 7:00 p.m. Grande Ballroom B By invitation only

Young Professionals Panel and Reception

7:00 p.m. – 7:45 p.m. *Harbor Island* 3

ECTC Panel Session

7:45 p.m. – 9:15 p.m. Harbor Island 1 & 2

WEDNESDAY - FRIDAY

Speakers Breakfast

7:00 a.m. – 7:45 a.m. Grande Ballroom A

Sessions

8:00 a.m. – 11:40 a.m. or 1:30 p.m. – 5:10 p.m. see pages 11 - 22 for specifics

Sessions 1, 7, 13, 19, 25, 31 Harbor Island 1

Sessions 2, 8, 14, 20, 26, 32 Harbor Island 2

Sessions 3, 9, 15, 21, 27, 33

Harbor Island 3

Sessions 4, 10, 16, 22, 28, 34 Nautilus 1 & 2

Sessions 5, 11, 17, 23, 29, 35 Nautilus 3 & 4

Sessions 6, 12, 18, 24, 30, 36 Nautilus 5

Interactive Presentations

9:00 a.m. - 11:00 a.m. or 2:00 p.m. - 4:00 p.m. 8:30 a.m. - 10:30 a.m. on Friday see pages 23 - 26 for specifics

> Sessions 37 - 41 Nautilus Foyer

Lunch

12 p.m. - 1:15 p.m. Grande Ballroom

Refreshment Breaks

9:15 a.m. – 10:00 a.m. 2:45 p.m. – 3:30 p.m.

Wednesday & Thursday

Bayview Pavilion

Friday Harbor Island Foyer Nautilus Foyer

WEDNESDAY ONLY

Women's Panel & Reception

6:30 p.m. – 7:30 p.m. *Harbor Island 3*

ECTC Plenary Session

7:30 p.m. – 9:00 p.m. Harbor Island 1 & 2

THURSDAY ONLY 68th ECTC Gala Reception

6:30 p.m. – 7:30 p.m. Bayview Lawn (Backup Location: Grande Ballroom)

IEEE EPS Seminar

8:00 p.m. – 9:30 p.m. Harbor Island 1 & 2

MARK YOUR CALENDARS NOW!



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